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# **PSP 102.4**

The PSP model is a joint development of Delft University of Technology and NXP Semiconductors

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**Unclassified Report** 

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> The PSP model is a compact MOSFET model intended for analog, RF, and digital design. It is jointly developed by NXP Semiconductors and Delft University of Technology. (Until 2011, it was jointly developed by NXP Semiconductors and Arizona State University. The roots of PSP lie in both MOS Model 11 (developed by NXP Semiconductors) and SP (developed at the Pennsylvania State University and later at Arizona State University). PSP is a surface-potential based MOS Model, containing all relevant physical effects (mobility reduction, velocity saturation, DIBL, gate current, lateral doping gradient effects, STI stress, etc.) to model present-day and upcoming deep-submicron bulk CMOS technologies. The source/drain junction model, c.q. the JUNCAP2 model, is

ing parameter sets, scaling rules, model equations, and a description of the parameter extraction procedure.

In December 2005, the Compact Model Council (CMC) has elected PSP as the new industrial standard model for compact MOSFET modeling.

fully integrated in PSP. This report contains a full description of the PSP model, includ-

Since December 2012, Delft University of Technology replaces Arizona State University

as the supporting institution.

#### **Conclusions:**

### History of model and documentation

### History of the model

**April 2005** Release of PSP 100.0 (which includes JUNCAP2 200.0) as part of SiMKit 2.1. A Verilog-A implementation of the PSP-model is made available as well. The PSP-NQS model is released as Verilog-A code only.

**August 2005** Release of PSP 100.1 (which includes JUNCAP2 200.1) as part of SiMKit 2.2. Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only. Focus of this release was mainly on the optimization of the evaluation speed of PSP. Moreover, the PSP implementation has been extended with operating point output (SiMKit-version only).

**March 2006** Release of PSP 101.0 (which includes JUNCAP2 200.1) as part of SiMKit 2.3. PSP 101.0 is *not* backward compatible with PSP 100.1. Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only. Focus of this release was on the implementation of requirements for CMC standardization, especially those which could not preserve backward compatibility.

**June 2006** Release of PSP 102.0 (which includes JUNCAP2 200.1) as part of SiMKit 2.3.2. PSP 102.0 is backward compatible with PSP 101.0 in all practical cases, provided a simple transformation to the parameter set is applied (see description below). Similar to the previous version, a Verilog-A implementation of the PSP-model is made available as well and the PSP-NQS model is released as Verilog-A code only.

Global parameter sets for PSP 101.0 can be transformed to PSP 102.0 by replacing **DPHIBL** (in 102.0 parameter set) by **DPHIBO** · **DPHIBL** (from 101.0 parameter set). After this transformation, the simulation results of PSP 102.0 are identical to those of PSP 101.0 in all practical situations.

**October 2006** Release of PSP 102.1 (which includes JUNCAP2 200.2) as part of SiMKit 2.4. PSP 102.1 is backward compatible with PSP 102.0. SiMKit 2.4 includes a preliminary implementation of the PSP-NQS model. Similar to the previous version, a Verilog-A implementation of the PSP-model is available as well.

**October 2007** Release of PSP 102.2 (which includes JUNCAP2 200.3). PSP 102.2 is backward compatible with PSP 102.1.

**April 2008** Release of PSP 102.3 (which includes JUNCAP2 200.3) as part of SiMKit 3.1. PSP 102.3 is backward compatible with PSP 102.2. The main changes are:

- Added asymmetric junction model for the drain-bulk junction. The new junction parameters have a suffix "D" added to their names. When **SWJUNASYM** = 1 the original parameters are used for the source-bulk junction and the new parameters are used for drain-bulk junction. When **SWJUNASYM** = 0 the original junction parameters are used for both source-bulk and drain-bulk junctions as in symmetric case, and the new junction parameters are neglected.
- Added asymmetric models for the overlap region of the drain side. These include
  - Added related model parameters TOXOVDO, LOVD and NOVDO to global, TOXOVD and NOVD to local and POTOXOVD, PONOVD, PLNOVD, PWNOVD and PLWNOVD to binning models.
  - Asymmetric GIDL/GISL model. Added related parameters AGIDLDW, BGIDLDO, STBGIDLDO and CGIDLDO to global, AGIDLD, BGIDLD, STBGIDLD and CGIDLD to local and POAGIDLD, PLAGIDLD, PWAGIDLD, PUAGIDLD, POSTBGIDLD and POCGIDLD to binning models.

- Asymmetric overlap gate current model. Added related parameters IGOVDW to global, IGOVD to local and POIGOVD, PLIGOVD, PWIGOVD and PLWIGOVD to binning models.
- Asymmetric overlap capacitance model. Added related parameters CGOVD to local, POCGOVD, PLCGOVD, PWCGOVD and PLWCGOVD to binning models.
- Asymmetric outer fringe capacitance model. Added related parameters CFRDW to global, CFRD to local and POCFRD, PLCFRD, PWCFRD and PLWCFRD to binning models.

When SWJUNASYM = 1 the original parameters for the models listed above are used for the source side and the newly added parameters are used for the drain side. When SWJUNASYM = 0 the original parameters are used for both source and drain sides and the new parameters are ignored.

- Added EF(local), EFO(global) and POEF(binning) as flicker noise frequency exponent parameters.
- Added noise parameters LINTNOI and ALPNOI to global model to increase the flexibility of the length scaling of the flicker noise.
- Some minor bug-fixes and implementation changes.

**December 2012** Release of PSP 102.4 as part of SiMKit 4.0.1. PSP 102.4 is backward compatible with the previous version, PSP 102.3. The main changes are:

- Several improvements in the noise-model implementation
  - Fixed sign of correlation coefficient (Verilog-A only).
  - Simplified implementation and better scaled noise amplitude at internal nodes (Verilog-A only).
  - Improved behavior when crossing  $V_{\rm ds}=0$  at high-frequency.
- Scaled local parameters were added to OP-output.
- Some minor implementation changes.
- New parameter **PARAMCHK** to set level of clip warnings (SiMKit only).
- More efficient model evaluation when  $\mathbf{MULT} = 0$  (SiMKit only).

#### **History of the documentation**

**April 2005** First release of PSP (PSP 100.0) documentation.

August 2005 Documentation updated for PSP 100.1, errors corrected and new items added.

**March 2006** Documentation adapted to PSP 101.0. Added more details on noise-model implementation and a full description of the NQS-model.

June 2006 Documentation adapted to PSP 102.0 and some errors corrected.

October 2006 Documentation adapted to PSP 102.1 and some errors corrected.

October 2007 Documentation adapted to PSP 102.2 and some errors corrected.

April 2008 Documentation adapted to PSP 102.3 and some errors corrected.

**January 2011** Description of SiMKit noise implementation (Section 6.5) aligned with recent modifications.

**April 2013** Documentation adapted to PSP 102.4.

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# **Section 1**

# Introduction

### 1.1 Origin and purpose

The PSP model is a compact MOSFET model intended for analog, RF, and digital design. It is jointly developed by NXP Semiconductors and Delft University of Technology. (Until 2011, it was jointly developed by NXP Semiconductors and Arizona State University. The roots of PSP lie in both *MOS Model 11* (developed by NXP Semiconductors) and *SP* (developed at the Pennsylvania State University and later at Arizona State University). PSP is a surface-potential based MOS Model, containing all relevant physical effects (mobility reduction, velocity saturation, DIBL, gate current, lateral doping gradient effects, STI stress, etc.) to model present-day and upcoming deep-submicron bulk CMOS technologies. The source/drain junction model, c.q. the JUNCAP2 model, is fully integrated in PSP.

PSP not only gives an accurate description of currents, charges, and their first order derivatives (i.e. transconductance, conductance and capacitances), but also of the higher order derivatives, resulting in an accurate description of electrical distortion behavior. The latter is especially important for analog and RF circuit design. The model furthermore gives an accurate description of the noise behavior of MOSFETs. Finally, PSP has an option for simulation of non-quasi-static (NQS) effects.

The source code of PSP and the most recent version of this documentation are available on the PSP model web site: psp.ewi.tudelft.nl and the NXP Semiconductors web site: www.nxp.com/models/simkit.

### 1.2 Structure of PSP

The PSP model has a hierarchical structure, similar to that of MOS Model 11 and SP. This means that there is a strict separation of the geometry scaling in the global model and the model equations in the local model.

As a consequence, PSP can be used at either one of two levels.

- Global level One uses a global parameter set, which describes a whole geometry range. Combined with instance parameters (such as L and W), a local parameter set is internally generated and further processed at the local level in exactly the same way as a custom-made local parameter set.
- Local level One uses a custom-made local parameter set to simulate a transistor with a specific geometry. Temperature scaling is included at this level.

The set of parameters which occur in the equations for the various electrical quantities is called the *local* parameter set. In PSP, temperature scaling parameters are included in the local parameter set. An overview of the local parameters in PSP is given in Section 2.5.7. Each of these parameters can be determined by purely electrical measurements. As a consequence, a local parameter set gives a complete description of the electrical properties of a device of *one* particular geometry.

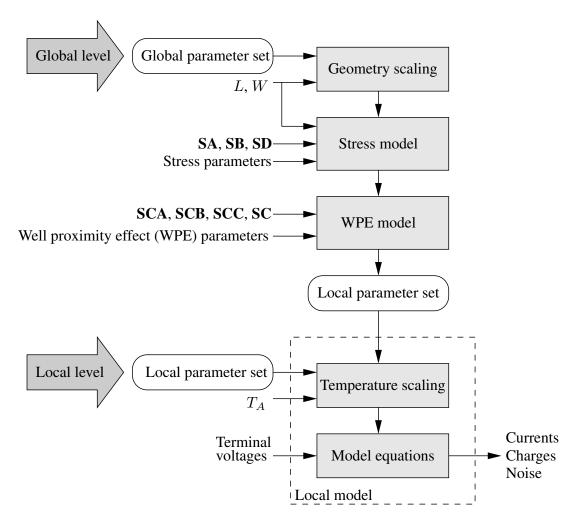


Figure 1.1: Simplified schematic overview of PSP's hierarchical structure.

Since most of these (local) parameters scale with geometry, all transistors of a particular process can be described by a (larger) set of parameters, called the *global* parameter set. An overview of the global parameters in PSP is given in Section 2.5.3. Roughly speaking, this set contains all local parameters for a long/wide device plus a number of sensitivity coefficients. From the global parameter set, one can obtain a local parameter set for a specific device by applying a set of scaling rules (see Section 3.2). The geometric properties of that specific device (such as its length and width) enter these scaling rules as *instance parameters*.

From PSP 101.0 onwards it is possible to use a set of binning rules (see Section 3.3) as an alternative to the geometrical (physics based) scaling rules. These binning rules come with their own set of parameters (see Section 2.5.4). Similar to the geometrical scaling rules, the binning rules yield a local parameter set which is used as input for the local model.

PSP is preferably used at global level when designing a circuit in a specific technology for which a global parameter set is available. On the other hand, using PSP at local level can be advantageous during parameter extraction.

As an option, it is possible to deal with the modification of transistor properties due to stress and well proximity effect (WPE). In PSP, this is implemented by additional sets of transformation rules, which are optionally applied to the intermediate local parameter set generated at the global level. The parameters associated with the stress and WPE models are consequently part of the global parameter set (both geometrical and binning).

The model structure described above is schematically depicted in Fig. 1.1.

The JUNCAP2 model is implemented in such a way that the same set of JUNCAP2 parameters can be used at

both the global and the local level. This is further explained in Section 6.4.

### 1.3 Availability

The PSP model developers (Delft University of Technology and NXP Semiconductors) distribute the PSP code in two formats:

- 1. Verilog-A code
- 2. C-code (as part of SiMKit-library)

The C-version is automatically generated from the Verilog-A version by the software package ADMS [1]. This procedure guarantees the two implementations to contain identical equations. Nevertheless—due to some specific limitations/capabilities of the two formats—there are a few minor differences, which are described in Section 6.5.

#### **1.3.1** SiMKit

*SiMKit* is a simulator-independent compact transistor model library. Simulator-specific connections are handled through so-called adapters that provide the correct interfacing to the circuit simulator of choice. Currently, adapters to the following circuit simulators are provided:

- 1. Spectre (Cadence)
- 2. Pstar (NXP Semiconductors)
- 3. ADS (Agilent)

Some other circuit simulators vendors provide their own SiMKit adapter, such that simulations with models in SiMKit are possible.

# **Section 2**

# **Constants and Parameters**

### 2.1 Nomenclature

The nomenclature of the quantities listed in the following sections has been chosen to express their purpose and their relation to other quantities and to preclude ambiguity and inconsistency. Throughout this document, all PSP parameter names are printed in boldface capitals. Parameters which refer to the long transistor limit and/or the reference temperature have a name containing an 'O', while the names of scaling parameters end with the letter 'L' and/or 'W' for length or width scaling, respectively. Parameters for temperature scaling start with 'ST', followed by the name of the parameter to which the temperature scaling applies. Parameters used for the binning model start with 'PO', 'PL', 'PW', or 'PLW', followed by the name of the local parameter they refer to.

### 2.2 Parameter clipping

For most parameters, a maximum and/or minimum value is given in the tables below. In PSP, all parameters are limited (clipped) to this pre-specified range in order to prevent difficulties in the numerical evaluation of the model, such as division by zero.

**N.B.** After computation of the scaling rules (either physical or binning), stress and well proximity effect equations, the resulting local parameters are subjected to the clipping values as given in Section 2.5.7.

### 2.3 Circuit simulator variables

#### External electrical variables

The definitions of the external electrical variables are illustrated in Fig. 2.1. The relationship between these external variables and the internal variables used in Chapter 4 is given in Fig. 6.1.

Symbol	Unit	Description					
$V_{ m D}^e$	V	Potential applied to drain node					
$V_{ m G}^e$	V	Potential applied to gate node					
$V_{ m S}^e$	V	Potential applied to source node					
$V_{ m B}^e$	V	Potential applied to bulk node					
$I_{ m D}^e$	A	DC current into drain node					
$I_{\mathrm{G}}^{e}$	Α	DC current into gate node					

... continued from previous page

Symbol	Unit	Description				
$I_{ m S}^e$	A	DC current into source node				
$I_{ m B}^e$	A	DC current into bulk node				
$S_{\mathrm{fl}}^{e}$	$A^2s$	Spectral density of flicker noise current in the channel				
$S_{\mathrm{id}}^e$	$A^2s$	Spectral density of thermal noise current in the channel				
$S_{ig,S}^e$	$A^2s$	Spectral density of induced gate noise at source side				
$S_{ig,D}^e$	$A^2s$	Spectral density of induced gate noise at drain side				
$S_{ m igs}^e$	$A^2s$	Spectral density of gate current shot noise at source side				
$S_{\mathrm{igd}}^{e}$	$A^2s$	Spectral density of gate current shot noise at drain side				
$S_{ m j,S}^e$	$A^2s$	Spectral density of source junction shot noise				
$S_{ m j,D}^e$	$A^2s$	Spectral density of drain junction shot noise				
$S_{ ext{igid}}^e$	$A^2s$	Cross spectral density between $S_{\rm id}^e$ and $(S_{\rm igS}^e$ or $S_{\rm igD}^e)$				

#### Other circuit simulator variables

Next to the electrical variables described above, the quantities in the table below are also provided to the model by the circuit simulator.

Symbol	Unit	Description			
$T_{ m A}$	°C	Ambient circuit temperature			
$f_{ m op}$	Hz	Operation frequency			

### 2.4 Model constants

In the following table the symbolic representation, the value and the description of the various physical constants used in the PSP model are given.

No.	Symbol	Unit	Value	Description
1	$T_0$	K	273.15	Offset between Celsius and Kelvin temperature scale
2	$k_{\mathrm{B}}$	J/K	$1.3806505 \cdot 10^{-23}$	Boltzmann constant
3	$\hbar$	J s	$1.05457168 \cdot 10^{-34}$	Reduced Planck constant
4	q	С	$1.6021918 \cdot 10^{-19}$	Elementary unit charge
5	$m_0$	kg	$9.1093826 \cdot 10^{-31}$	Electron rest mass
6	$\epsilon_0$	F/m	$8.85418782 \cdot 10^{-12}$	Permittivity of free space
7	$\epsilon_{ m r,Si}$	_	11.8	Relative permittivity of silicon
8	$QM_{ m N}$	$V m^{\frac{4}{3}} C^{-\frac{2}{3}}$	5.951993	Constant of quantum-mechanical behavior of electrons
9	$QM_{ m P}$	$V m^{\frac{4}{3}} C^{-\frac{2}{3}}$	7.448711	Constant of quantum-mechanical behavior of holes

### 2.5 Model parameters

In this section all parameters of the PSP-model are described. The parameters for the intrinsic MOS model, the stress and well proximity effect models and the junction model are given in separate tables. The complete

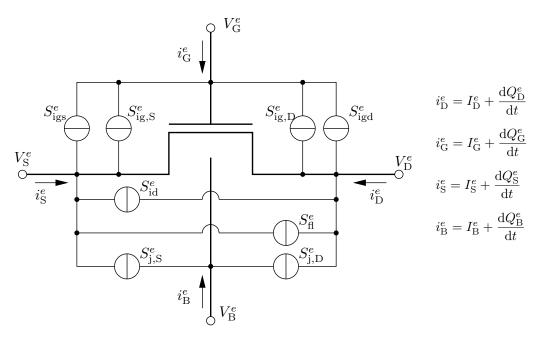


Figure 2.1: Definition of external electrical quantities.

parameter list for each of the model entry levels is composed of several parts, as indicated in the table below.

Entry level	Sections
Global (geometrical scaling)	2.5.1 (instance parameters)
	2.5.3 (intrinsic MOS)
	2.5.5 (stress)
	2.5.6 (well proximity effect)
	2.5.8 (junctions)
	2.5.9 (parasitic resistances)
Binning	2.5.1 (instance parameters)
	2.5.4 (intrinsic MOS)
	2.5.5 (stress)
	2.5.6 (well proximity effect)
	2.5.8 (junctions)
	2.5.9 (parasitic resistances)
Local	2.5.2 (instance parameters)
	2.5.7 (intrinsic MOS)
	2.5.8 (junctions)
	2.5.9 (parasitic resistances)

### 2.5.1 Instance parameters for global and binning model

No.	Name	Unit	Default	Min.	Max.	Description	
0	L	m	$10^{-6}$	$10^{-9}$	_	Drawn channel length	
1	W	m	$10^{-6}$	$10^{-9}$	_	Drawn channel width (total width)	
2	ABSOURCE	$m^2$	$10^{-12}$	0	_	Source junction area	

... continued from previous page

No.	Name	Unit	Default	Min.	Max.	Description	
3	LSSOURCE	m	$10^{-6}$	0	_	STI-edge part of source junction perimeter	
4	LGSOURCE	m	$10^{-6}$	0	_	Gate-edge part of source junction perimeter	
5	ABDRAIN	$m^2$	$10^{-12}$	0	_	Drain junction area	
6	LSDRAIN	m	$10^{-6}$	0	_	STI-edge part of drain junction perimeter	
7	LGDRAIN	m	$10^{-6}$	0	_	Gate-edge part of drain junction perimeter	
8	AS	$m^2$	$10^{-12}$	0	_	Source junction area (alternative spec.)	
9	PS	m	$10^{-6}$	0	_	Source STI-edge perimeter (alternative spec.)	
10	AD	$m^2$	$10^{-12}$	0	_	Drain junction area (alternative spec.)	
11	PD	m	$10^{-6}$	0	_	Drain STI-edge perimeter (alternative spec.)	
12	DELVTO	V	0	_	_	Threshold voltage shift parameter	
13	FACTUO	_	1	0	_	Zero-field mobility pre-factor	
14	SA	m	0	_	_	Distance between OD-edge and poly at source side	
15	SB	m	0	_	_	Distance between OD-edge and poly at drain side	
16	SD	m	0	_	_	Distance between neighboring fingers	
17	SCA	_	0	0	_	Integral of the first distribution function for scattered well dopant	
18	SCB	_	0	0	_	Integral of the second distribution function for scattered well dopant	
19	SCC	_	0	0	_	Integral of the third distribution function for scattered well dopant	
20	SC	m	0	_	_	Distance between OD edge and nearest well edge	
21	NGCON	-	1	1	2	Number of gate contacts	
22	XGW	m	$10^{-7}$	_	_	Distance from the gate contact to the channel edge	
23	NF	_	1	1	_	Number of fingers; internally rounded to the nearest integer	
24	MULT	_	1	0	_	Number of devices in parallel	

Note that if both **SA** and **SB** are set to 0 the stress-equations are not computed. If **SCA**, **SCB**, **SCC** and **SC** are all set to 0 the well proximity effect equations are not computed.

The switching parameter **SWJUNCAP** is used to determine the meaning and usage of the junction instance parameters, where **AB** (junction area), **LS** (STI-edge part of junction perimeter), and **LG** (gate-edge part of junction perimeter) are the instance parameters of a single instance (source or drain) of the JUNCAP2 model.

		source			drain	
SWJUNCAP	AB	LS	LG	AB	LS	LG
0	0	0	0	0	0	0
1	ABSOURCE	LSSOURCE	LGSOURCE	ABDRAIN	LSDRAIN	LGDRAIN
2	AS	PS	$W_{ m E}$	AD	PD	$W_{ m E}$
3	AS	$\mathbf{PS} - W_{\mathrm{E}}$	$W_{ m E}$	AD	$\mathbf{PD} - W_{\mathrm{E}}$	$W_{ m E}$

### 2.5.2 Instance parameters for local model

As explained in Section 6.4, the instance parameters for the JUNCAP2 model are used at the local level as well.

No.	Name	Unit	Default	Min.	Max.	Description
0	ABSOURCE	$m^2$	$1 \cdot 10^{-12}$	0	_	Source junction area
1	LSSOURCE	m	$1 \cdot 10^{-6}$	0	_	STI-edge part of source junction perimeter
2	LGSOURCE	m	$1 \cdot 10^{-6}$	0	_	Gate-edge part of source junction perimeter
3	ABDRAIN	$m^2$	$1 \cdot 10^{-12}$	0	_	Drain junction area
4	LSDRAIN	m	$1 \cdot 10^{-6}$	0	_	STI-edge part of drain junction perimeter
5	LGDRAIN	m	$1 \cdot 10^{-6}$	0	_	Gate-edge part of drain junction perimeter
6	AS	$m^2$	$1 \cdot 10^{-12}$	0	_	Source junction area (alternative spec.)
7	PS	m	$1 \cdot 10^{-6}$	0	_	Source STI-edge perimeter (alternative spec.)
8	AD	$m^2$	$1 \cdot 10^{-12}$	0	_	Drain junction area (alternative spec.)
9	PD	m	$1 \cdot 10^{-6}$	0	_	Drain STI-edge perimeter (alternative spec.)
10	JW	m	$1 \cdot 10^{-6}$	0	_	Junction width
11	DELVTO	V	0	_	_	Threshold voltage shift parameter
12	FACTUO	_	1	0		Zero-field mobility pre-factor
13	MULT	_	1	0	_	Number of devices in parallel

Also at the local level, the switching parameter **SWJUNCAP** is used to determine the meaning and usage of the junction instance parameters, where **AB** (junction area), **LS** (STI-edge part of junction perimeter), and **LG** (gate-edge part of junction perimeter) are the instance parameters of a single instance (source or drain) of the JUNCAP2 model. Because the transistor width W is not available at the local level, an additional instance parameter **JW** (junction width) is required when **SWJUNCAP** = 2 or 3.

		source		drain			
SWJUNCAP	AB	LS	LG	AB	LS	LG	
0	0	0	0	0	0	0	
1	ABSOURCE	LSSOURCE	LGSOURCE	ABDRAIN	LSDRAIN	LGDRAIN	
2	AS	PS	JW	AD	PD	JW	
3	AS	PS - JW	JW	AD	PD – JW	JW	

### 2.5.3 Parameters for global model (physical geometrical scaling rules)

The physical geometry scaling rules of PSP (see Section 3.2) have been developed to give a good description over the whole geometry range of CMOS technologies.

No.	Name	Unit	Default	Min.	Max.	Description					
0	LEVEL	_	1020	_	_	Model selection parameter; see Sec. 6.1					
1	ТҮРЕ	_	1	-1	1	Channel type parameter; $1 \leftrightarrow \text{NMOS}, -1 \leftrightarrow \text{PMOS}^1$					
2	TR	°C	21	-273	_	Reference temperature					
	Switch Parameters										
3	PARAMCHK	-	0	_	_	Level of clip-warning info <sup>2</sup>					
4	SWIGATE	-	0	0	1	Flag for gate current $(0 \leftrightarrow \text{``off''})$					
5	SWIMPACT	Ι	0	0	1	Flag for impact ionization current (0 $\leftrightarrow$ "off")					
6	SWGIDL	_	0	0	1	Flag for GIDL/GISL current (0 $\leftrightarrow$ "off")					
7	SWJUNCAP	-	0	0	3	Flag for JUNCAP (0 $\leftrightarrow$ "off"); see Sec. 2.5.1					
8	SWJUNASYM	_	0	_	_	Flag for asymmetric junctions $(0 \leftrightarrow \text{"off"})^3$					
9	QMC	_	1	0	_	Quantum-mechanical correction factor					
			Pro	cess Para	ameters						
10	LVARO	m	0	_	_	Geometry independent difference between actual and programmed poly-silicon gate length					
11	LVARL	_	0	_	_	Length dependence of $\Delta L_{ m PS}$					
12	LVARW	1	0	_	_	Width dependence of $\Delta L_{ m PS}$					
13	LAP	m	0	_	_	Effective channel length reduction per side due to lateral diffusion of source/drain dopant ions					
14	WVARO	m	0	_	_	Geometry independent difference between actual and programmed field-oxide opening					
15	WVARL	_	0	_	_	Length dependence of $\Delta W_{ m OD}$					
16	WVARW	_	0	_	_	Width dependence of $\Delta W_{ m OD}$					
17	WOT	m	0	_	_	Effective reduction of channel width per side due to lateral diffusion of channel-stop dopant ions					
18	DLQ	m	0	_	_	Effective channel length offset for CV					
19	DWQ	m	0	_	_	Effective channel width offset for CV					
20	VFBO	V	-1	_	_	Geometry-independent flat-band voltage at <b>TR</b>					
21	VFBL	_	0	_	_	Length dependence VFB					

<sup>&</sup>lt;sup>1</sup>See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

<sup>&</sup>lt;sup>2</sup>Only in SiMKit-version of PSP. See Section 6.5.4 for more information.

<sup>&</sup>lt;sup>3</sup>See Section 3.7 for more information on usage of **SWJUNASYM**.

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No.	tinued from previous p	Unit	Default	Min.	Max.	Description
22	VFBW	_	0		_	Width dependence of <b>VFB</b>
23	VFBLW	_	0	_	_	Area dependence of <b>VFB</b>
24	STVFBO	V/K	$5 \cdot 10^{-4}$	_	_	Geometry-independent temperature dependence of VFB
25	STVFBL	_	0	_	_	Length dependence of STVFB
26	STVFBW	_	0	_		Width dependence of STVFB
27	STVFBLW	_	0	_		Area dependence of STVFB
28	TOXO	m	$2 \cdot 10^{-9}$	$10^{-10}$	_	Gate oxide thickness
29	EPSROXO	_	3.9	1	_	Relative permittivity of gate dielectric
30	NSUBO	m <sup>-3</sup>	$3 \cdot 10^{23}$	$10^{20}$	_	Geometry independent substrate doping
31	NSUBW	_	0	_	_	Width dependence of substrate doping due to segregation
32	WSEG	m	$10^{-8}$	$10^{-10}$	_	Characteristic length for segregation of substrate doping
33	NPCK	$\mathrm{m}^{-3}$	$10^{24}$	0	_	Pocket doping level
34	NPCKW	_	0	_	_	Width dependence of <b>NPCK</b> due to segregation
35	WSEGP	m	$10^{-8}$	$10^{-10}$	_	Characteristic length for segregation of pocket doping
36	LPCK	m	$10^{-8}$	$10^{-10}$	_	Characteristic length for lateral doping profile
37	LPCKW	_	0	_	_	Width dependence of <b>LPCK</b> due to segregation
38	FOL1	_	0	_	_	First order length dependence of short channel body-effect
39	FOL2	_	0	_		Second order length dependence of short channel body-effect
40	VNSUBO	V	0	_		Effective doping bias-dependence parameter
41	NSLPO	V	0.05	_	_	Effective doping bias-dependence parameter
42	DNSUBO	$V^{-1}$	0	_	_	Effective doping bias-dependence parameter
43	DPHIBO	V	0	_	_	Geometry independent offset of $arphi_{\mathrm{B}}$
44	DPHIBL	V	0	_	_	Length dependence of <b>DPHIB</b>
45	DPHIBLEXP	_	1	_	_	Exponent for length dependence of <b>DPHIB</b>
46	DPHIBW	-	0	_	_	Width dependence of <b>DPHIB</b>
47	DPHIBLW		0	_	_	Area dependence of <b>DPHIB</b>
48	NPO	$\mathrm{m}^{-3}$	$10^{26}$		_	Geometry-independent gate poly-silicon doping
49	NPL	_	0	_	_	Length dependence of NP

	tinued from previous	_	1							
No.	Name	Unit	Default	Min.	Max.	Description				
50	СТО	_	0	_	_	Geometry-independent part of interface states factor CT				
51	CTL	-	0	_	_	Length dependence of CT				
52	CTLEXP	_	1	_	_	Exponent describing length dependence of <b>CT</b>				
53	CTW	_	0	_	_	Width dependence of CT				
54	CTLW	_	0	_	_	Area dependence of CT				
55	TOXOVO	m	$2 \cdot 10^{-9}$	$10^{-10}$	ı	Overlap oxide thickness				
56	TOXOVDO	m	$2 \cdot 10^{-9}$	$10^{-10}$	_	Overlap oxide thickness for drain side				
57	LOV	m	0	0	1	Overlap length for overlap capacitance				
58	LOVD	m	0	0	_	Overlap length for gate/drain overlap capacitance				
59	NOVO	$\mathrm{m}^{-3}$	$5 \cdot 10^{25}$	_	_	Effective doping of overlap region				
60	NOVDO	$\mathrm{m}^{-3}$	$5 \cdot 10^{25}$	_	_	Effective doping of overlap region for drain side				
	DIBL-Parameters									
61	CFL	$V^{-1}$	0	_	_	Length dependence of DIBL-parameter				
62	CFLEXP		2	_	_	Exponent for length dependence of CF				
63	CFW	_	0	_	_	Width dependence of CF				
64	CFBO	$V^{-1}$	0	_	_	Back-bias dependence of <b>CF</b>				
	Mobility Parameters									
65	UO	m <sup>2</sup> /V/s	$5 \cdot 10^{-2}$	_	_	Zero-field mobility at TR				
66	FBET1	_	0	_	<u> </u>	Relative mobility decrease due to first lateral profile				
67	FBET1W		0	_	_	Width dependence of <b>FBET1</b>				
68	LP1	m	$10^{-8}$	$10^{-10}$	_	Mobility-related characteristic length of first lateral profile				
69	LP1W	_	0	_	_	Width dependence of LP1				
70	FBET2	_	0	_	_	Relative mobility decrease due to second lateral profile				
71	LP2	m	$10^{-8}$	$10^{-10}$	_	Mobility-related characteristic length of second lateral profile				
72	BETW1	_	0	_		First higher-order width scaling coefficient of <b>BETN</b>				
73	BETW2	_	0	_	_	Second higher-order width scaling coefficient of <b>BETN</b>				
74	WBET	m	10-9	$10^{-10}$	_	Characteristic width for width scaling of <b>BETN</b>				
75	STBETO	_	1	_	_	Geometry independent temperature dependence of <b>BETN</b>				
76	STBETL	_	0	_	_	Length dependence of STBET				
77	STBETW	_	0	_	_	Width dependence of STBET				

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No.		continued from previous page								
	Name	Unit	Default	Min.	Max.	Description				
78	STBETLW	_	0	_	_	Area dependence of <b>STBET</b>				
79	MUEO	m/V	0.5	_	_	Geometry independent mobility reduction coefficient at <b>TR</b>				
80	MUEW	_	0	_	_	Width dependence of MUE				
81	STMUEO	_	0	_	_	Temperature dependence of MUE				
82	THEMUO	_	1.5	0	_	Mobility reduction exponent at <b>TR</b>				
83	STTHEMUO	_	1.5	_	_	Temperature dependence of <b>THEMU</b>				
84	CSO	-	0	_	_	Geometry independent Coulomb scattering parameter at <b>TR</b>				
85	CSL	_	0	_	_	Length dependence of CS				
86	CSLEXP	_	0	_	_	Exponent for length dependence of CS				
87	CSW	_	0	_	_	Width dependence of CS				
88	CSLW	_	0	_	_	Area dependence of CS				
89	STCSO	_	0	_	_	Temperature dependence of <b>CS</b>				
90	XCORO	$V^{-1}$	0	_	_	Geometry independent non-universality parameter				
91	XCORL	_	0	_	_	Length dependence of <b>XCOR</b>				
92	XCORW	_	0	_	_	Width dependence of <b>XCOR</b>				
93	XCORLW	_	0	_	_	Area dependence of <b>XCOR</b>				
94	STXCORO	_	0	_	_	Temperature dependence of <b>XCOR</b>				
95	FETAO	_	1	_	_	Effective field parameter				
			Series R	esistance	Parame	eters				
96	RSW1	Ω	2500	_	_	Source/drain series resistance for channel width $W_{\rm EN}$ at ${\bf TR}$				
97	RSW2	-	0	_	_	Higher-order width scaling of source/drain series resistance				
98	STRSO	_	1	_	_	Temperature dependence of <b>RS</b>				
99	RSBO	$V^{-1}$	0	_	_	Back-bias dependence of <b>RS</b>				
100	RSGO	$V^{-1}$	0	_	_	Gate-bias dependence of <b>RS</b>				
			Velocity S	Saturatio	n Paran	neters				
101	THESATO	$V^{-1}$	0	_	_	Geometry independent velocity saturation parameter at <b>TR</b>				
102	THESATL	$V^{-1}$	0.05	_	_	Length dependence of THESAT				
103	THESATLEXP	_	1	_	_	Exponent for length dependence of <b>THE-SAT</b>				
104	THESATW	_	0	_	_	Width dependence of THESAT				
105	THESATLW	_	0	_	_	Area dependence THESAT				
106	STTHESATO	_	1	_	_	Geometry independent temperature dependence of <b>THESAT</b>				
107	STTHESATL	_	0	_	_	Length dependence of STTHESAT				
108	STTHESATW	_	0	_	_	Width dependence of STTHESAT				

continued from previous page									
No.	Name	Unit	Default	Min.	Max.	Description			
109	STTHESATLW	_	0	_	_	Area dependence of STTHESAT			
110	THESATBO	$V^{-1}$	0	_	_	Back-bias dependence of <b>THESAT</b>			
111	THESATGO	$V^{-1}$	0	_	_	Gate-bias dependence of THESAT			
	Saturation Voltage Parameters								
112	AXO	_	18	_	_	Geometry independent linear/saturation transition factor			
113	AXL	_	0.4	0	_	Length dependence of <b>AX</b>			
'		Channe	el Length N		on (CLM	1) Parameters			
114	ALPL	_	$5 \cdot 10^{-4}$	_	_	Length dependence of CLM pre-factor ALP			
115	ALPLEXP	_	1	_	_	Exponent for length dependence of <b>ALP</b>			
116	ALPW	-	0	_	_	Width dependence of ALP			
117	ALP1L1	V	0	_	_	Length dependence of CLM enhancement factor above threshold			
118	ALP1LEXP	-	0.5	_	_	Exponent describing the length dependence of <b>ALP1</b>			
119	ALP1L2	_	0	0	_	Second order length dependence of ALP1			
120	ALP1W	_	0	_	_	Width dependence of ALP1			
121	ALP2L1	V	0	_	_	Length dependence of CLM enhancement factor below threshold			
122	ALP2LEXP	_	0.5	_	_	Exponent describing the length dependence <b>ALP2</b>			
123	ALP2L2	_	0	0	_	Second order length dependence of ALP2			
124	ALP2W	_	0	_	_	Width dependence of ALP2			
125	VPO	V	0.05	_	_	CLM logarithmic dependence parameter			
			Impact Ion	nization (	II) Para	meters			
126	A10	_	1	_	_	Geometry independent part of impactionization pre-factor A1			
127	A1L	-	0	_	_	Length dependence of A1			
128	A1W	_	0	_	_	Width dependence of A1			
129	A2O	V	10	_	_	Impact-ionization exponent at TR			
130	STA2O	V	0	_	_	Temperature dependence of A2			
131	A30	_	1.0	_	_	Geometry independent saturation-voltage dependence of II			
132	A3L	_	0	_	_	Length dependence of A3			
133	A3W	_	0	_	_	Width dependence of A3			
134	A40	$V^{-\frac{1}{2}}$	0	_	_	Geometry independent back-bias dependence of II			
135	A4L	_	0	_	_	Length dependence of A4			
136	A4W	-	0	_	_	Width dependence of A4			
			Gate C	Current I	Paramete	ers			

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	tinued from previous		D 4 -	3.50	1	B
No.	Name	Unit	Default	Min.	Max.	Description
137	GCOO	_	0	_	_	Gate tunneling energy adjustment
138	IGINVLW	A	0	_	_	Gate channel current pre-factor for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$
139	IGOVW	A	0	_	_	Gate overlap current pre-factor for a channel width of $W_{\mathrm{EN}}$
140	IGOVDW	A	0	_	_	Gate overlap current pre-factor for a channel width of $W_{\rm EN}$ for drain side
141	STIGO	_	2	_	_	Temperature dependence of gate current
142	GC2O	_	0.375	_	_	Gate current slope factor
143	GC3O	_	0.063	_	_	Gate current curvature factor
144	СНІВО	V	3.1	_	_	Tunneling barrier height
		Gate-In	duced Dra	in Leaka	ge (GID	L) Parameters
145	AGIDLW	A/V <sup>3</sup>	0	_	_	Width dependence of GIDL pre-factor
146	AGIDLDW	A/V <sup>3</sup>	0	_	_	Width dependence of GIDL pre-factor for drain side
147	BGIDLO	V	41	_	_	GIDL probability factor at TR
148	BGIDLDO	V	41	_	_	GIDL probability factor at <b>TR</b> for drain side
149	STBGIDLO	V/K	0	_	_	Temperature dependence of <b>BGIDL</b>
150	STBGIDLDO	V/K	0	_	_	Temperature dependence of <b>BGIDL</b> for drain side
151	CGIDLO	_	0	_	_	Back-bias dependence of GIDL
152	CGIDLDO	_	0	_	_	Back-bias dependence of GIDL for drain side
		1	Charge	Model 1	Paramet	ers
153	CGBOVL	F	0	_	_	Oxide capacitance for gate–bulk overlap for a channel length of $L_{ m EN}$
154	CFRW	F	0	_	_	Outer fringe capacitance for a channel width of $W_{\mathrm{EN}}$
155	CFRDW	F	0	_	_	Outer fringe capacitance for a channel width of $W_{\mathrm{EN}}$ for drain side
			Noise	Model P	aramete	ers
156	FNTO	_	1.0	_	_	Thermal noise coefficient
157	NFALW	$V^{-1}/m^4$	$8 \cdot 10^{22}$	_	_	First coefficient of flicker noise for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$
158	NFBLW	$V^{-1}/m^2$	$3 \cdot 10^7$	_	_	Second coefficient of flicker noise for a channel area of $W_{\rm EN} \cdot L_{\rm EN}$
159	NFCLW	$V^{-1}$	0	_	_	Third coefficient of flicker noise for a channel area of $W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}$
160	EFO	_	1.0	_		Flicker noise frequency exponent
161	LINTNOI	m	0.0	_	_	Length offset for flicker noise
162	ALPNOI	_	2.0	_	_	Exponent for length offset for flicker noise

No.	Name	Unit	Default	Min.	Max.	Description				
	Other Parameters									
163	DTA	K	0	_	_	Temperature offset w.r.t. ambient circuit temperature				

### 2.5.4 Parameters for binning model

The binning scaling rules of PSP (see Section 3.3) have been developed as a flexible but phenomenological alternative to the geometrical scaling rules.

No.	Name	Unit	Default	Min.	Max.	Description					
0	LEVEL	_	1021	_	_	Model selection parameter; see Sec. 6.1					
1	ТҮРЕ	_	1	-1	1	Channel type parameter; $1 \leftrightarrow NMOS, -1 \leftrightarrow PMOS^4$					
2	TR	°C	21	-273	_	reference temperature					
	Switch Parameters										
3	PARAMCHK	_	0	_	_	Level of clip-warning info <sup>5</sup>					
4	SWIGATE	_	0	0	1	Flag for gate current (0 $\leftrightarrow$ "off")					
5	SWIMPACT	-	0	0	1	Flag for impact ionization current (0 $\leftrightarrow$ "off")					
6	SWGIDL	_	0	0	1	Flag for GIDL/GISL current (0 $\leftrightarrow$ "off")					
7	SWJUNCAP	-	0	0	3	Flag for JUNCAP (0 $\leftrightarrow$ "off"); see Sec. 2.5.2					
8	SWJUNASYM	-	0	_	_	Flag for asymmetric junctions $(0 \leftrightarrow \text{``off''})^6$					
9	QMC	_	1	0	_	Quantum-mechanical correction factor					
	I		Labels	for bing	ing set						
10	LMIN	m	0	_	-	Dummy parameter to label binning set					
11	LMAX	m	1	_	_	Dummy parameter to label binning set					
12	WMIN	m	0	_	_	Dummy parameter to label binning set					
13	WMAX	m	1	_	_	Dummy parameter to label binning set					
			Proce	ess Paran	neters						
14	LVARO	m	0	_	_	Geometry independent difference between actual and programmed poly-silicon gate length					
15	LVARL	_	0	_	_	Length dependence of difference between actual and programmed poly-silicon gate length					
16	LAP	m	0	_	_	Effective channel length reduction per side due to lateral diffusion of source/drain dopant ions					
17	WVARO	m	0	_	_	Geometry independent difference between actual and programmed field-oxide opening					
18	WVARW	_	0	_	_	Width dependence of difference between actual and programmed field-oxide opening					

<sup>&</sup>lt;sup>4</sup>See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

<sup>&</sup>lt;sup>5</sup>Only in SiMKit-version of PSP. See Section 6.5.4 for more information.

<sup>&</sup>lt;sup>6</sup>See Section 3.7 for more information on usage of **SWJUNASYM**.

	continued from previous page									
No.	Name	Unit	Default	Min.	Max.	Description				
19	WOT	m	0	_	_	Effective reduction of channel width per side due to lateral diffusion of channel-stop dopant ions				
20	DLQ	m	0	_	_	Effective channel length reduction for CV				
21	DWQ	m	0	_	_	Effective channel width reduction for CV				
22	POVFB	V	-1	_	_	Coefficient for the geometry independent part of flat-band voltage at <b>TR</b>				
23	PLVFB	V	0	_	_	Coefficient for the length dependence of flat-band voltage at <b>TR</b>				
24	PWVFB	V	0	_	_	Coefficient for the width dependence of flat-band voltage at <b>TR</b>				
25	PLWVFB	V	0	_	_	Coefficient for the length times width dependence of flat-band voltage at <b>TR</b>				
26	POSTVFB	V/K	$5 \cdot 10^{-4}$	_	_	Coefficient for the geometry independent part of temperature dependence of VFB				
27	PLSTVFB	V/K	0	_	_	Coefficient for the length dependence of temperature dependence of <b>VFB</b>				
28	PWSTVFB	V/K	0	_	_	Coefficient for the width dependence of temperature dependence of <b>VFB</b>				
29	PLWSTVFB	V/K	0	_	_	Coefficient for the length times width dependence of temperature dependence of <b>VFB</b>				
30	POTOX	m	$2 \cdot 10^{-9}$	_	_	Coefficient for the geometry independent part of gate oxide thickness				
31	POEPSROX	-	3.9	1	_	Coefficient for the geometry independent part of relative permittivity of gate dielectric				
32	PONEFF	m <sup>-3</sup>	$5 \cdot 10^{23}$	_	_	Coefficient for the geometry independent part of substrate doping				
33	PLNEFF	m <sup>-3</sup>	0	_	_	Coefficient for the length dependence of substrate doping				
34	PWNEFF	m <sup>-3</sup>	0	_	_	Coefficient for the width dependence of substrate doping				
35	PLWNEFF	$\mathrm{m}^{-3}$	0	_	_	Coefficient for the length times width dependence of substrate doping				
36	POVNSUB	V	0	_	_	Coefficient for the geometry independent part of effective doping bias-dependence parameter				
37	PONSLP	V	$5 \cdot 10^{-2}$	_	_	Coefficient for the geometry independent part of effective doping bias-dependence parameter				
38	PODNSUB	V <sup>-1</sup>	0	_	_	Coefficient for the geometry independent part of effective doping bias-dependence parameter				

	ntinued from previous p	1	D.C. I	3.51	3.5	D
No.	Name	Unit	Default	Min.	Max.	Description
39	PODPHIB	V	0	_	_	Coefficient for the geometry independent part of offset of $\phi_{\rm B}$
40	PLDPHIB	V	0	_	_	Coefficient for the length dependence of offset of $\phi_{\rm B}$
41	PWDPHIB	V	0	_	_	Coefficient for the width dependence of offset of $\phi_{\mathrm{B}}$
42	PLWDPHIB	V	0	_	_	Coefficient for the length times width dependence of offset of $\phi_{\rm B}$
43	PONP	$m^{-3}$	$10^{26}$	_	_	Coefficient for the geometry independent part of gate poly-silicon doping
44	PLNP	$m^{-3}$	0	_	_	Coefficient for the length dependence of gate poly-silicon doping
45	PWNP	m <sup>-3</sup>	0	_	_	Coefficient for the width dependence of gate poly-silicon doping
46	PLWNP	m <sup>-3</sup>	0	_	_	Coefficient for the length times width dependence of gate poly-silicon doping
47	POCT	_	0	_	_	Coefficient for the geometry independent part of interface states factor
48	PLCT	_	0	_	_	Coefficient for the length dependence of interface states factor
49	PWCT	_	0	_	_	Coefficient for the width dependence of interface states factor
50	PLWCT	_	0	_	_	Coefficient for the length times width dependence of interface states factor
51	POTOXOV	m	$2 \cdot 10^{-9}$	_	_	Coefficient for the geometry independent part of overlap oxide thickness
52	POTOXOVD	m	$2 \cdot 10^{-9}$	_	_	Coefficient for the geometry independent part of overlap oxide thickness for drain side
53	PONOV	m <sup>-3</sup>	$5 \cdot 10^{25}$	_	_	Coefficient for the geometry independent part of effective doping of overlap region
54	PLNOV	m <sup>-3</sup>	0	_		Coefficient for the length dependence of effective doping of overlap region
55	PWNOV	$\mathrm{m}^{-3}$	0	_	_	Coefficient for the width dependence of effective doping of overlap region
56	PLWNOV	$\mathrm{m}^{-3}$	0	_	_	Coefficient for the length times width dependence of effective doping of overlap region
57	PONOVD	$\mathrm{m}^{-3}$	$5 \cdot 10^{25}$	_	_	Coefficient for the geometry independent part of effective doping of overlap region for drain side
58	PLNOVD	$\mathrm{m}^{-3}$	0	_	_	Coefficient for the length dependence of effective doping of overlap region for drain side

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No.	Name	Unit	Default	Min.	Max.	Description			
59	PWNOVD	m <sup>-3</sup>	0	_	_	Coefficient for the width dependence of effective doping of overlap region for drain side			
60	PLWNOVD	$\mathrm{m}^{-3}$	0	_	_	Coefficient for the length times width dependence of effective doping of overlap region for drain side			
			DIB	L Param	eters	_			
61	POCF	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of DIBL parameter			
62	PLCF	$V^{-1}$	0	_	_	Coefficient for the length dependence of DIBL parameter			
63	PWCF	$V^{-1}$	0	_	_	Coefficient for the width dependence of DIBL parameter			
64	PLWCF	$V^{-1}$	0	_	_	Coefficient for the length times width dependence of DIBL parameter			
65	POCFB	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of back-bias dependence of <b>CF</b>			
	Mobility Parameters								
66	POBETN	m <sup>2</sup> /V/s	$7 \cdot 10^{-2}$	_	_	Coefficient for the geometry independent part of product of channel aspect ratio and zero-field mobility at <b>TR</b>			
67	PLBETN	m <sup>2</sup> /V/s	0	_	_	Coefficient for the length dependence of product of channel aspect ratio and zero-field mobility at <b>TR</b>			
68	PWBETN	m <sup>2</sup> /V/s	0	_	_	Coefficient for the width dependence of product of channel aspect ratio and zero-field mobility at <b>TR</b>			
69	PLWBETN	m <sup>2</sup> /V/s	0	_	_	Coefficient for the length times width dependence of product of channel aspect ratio and zero-field mobility at <b>TR</b>			
70	POSTBET	-	1	_	_	Coefficient for the geometry independent part of temperature dependence of <b>BETN</b>			
71	PLSTBET	_	0	_	_	Coefficient for the length dependence of temperature dependence of <b>BETN</b>			
72	PWSTBET	_	0	_	_	Coefficient for the width dependence of temperature dependence of <b>BETN</b>			
73	PLWSTBET	_	0	_	_	Coefficient for the length times width dependence of temperature dependence of <b>BETN</b>			
74	POMUE	m/V	$5\cdot 10^{-1}$	_	_	Coefficient for the geometry independent part of mobility reduction coefficient at <b>TR</b>			
75	PLMUE	m/V	0	_	_	Coefficient for the length dependence of mobility reduction coefficient at <b>TR</b>			
76	PWMUE	m/V	0	_	_	Coefficient for the width dependence of mobility reduction coefficient at <b>TR</b>			

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No.	Name	Unit	Default	Min.	Max.	Description
77	PLWMUE	m/V	0	_	_	Coefficient for the length times width dependence of mobility reduction coefficient at <b>TR</b>
78	POSTMUE	_	0	_	_	Coefficient for the geometry independent part of temperature dependence of MUE
79	POTHEMU	-	1.5	_	_	Coefficient for the geometry independent part of mobility reduction exponent at <b>TR</b>
80	POSTTHEMU	_	1.5	_	_	Coefficient for the geometry independent part of temperature dependence of <b>THEMU</b>
81	POCS	_	0	_	_	Coefficient for the geometry independent part of Coulomb scattering parameter at <b>TR</b>
82	PLCS	_	0	_	_	Coefficient for the length dependence of Coulomb scattering parameter at <b>TR</b>
83	PWCS	_	0	_	_	Coefficient for the width dependence of Coulomb scattering parameter at <b>TR</b>
84	PLWCS	_	0	_	_	Coefficient for the length times width dependence of Coulomb scattering parameter at <b>TR</b>
85	POSTCS	_	0	_	_	Coefficient for the geometry independent part of temperature dependence of <b>CS</b>
86	POXCOR	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of non-universality parameter
87	PLXCOR	$V^{-1}$	0	_	_	Coefficient for the length dependence of non-universality parameter
88	PWXCOR	$V^{-1}$	0	_	_	Coefficient for the width dependence of non-universality parameter
89	PLWXCOR	$V^{-1}$	0	_	_	Coefficient for the length times width dependence of non-universality parameter
90	POSTXCOR	_	0	_	_	Coefficient for the geometry independent part of temperature dependence of <b>XCOR</b>
91	POFETA	_	1	_	_	Coefficient for the geometry independent part of effective field parameter
			Series Res	istance I	Paramet	ers
92	PORS	Ω	30	_	_	Coefficient for the geometry independent part of source/drain series resistance at <b>TR</b>
93	PLRS	Ω	0	_	_	Coefficient for the length dependence of source/drain series resistance at <b>TR</b>
94	PWRS	Ω	0	_	_	Coefficient for the width dependence of source/drain series resistance at <b>TR</b>
95	PLWRS	Ω	0	_	_	Coefficient for the length times width dependence of source/drain series resistance at <b>TR</b>

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No.	Name	Unit	Default	Min.	Max.	Description		
96	POSTRS	_	1	_	_	Coefficient for the geometry independent part of temperature dependence of <b>RS</b>		
97	PORSB	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of back-bias dependence of <b>RS</b>		
98	PORSG	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of gate-bias dependence of <b>RS</b>		
			Velocity Sa	turation	Parame	ters		
99	POTHESAT	$V^{-1}$	1	_	_	Coefficient for the geometry independent part of velocity saturation parameter at <b>TR</b>		
100	PLTHESAT	$V^{-1}$	0	_	_	Coefficient for the length dependence of velocity saturation parameter at <b>TR</b>		
101	PWTHESAT	$V^{-1}$	0	_	_	Coefficient for the width dependence of velocity saturation parameter at <b>TR</b>		
102	PLWTHESAT	$V^{-1}$	0	_	_	Coefficient for the length times width dependence of velocity saturation parameter at <b>TR</b>		
103	POSTTHESAT	-	1	_	_	Coefficient for the geometry independent part of temperature dependence of <b>THE-SAT</b>		
104	PLSTTHESAT	_	0	_	_	Coefficient for the length dependence of temperature dependence of <b>THESAT</b>		
105	PWSTTHESAT	_	0	_	_	Coefficient for the width dependence of temperature dependence of <b>THESAT</b>		
106	PLWSTTHESAT		0	_	_	Coefficient for the length times width dependence of temperature dependence of <b>THESAT</b>		
107	POTHESATB	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of back-bias dependence of velocity saturation		
108	PLTHESATB	$V^{-1}$	0	_	_	Coefficient for the length dependence of back-bias dependence of velocity saturation		
109	PWTHESATB	$V^{-1}$	0	_	_	Coefficient for the width dependence of back-bias dependence of velocity saturation		
110	PLWTHESATB	$V^{-1}$	0	_	_	Coefficient for the length times width dependence of back-bias dependence of velocity saturation		
111	POTHESATG	V <sup>-1</sup>	0	_	_	Coefficient for the geometry independent part of gate-bias dependence of velocity saturation		
112	PLTHESATG	$V^{-1}$	0	_		Coefficient for the length dependence of gate-bias dependence of velocity saturation		

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No.	Name	Unit	Default	Min.	Max.	Description		
113	PWTHESATG	$V^{-1}$	0	_	_	Coefficient for the width dependence of gate-bias dependence of velocity saturation		
114	PLWTHESATG	V <sup>-1</sup>	0	_	_	Coefficient for the length times width dependence of gate-bias dependence of velocity saturation		
			Saturation	Voltage	Paramet	ters		
115	POAX	_	3	_	_	Coefficient for the geometry independent part of linear/saturation transition factor		
116	PLAX	_	0	_	_	Coefficient for the length dependence of linear/saturation transition factor		
117	PWAX	_	0	_	_	Coefficient for the width dependence of linear/saturation transition factor		
118	PLWAX	_	0	_	_	Coefficient for the length times width dependence of linear/saturation transition factor		
		Chann	el Length Mo	dulation	(CLM)	Parameters		
119	POALP	_	$10^{-2}$	_	_	Coefficient for the geometry independent part of CLM pre-factor		
120	PLALP	_	0	_	_	Coefficient for the length dependence of CLM pre-factor		
121	PWALP	_,	0	_	_	Coefficient for the width dependence of CLM pre-factor		
122	PLWALP	-	0	_	_	Coefficient for the length times width dependence of CLM pre-factor		
123	POALP1	V	0	_	_	Coefficient for the geometry independent part of CLM enhancement factor above threshold		
124	PLALP1	V	0	_	_	Coefficient for the length dependence of CLM enhancement factor above threshold		
125	PWALP1	V	0	_	_	Coefficient for the width dependence of CLM enhancement factor above threshold		
126	PLWALP1	V	0	_	_	Coefficient for the length times width dependence of CLM enhancement factor above threshold		
127	POALP2	$V^{-1}$	0	_	_	Coefficient for the geometry independent part of CLM enhancement factor below threshold		
128	PLALP2	$V^{-1}$	0	_	_	Coefficient for the length dependence of CLM enhancement factor below threshold		
129	PWALP2	$V^{-1}$	0	_	_	Coefficient for the width dependence of CLM enhancement factor below threshold		
130	PLWALP2	$V^{-1}$	0	_	_	Coefficient for the length times width dependence of CLM enhancement factor below threshold		

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No.	Name	Unit	Default	Min.	Max.	Description			
131	POVP	V	$5 \cdot 10^{-2}$	_	_	Coefficient for the geometry independent part of CLM logarithmic dependence parameter			
			Impact Ioniz	ation (II	) Param	neters			
132	POA1	_	1	_	_	Coefficient for the geometry independent part of impact-ionization pre-factor			
133	PLA1	_	0	_	_	Coefficient for the length dependence of impact-ionization pre-factor			
134	PWA1	_	0	_	_	Coefficient for the width dependence of impact-ionization pre-factor			
135	PLWA1	_	0	_	_	Coefficient for the length times width dependence of impact-ionization pre-factor			
136	POA2	V	10	_	_	Coefficient for the geometry independent part of impact-ionization exponent at <b>TR</b>			
137	POSTA2	V	0	_	_	Coefficient for the geometry independent part of temperature dependence of <b>A2</b>			
138	POA3	_	1	_	_	Coefficient for the geometry independent part of saturation-voltage dependence of II			
139	PLA3	_	0	_	_	Coefficient for the length dependence of saturation-voltage dependence of II			
140	PWA3	_	0	_	_	Coefficient for the width dependence of saturation-voltage dependence of II			
141	PLWA3	_	0	_	_	Coefficient for the length times width dependence of saturation-voltage dependence of II			
142	POA4	$V^{-0.5}$	0	_	_	Coefficient for the geometry independent part of back-bias dependence of II			
143	PLA4	$V^{-0.5}$	0	_	_	Coefficient for the length dependence of back-bias dependence of II			
144	PWA4	$V^{-0.5}$	0	_	_	Coefficient for the width dependence of back-bias dependence of II			
145	PLWA4	$V^{-0.5}$	0	_	_	Coefficient for the length times width dependence of back-bias dependence of II			
	Gate Current Parameters								
146	POGCO	_	0	_	_	Coefficient for the geometry independent part of gate tunneling energy adjustment			
147	POIGINV	A	0	_	_	Coefficient for the geometry independent part of gate channel current pre-factor			
148	PLIGINV	A	0	_	_	Coefficient for the length dependence of gate channel current pre-factor			
149	PWIGINV	A	0	_	_	Coefficient for the width dependence of gate channel current pre-factor			

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No.	Name	Unit	Default	Min.	Max.	Description			
150	PLWIGINV	A	0	_	_	Coefficient for the length times width dependence of gate channel current prefactor			
151	POIGOV	A	0	_	_	Coefficient for the geometry independent part of gate overlap current pre-factor			
152	PLIGOV	A	0	_	_	Coefficient for the length dependence of gate overlap current pre-factor			
153	PWIGOV	A	0	_	_	Coefficient for the width dependence of gate overlap current pre-factor			
154	PLWIGOV	A	0	_	_	Coefficient for the length times width dependence of gate overlap current pre-factor			
155	POSTIG	_	2	_	_	Coefficient for the geometry independent part of temperature dependence of gate current			
156	POGC2	_	$3.75 \cdot 10^{-1}$	_	_	Coefficient for the geometry independent part of gate current slope factor			
157	POGC3	_	$6.3 \cdot 10^{-2}$	_	_	Coefficient for the geometry independent part of gate current curvature factor			
158	POCHIB	V	3.1	_	_	Coefficient for the geometry independent part of tunneling barrier height			
	Gate-Induced Drain Leakage (GIDL) Parameters								
159	POAGIDL	A/V <sup>3</sup>	0	_	_	Coefficient for the geometry independent part of GIDL pre-factor			
160	PLAGIDL	A/V <sup>3</sup>	0	_	_	Coefficient for the length dependence of GIDL pre-factor			
161	PWAGIDL	A/V <sup>3</sup>	0	_	_	Coefficient for the width dependence of GIDL pre-factor			
162	PLWAGIDL	A/V <sup>3</sup>	0	_	_	Coefficient for the length times width dependence of GIDL pre-factor			
163	POAGIDLD	A/V <sup>3</sup>	0	_	_	Coefficient for the geometry independent part of GIDL pre-factor for drain side			
164	PLAGIDLD	A/V <sup>3</sup>	0	_	_	Coefficient for the length dependence of GIDL pre-factor for drain side			
165	PWAGIDLD	A/V <sup>3</sup>	0	_	_	Coefficient for the width dependence of GIDL pre-factor for drain side			
166	PLWAGIDLD	A/V <sup>3</sup>	0	_	_	Coefficient for the length times width dependence of GIDL pre-factor for drain side			
167	POBGIDL	V	41	_	_	Coefficient for the geometry independent part of GIDL probability factor at <b>TR</b>			
168	POBGIDLD	V	41	_	_	Coefficient for the geometry independent part of GIDL probability factor at <b>TR</b> for drain side			

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No.	Name	Unit	Default	Min.	Max.	Description
169	POSTBGIDL	V/K	0	_	_	Coefficient for the geometry independent part of temperature dependence of <b>BGIDL</b>
170	POSTBGIDLD	V/K	0	_	_	Coefficient for the geometry independent part of temperature dependence of <b>BGIDL</b> for drain side
171	POCGIDL	_	0	_	_	Coefficient for the geometry independent part of back-bias dependence of GIDL
172	POCGIDLD	_	0	_	_	Coefficient for the geometry independent part of back-bias dependence of GIDL for drain side
			Charge I	Model Pa	rameter	·s
173	POCOX	F	$10^{-14}$	_	_	Coefficient for the geometry independent part of oxide capacitance for intrinsic channel
174	PLCOX	F	0	_	_	Coefficient for the length dependence of oxide capacitance for intrinsic channel
175	PWCOX	F	0		_	Coefficient for the width dependence of oxide capacitance for intrinsic channel
176	PLWCOX	F	0	_	_	Coefficient for the length times width dependence of oxide capacitance for intrinsic channel
177	POCGOV	F	$10^{-15}$	_	_	Coefficient for the geometry independent part of oxide capacitance for gatedrain/source overlap
178	PLCGOV	F	0	_	_	Coefficient for the length dependence of oxide capacitance for gate-drain/source overlap
179	PWCGOV	F	0	_	_	Coefficient for the width dependence of oxide capacitance for gate-drain/source overlap
180	PLWCGOV	F	0	_	_	Coefficient for the length times width dependence of oxide capacitance for gatedrain/source overlap
181	POCGOVD	F	$10^{-15}$	_	_	Coefficient for the geometry independent part of oxide capacitance for gatedrain/source overlap for drain side
182	PLCGOVD	F	0	_	_	Coefficient for the length dependence of oxide capacitance for gate-drain/source overlap for drain side
183	PWCGOVD	F	0	_	_	Coefficient for the width dependence of oxide capacitance for gate-drain/source overlap for drain side
184	PLWCGOVD	F	0	_	_	Coefficient for the length times width dependence of oxide capacitance for gatedrain/source overlap for drain side

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No.	Name	Unit	Default	Min.	Max.	Description				
185	POCGBOV	F	0	_	_	Coefficient for the geometry independent part of oxide capacitance for gate-bulk overlap				
186	PLCGBOV	F	0	_	_	Coefficient for the length dependence of oxide capacitance for gate-bulk overlap				
187	PWCGBOV	F	0	_	_	Coefficient for the width dependence of oxide capacitance for gate-bulk overlap				
188	PLWCGBOV	F	0	_	_	Coefficient for the length times width dependence of oxide capacitance for gatebulk overlap				
189	POCFR	F	0	_	_	Coefficient for the geometry independent part of outer fringe capacitance				
190	PLCFR	F	0	_	_	Coefficient for the length dependence of outer fringe capacitance				
191	PWCFR	F	0	_	_	Coefficient for the width dependence of outer fringe capacitance				
192	PLWCFR	F	0	_	_	Coefficient for the length times width dependence of outer fringe capacitance				
193	POCFRD	F	0	_	_	Coefficient for the geometry independent part of outer fringe capacitance for drain side				
194	PLCFRD	F	0	_	_	Coefficient for the length dependence of outer fringe capacitance for drain side				
195	PWCFRD	F	0	_	_	Coefficient for the width dependence of outer fringe capacitance for drain side				
196	PLWCFRD	F	0	_	_	Coefficient for the length times width dependence of outer fringe capacitance for drain side				
			Noise M	odel Par	ameters	5				
197	POFNT	_	1	_	_	Coefficient for the geometry independent part of thermal noise coefficient				
198	PONFA	$V^{-1}/m^4$	$8 \cdot 10^{22}$	_	_	Coefficient for the geometry independent part of first coefficient of flicker noise				
199	PLNFA	$V^{-1}/m^4$	0	_	_	Coefficient for the length dependence of first coefficient of flicker noise				
200	PWNFA	$V^{-1}/m^4$	0	_	_	Coefficient for the width dependence of first coefficient of flicker noise				
201	PLWNFA	V <sup>-1</sup> /m <sup>4</sup>	0	_	_	Coefficient for the length times width dependence of first coefficient of flicker noise				
202	PONFB	$V^{-1}/m^2$	$3 \cdot 10^7$	_	_	Coefficient for the geometry independent part of second coefficient of flicker noise				
203	PLNFB	$V^{-1}/m^2$	0	_	_	Coefficient for the length dependence of second coefficient of flicker noise				

No.	Name	Unit	Default	Min.	Max.	Description			
204	PWNFB	$V^{-1}/m^2$	0	_	_	Coefficient for the width dependence of second coefficient of flicker noise			
205	PLWNFB	V <sup>-1</sup> /m <sup>2</sup>	0	_	_	Coefficient for the length times width dependence of second coefficient of flicker noise			
206	PONFC	$V^{-1}$	0	_		Coefficient for the geometry independent part of third coefficient of flicker noise			
207	PLNFC	$V^{-1}$	0	_	_	Coefficient for the length dependence of third coefficient of flicker noise			
208	PWNFC	$V^{-1}$	0	_	_	Coefficient for the width dependence of third coefficient of flicker noise			
209	PLWNFC	V <sup>-1</sup>	0	_	_	Coefficient for the length times width dependence of third coefficient of flicker noise			
210	POEF	_	1.0	_	_	Coefficient for the geometry independent part of flicker noise frequency exponent			
	Other Parameters								
211	DTA	K	0	_	_	temperature offset w.r.t. ambient circuit temperature			

#### 2.5.5 Parameters for stress model

The stress model of BSIM4.4.0 has been adopted in PSP with as little modifications as possible. Parameter names have been copied, but they have been subjected to PSP conventions by replacing every zero by an 'O'. Moreover, the parameters STK2 and LODK2 are not available in PSP. Except for these changes, stress parameters determined for BSIM can be directly applied in PSP. Some trivial conversion of parameters BSIM $\rightarrow$ PSP is still necessary, see [2].

The parameters in this section are part of PSP's global parameter set (both geometrical and binning).

No.	Name	Unit	Default	Min.	Max.	Description
0	SAREF	m	$10^{-6}$	10 <sup>-9</sup>	_	Reference distance between OD edge to Poly from one side
1	SBREF	m	$10^{-6}$	10 <sup>-9</sup>	_	Reference distance between OD edge to Poly from other side
2	WLOD	m	0	_	_	Width parameter
3	KUO	m	0	_	_	Mobility degradation/en- hancement coefficient
4	KVSAT	m	0	-1	1	Saturation velocity degradation/enhancement parameter
5	TKUO	_	0	_	_	Temperature coefficient of <b>KUO</b>
6	LKUO	mLLODKUO	0	_	_	Length dependence of <b>KUO</b>
7	WKUO	mwlodkuo	0	_	_	Width dependence of <b>KUO</b>
8	PKUO	mLLODKUO+WLODKUO	0	_	_	Cross-term dependence of <b>KUO</b>
9	LLODKUO	-	0	0	_	Length parameter for mobility stress effect
10	WLODKUO	-	0	0	_	Width parameter for mobility stress effect
11	KVTHO	Vm	0	_	_	Threshold shift parameter
12	LKVTHO	m <sup>LLODVTH</sup>	0		_,	Length dependence of <b>KVTHO</b>
13	WKVTHO	mwlodvth	0		_,	Width dependence of <b>KVTHO</b>
14	PKVTHO	mLLODVTH+WLODVTH	0	_	_	Cross-term dependence of <b>KVTHO</b>
15	LLODVTH	_	0	0	_	Length parameter for thres- hold voltage stress effect
16	WLODVTH	-	0	0	_	Width parameter for thres- hold voltage stress effect
17	STETAO	m	0	_	_	ETAO shift factor related to threshold voltage change

No.	Name	Unit	Default	Min.	Max.	Description
18	LODETAO	_	1	0	_	ETAO shift modification
						factor

### 2.5.6 Parameters for well proximity effect model

The WPE model of BSIM4.5.0 has been adopted in PSP with as little modifications as possible. Parameter names have been copied, but they have been subjected to PSP conventions by replacing every zero by an 'O'. Moreover, the parameter **K2WE** is not available in PSP. Except for some trivial conversion of parameters BSIM $\rightarrow$ PSP [2], WPE parameters from BSIM can be used directly in PSP. The WPE parameters have both geometrical and binning rules included as explained in Section 3.6.2. Consequently one of the following parameter sets can be used depending on which scaling rule is selected.

The parameters in the following table are part of PSP's global parameter set.

No.	Name	Unit	Default	Min.	Max.	Description
0	SCREF	m	$1 \cdot 10^{-6}$	0	_	Distance between OD-edge and well edge of a reference device
1	WEB	_	0	_	_	Coefficient for SCB
2	WEC	_	0	_	_	Coefficient for SCC
3	KVTHOWEO	_	0	_	_	Geometry independent threshold shift parameter
4	KVTHOWEL	_	0	_	_	Length dependence of threshold shift parameter
5	KVTHOWEW	_	0	_	_	Width dependence of threshold shift parameter
6	KVTHOWELW	_	0	_	_	Area dependence of thres- hold shift parameter
7	KUOWEO	_	0	_	_	Geometry independent mobility degradation factor
8	KUOWEL	_	0	_	_	Length dependence of mobility degradation factor
9	KUOWEW	_	0	_	_	Width dependence of mobility degradation factor
10	KUOWELW	_	0	_	_	Area dependence of mobility degradation factor

The parameters in the following table are part of PSP's binning parameter set.

No.	Name	Unit	Default	Min.	Max.	Description
0	SCREF	m	$1 \cdot 10^{-6}$	0	_	Distance between OD-edge and well edge of a reference device
1	WEB	-	0	_	_	Coefficient for SCB
2	WEC	-	0	_	_	Coefficient for SCC
3	POKVTHOWE	_	0	_	_	Coefficient for the geometry independent part of threshold shift parameter

No.	Name	Unit	Default	Min.	Max.	Description
4	PLKVTHOWE	_	0	_	_	Coefficient for the length de- pendence of threshold shift parameter
5	PWKVTHOWE	_	0	_	_	Coefficient for the width dependence of threshold shift parameter
6	PLWKVTHOWE	_	0	_	_	Coefficient for the length times width dependence of threshold shift parameter
7	POKUOWE	_	0	_	_	Coefficient for the geometry independent part of mobility degradation factor
8	PLKUOWE	_	0	_	_	Coefficient for the length dependence of mobility degradation factor
9	PWKUOWE	_	0	_	_	Coefficient for the width dependence of mobility degradation factor
10	PLWKUOWE	_	0	_	_	Coefficient for the length times width dependence of mobility degradation factor

### 2.5.7 Parameters for local model

The set of local parameters valid for an individual transistor with a specific channel width and length are given in the table below. Since the local parameter set is valid for one device with a specific geometry, it does not contain the channel length and width as instance parameters.

No.	Name	Unit	Default	Min.	Max.	Description					
0	LEVEL	_	102	_	_	Model selection parameter; see Sec. 6.1					
1	ТҮРЕ	-	1	-1	1	Channel type parameter; $1 \leftrightarrow \text{NMOS}, -1 \leftrightarrow \text{PMOS}^7$					
2	TR	°C	21	-273	_	Reference temperature					
			Sv	vitch Par	ameters						
3	PARAMCHK	_	0	_	_	Level of clip-warning info <sup>8</sup>					
4	SWIGATE	_	0	0	1	Flag for gate current $(0 \leftrightarrow \text{``off''})$					
5	SWIMPACT	-	0	0	1	Flag for impact ionization current (0 $\leftrightarrow$ "off")					
6	SWGIDL	_	0	0	1	Flag for GIDL/GISL current (0 $\leftrightarrow$ "off")					
7	SWJUNCAP	-	0	0	3	Flag for JUNCAP (0 $\leftrightarrow$ "off"); see Sec. 2.5.2					
8	SWJUNASYM	_	0	_	_	Flag for asymmetric junctions $(0 \leftrightarrow \text{``off''})^9$					
9	QMC	_	1	0	_	Quantum-mechanical correction factor					
	Process Parameters										
10	VFB	V	-1	_	_	Flat-band voltage at <b>TR</b>					
11	STVFB	V/K	$5 \cdot 10^{-4}$	_	_	Temperature dependence of VFB					
12	TOX	m	$2 \cdot 10^{-9}$	$10^{-10}$	_	Gate oxide thickness					
13	EPSROX	_	3.9	1	_	Relative permittivity of gate dielectric					
14	NEFF	$\mathrm{m}^{-3}$	$5 \cdot 10^{23}$	$10^{20}$	$10^{26}$	Substrate doping					
15	VNSUB	V	0	_	_	Effective doping bias-dependence parameter					
16	NSLP	V	0.05	$10^{-3}$	_	Effective doping bias-dependence parameter					
17	DNSUB	$V^{-1}$	0	0	1	Effective doping bias-dependence parameter					
18	DPHIB	V	0	_	_	Offset of $\varphi_{\mathrm{B}}$					
19	NP	$\mathrm{m}^{-3}$	$10^{26}$	0	_	Gate poly-silicon doping					
20	CT	_	0	0	_	Interface states factor					
21	TOXOV	m	$2 \cdot 10^{-9}$	$10^{-10}$	_	Overlap oxide thickness					
22	TOXOVD	m	$2 \cdot 10^{-9}$	$10^{-10}$	_	Overlap oxide thickness for drain side					
23	NOV	$\mathrm{m}^{-3}$	$5\cdot 10^{25}$	$10^{20}$	$10^{27}$	Effective doping of overlap region					
24	NOVD	$\mathrm{m}^{-3}$	$5 \cdot 10^{25}$	$10^{20}$	$10^{27}$	Effective doping of overlap region for drain side					
			D	IBL Para	ameters						

<sup>&</sup>lt;sup>7</sup>See Section 6.3.1 for more information on usage of **TYPE** in various simulators.

 $<sup>^8</sup>$ Only in SiMKit-version of PSP. See Section 6.5.4 for more information.

<sup>&</sup>lt;sup>9</sup>See Section 3.7 for more information on usage of **SWJUNASYM**.

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No.	Name	Unit	Default	Min.	Max.	Description				
25	CF	$V^{-1}$	0	0	_	DIBL parameter				
26	CFB	$V^{-1}$	0	0	1	Back-bias dependence of CF				
			Mo	bility Pa	rameter	s				
27	BETN	m <sup>2</sup> /V/s	$7 \cdot 10^{-2}$	0	_	Product of channel aspect ratio and zero-field mobility at <b>TR</b>				
28	STBET	_	1	_	_	Temperature dependence of <b>BETN</b>				
29	MUE	m/V	0.5	0	_	Mobility reduction coefficient at <b>TR</b>				
30	STMUE	_	0	_	_	Temperature dependence of MUE				
31	THEMU	_	1.5	0	_	Mobility reduction exponent at <b>TR</b>				
32	STTHEMU	_	1.5	_	_	Temperature dependence of <b>THEMU</b>				
33	CS	_	0	0	_	Coulomb scattering parameter at <b>TR</b>				
34	STCS	_	0	_	_	Temperature dependence of CS				
35	XCOR	$V^{-1}$	0	0	_	Non-universality parameter				
36	STXCOR	_	0	_	_	Temperature dependence of <b>XCOR</b>				
37	FETA	_	1	0	_	Effective field parameter				
Series Resistance Parameters										
38	RS	Ω	30	0	_	Source/drain series resistance at <b>TR</b>				
39	STRS	_	1	_	_	Temperature dependence of <b>RS</b>				
40	RSB	$V^{-1}$	0	-0.5	1	Back-bias dependence of <b>RS</b>				
41	RSG	$V^{-1}$	0	-0.5	_	Gate-bias dependence of <b>RS</b>				
	Velocity Saturation Parameters									
42	THESAT	$V^{-1}$	1	0	_	Velocity saturation parameter at <b>TR</b>				
43	STTHESAT	_	1	_	_	Temperature dependence of <b>THESAT</b>				
44	THESATB	$V^{-1}$	0	-0.5	1	Back-bias dependence of velocity saturation				
45	THESATG	V <sup>-1</sup>	0	-0.5	_	Gate-bias dependence of velocity saturation				
			Saturati	ion Volta	ge Parai	meter				
46	AX	-	3	2	_	Linear/saturation transition factor				
		Chann	el Length	Modulat	ion (CLI	M) Parameters				
47	ALP	_	0.01	0	_	CLM pre-factor				
48	ALP1	V	0	0	_	CLM enhancement factor above threshold				
49	ALP2	$V^{-1}$	0	0	_	CLM enhancement factor below threshold				
50	VP	V	0.05	$10^{-10}$	_	CLM logarithmic dependence parameter				
			Impact Io	nization	(II) Para	ameters				
51	A1	_	1	0	_	Impact-ionization pre-factor				
52	A2	V	10	0	_	Impact-ionization exponent at <b>TR</b>				
53	STA2	V	0	_	_	Temperature dependence of A2				
54	A3	_	1	0	_	Saturation-voltage dependence of II				
55	A4	$V^{-\frac{1}{2}}$	0	0	_	Back-bias dependence of II				

No.	Name	Unit	Default	Min.	Max.	Description				
	I	I	Gate	Current 1		ters				
56	GCO	_	0	-10	10	Gate tunnelling energy adjustment				
57	IGINV	A	0	0	_	Gate channel current pre-factor				
58	IGOV	A	0	0	_	Gate overlap current pre-factor				
59	IGOVD	A	0	0	_	Gate overlap current pre-factor for drain side				
60	STIG	_	2	_	_	Temperature dependence of gate current				
61	GC2	_	0.375	0	10	Gate current slope factor				
62	GC3	_	0.063	-2	2	Gate current curvature factor				
63	СНІВ	V	3.1	1	_	Tunnelling barrier height				
Gate-Induced Drain Leakage (GIDL) Parameters										
64	AGIDL	A/V <sup>3</sup>	0	0	_	GIDL pre-factor				
65	AGIDLD	A/V <sup>3</sup>	0	0	_	GIDL pre-factor for drain side				
66	BGIDL	V	41	0	_	GIDL probability factor at <b>TR</b>				
67	BGIDLD	V	41	0	_	GIDL probability factor at <b>TR</b> for drain side				
68	STBGIDL	V/K	0	_	_	Temperature dependence of <b>BGIDL</b>				
69	STBGIDLD	V/K	0	_	_	Temperature dependence of <b>BGIDL</b> for drain side				
70	CGIDL	_	0	_	_	Back-bias dependence of GIDL				
71	CGIDLD	_	0	_	_	Back-bias dependence of GIDL for drain side				
	1	•	Charg	e Model	Parame	ters				
72	COX	F	$10^{-14}$	0	_	Oxide capacitance for intrinsic channel				
73	CGOV	F	$10^{-15}$	0	_	Oxide capacitance for gate-drain/source overlap				
74	CGOVD	F	$10^{-15}$	0	_	Oxide capacitance for gate-drain/source overlap for drain side				
75	CGBOV	F	0	0	_	Oxide capacitance for gate-bulk overlap				
76	CFR	F	0	0	_	Outer fringe capacitance				
77	CFRD	F	0	0	_	Outer fringe capacitance for drain side				
	1		Noise	Model I	Paramet	ers				
78	FNT	_	1.0	0	_	Thermal noise coefficient				
79	NFA	$V^{-1}/m^4$	$8 \cdot 10^{22}$	0	_	First coefficient of flicker noise				
80	NFB	$V^{-1}/m^2$	$3 \cdot 10^7$	0	_	Second coefficient of flicker noise				
81	NFC	$V^{-1}$	0	0	_	Third coefficient of flicker noise				
82	EF	-	1.0	0	_	Flicker noise frequency exponent				
			O	ther Para	ameters					
83	DTA	K	0	_	_	Temperature offset w.r.t. ambient circuit temperature				

### 2.5.8 Parameters for source-bulk and drain-bulk junction model

The JUNCAP2 parameters are part of both the global and the local parameter sets. The parameters in the following table are shared by both source-bulk and drain-bulk junctions.

No.	Name	Unit	Default	Min.	Max.	Description
0	TRJ	°C	21	$T_{\min}$	_	Reference temperature
1	SWJUNEXP	_	0	0	1	Flag for JUNCAP2 Express; $0 \leftrightarrow \text{full JUN-}$ CAP2 model, $1 \leftrightarrow \text{Express model}$
2	IMAX	A	1000	$10^{-12}$	_	Maximum current up to which forward current behaves exponentially

The parameters in the following table are for the source-bulk junction.

No.	Name	Unit	Default	Min.	Max.	Description	
				citance P	aramete	ers	
0	CJORBOT	F/m <sup>2</sup>	$10^{-3}$	$10^{-12}$	_	Zero-bias capacitance per unit-of-area of bottom component for source-bulk junction	
1	CJORSTI	F/m	10 <sup>-9</sup>	$10^{-18}$	_	Zero-bias capacitance per unit-of-length of STI-edge component for source-bulk junction	
2	CJORGAT	F/m	10 <sup>-9</sup>	$10^{-18}$	_	Zero-bias capacitance per unit-of-length of gate-edge component for source-bulk junction	
3	VBIRBOT	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference tempera- ture of bottom component for source-bulk junction	
4	VBIRSTI	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference temperature of STI-edge component for source-bulk junction	
5	VBIRGAT	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference tempera- ture of gate-edge component for source- bulk junction	
6	PBOT	_	0.5	0.05	0.95	Grading coefficient of bottom component for source-bulk junction	
7	PSTI	_	0.5	0.05	0.95	Grading coefficient of STI-edge component for source-bulk junction	
8	PGAT	_	0.5	0.05	0.95	Grading coefficient of gate-edge component for source-bulk junction	
			Ideal-	current l	Paramet	ers	
9	PHIGBOT	V	1.16	_	_	Zero-temperature bandgap voltage of bot- tom component for source-bulk junction	
10	PHIGSTI	V	1.16	-	_	Zero-temperature bandgap voltage of STI- edge component for source-bulk junction	
11	PHIGGAT	V	1.16	_	_	Zero-temperature bandgap voltage of gate- edge component for source-bulk junction	

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No.	Name	Unit	Default	Min.	Max.	Description		
12	IDSATRBOT	A/m <sup>2</sup>	10 <sup>-12</sup>	0	_	Saturation current density at the reference temperature of bottom component for source-bulk junction		
13	IDSATRSTI	A/m	10 <sup>-18</sup>	0	_	Saturation current density at the reference temperature of STI-edge component for source-bulk junction		
14	IDSATRGAT	A/m	10 <sup>-18</sup>	0	_	Saturation current density at the reference temperature of gate-edge component for source-bulk junction		
15	CSRHBOT	A/m <sup>3</sup>	$10^{2}$	0	_	Shockley-Read-Hall prefactor of bottom component for source-bulk junction		
16	CSRHSTI	A/m <sup>2</sup>	$10^{-4}$	0	_	Shockley-Read-Hall prefactor of STI-edge component for source-bulk junction		
17	CSRHGAT	A/m <sup>2</sup>	$10^{-4}$	0	_	Shockley-Read-Hall prefactor of gate-edge component for source-bulk junction		
18	XJUNSTI	m	$10^{-7}$	$10^{-9}$	_	Junction depth of STI-edge component for source-bulk junction		
19	XJUNGAT	m	$10^{-7}$	$10^{-9}$	_	Junction depth of gate-edge component for source-bulk junction		
		,	Trap-assist	ed Tunne	ling Par	ameters		
20	СТАТВОТ	A/m <sup>3</sup>	$10^{2}$	0	_	Trap-assisted tunneling prefactor of bot- tom component for source-bulk junction		
21	CTATSTI	A/m <sup>2</sup>	$10^{-4}$	0	_	Trap-assisted tunneling prefactor of STI-edge component for source-bulk junction		
22	CTATGAT	A/m <sup>2</sup>	$10^{-4}$	0	_	Trap-assisted tunneling prefactor of gate- edge component for source-bulk junction		
23	MEFFTATBOT	_	0.25	.01	_	Effective mass (in units of $m_0$ ) for trapassisted tunneling of bottom component for source-bulk junction		
24	MEFFTATSTI	_	0.25	.01	_	Effective mass (in units of $m_0$ ) for trapassisted tunneling of STI-edge component for source-bulk junction		
25	MEFFTATGAT	_	0.25	.01	_	Effective mass (in units of $m_0$ ) for trapassisted tunneling of gate-edge component for source-bulk junction		
			Band-to-ba	nd Tunn	eling Par	rameters		
26	СВВТВОТ	$AV^{-3}$	$10^{-12}$	0	_	Band-to-band tunneling prefactor of bot- tom component for source-bulk junction		
27	CBBTSTI	AV <sup>−3</sup> m	$10^{-18}$	0	_	Band-to-band tunneling prefactor of STI- edge component for source-bulk junction		
28	CBBTGAT	AV <sup>−3</sup> m	$10^{-18}$	0	_	Band-to-band tunneling prefactor of gate- edge component for source-bulk junction		

No.	ntinued from previous  Name	Unit	Default	Min.	Max.	Description
29	FBBTRBOT	Vm <sup>-1</sup>	109	_	_	Normalization field at the reference temperature for band-to-band tunneling of bottom component for source-bulk junction
30	FBBTRSTI	Vm <sup>-1</sup>	109	_	_	Normalization field at the reference temperature for band-to-band tunneling of STI-edge component for source-bulk junction
31	FBBTRGAT	Vm <sup>-1</sup>	109	_	_	Normalization field at the reference temperature for band-to-band tunneling of gate-edge component for source-bulk junction
32	STFBBTBOT	K <sup>-1</sup>	$-10^{-3}$	ı	_	Temperature scaling parameter for band- to-band tunneling of bottom component for source-bulk junction
33	STFBBTSTI	K <sup>-1</sup>	$-10^{-3}$	1	_	Temperature scaling parameter for band- to-band tunneling of STI-edge component for source-bulk junction
34	STFBBTGAT	K <sup>-1</sup>	$-10^{-3}$	-	_	Temperature scaling parameter for band- to-band tunneling of gate-edge component for source-bulk junction
		A	valanche a	nd Break	down Pa	arameters
35	VBRBOT	V	10	0.1	_	Breakdown voltage of bottom component for source-bulk junction
36	VBRSTI	V	10	0.1	_	Breakdown voltage of STI-edge component for source-bulk junction
37	VBRGAT	V	10	0.1	_	Breakdown voltage of gate-edge component for source-bulk junction
38	PBRBOT	V	4	0.1	_	Breakdown onset tuning parameter of bottom component for source-bulk junction
39	PBRSTI	V	4	0.1	_	Breakdown onset tuning parameter of STI- edge component for source-bulk junction
40	PBRGAT	V	4	0.1	_	Breakdown onset tuning parameter of gate- edge component for source-bulk junction
			JUNCA	P Expres	s Param	neters
41	VJUNREF	V	2.5	0.5	_	Typical maximum source-bulk junction voltage; usually about $2 \cdot V_{\mathrm{sup}}$
42	FJUNQ	V	0.03	0	_	Fraction below which source-bulk junction capacitance components are neglected

The parameters in the following table are for the drain-bulk junction.

No.	Name	Unit	Default	Min.	Max.	Description		
			Capac	citance Pa	rametei	rs		
0	CJORBOTD	F/m <sup>2</sup>	$10^{-3}$	$10^{-12}$	_	Zero-bias capacitance per unit-of-area of bottom component for drain-bulk junction		
1	CJORSTID	F/m	10-9	$10^{-18}$	_	Zero-bias capacitance per unit-of-length of STI-edge component for drain-bulk junction		
2	CJORGATD	F/m	10 <sup>-9</sup>	$10^{-18}$	_	Zero-bias capacitance per unit-of-length of gate-edge component for drain-bulk junction		
3	VBIRBOTD	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference tempera- ture of bottom component for drain-bulk junction		
4	VBIRSTID	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference tempera- ture of STI-edge component for drain-bulk junction		
5	VBIRGATD	V	1	$V_{ m bi,low}$	_	Built-in voltage at the reference tempera- ture of gate-edge component for drain-bulk junction		
6	PBOTD	ı	0.5	0.05	0.95	Grading coefficient of bottom componer for drain-bulk junction		
7	PSTID	-	0.5	0.05	0.95	Grading coefficient of STI-edge component for drain-bulk junction		
8	PGATD	_	0.5	0.05	0.95	Grading coefficient of gate-edge component for drain-bulk junction		
			Ideal-	current P	aramete	rs		
9	PHIGBOTD	V	1.16	_	_	Zero-temperature bandgap voltage of bot- tom component for drain-bulk junction		
10	PHIGSTID	V	1.16	_	_	Zero-temperature bandgap voltage of STI- edge component for drain-bulk junction		
11	PHIGGATD	V	1.16	_	_	Zero-temperature bandgap voltage of gate- edge component for drain-bulk junction		
12	IDSATRBOTD	A/m <sup>2</sup>	10 <sup>-12</sup>	0	_	Saturation current density at the reference temperature of bottom component for drain-bulk junction		
13	IDSATRSTID	A/m	10^-18	0	_	Saturation current density at the reference temperature of STI-edge component for drain-bulk junction		
14	IDSATRGATD	A/m	10 <sup>-18</sup>	0	_	Saturation current density at the reference temperature of gate-edge component for drain-bulk junction		
15	CSRHBOTD	A/m <sup>3</sup>	$10^{2}$	0	_	Shockley-Read-Hall prefactor of bottom component for drain-bulk junction		
16	CSRHSTID	A/m <sup>2</sup>	$10^{-4}$	0	_	Shockley-Read-Hall prefactor of STI-edge component for drain-bulk junction		

	continued from previous page  Nome  Linit Defoult Min Max Description									
No.	Name	Unit	Default	Min.	Max.	Description				
17	CSRHGATD	A/m <sup>2</sup>	$10^{-4}$	0	_	Shockley-Read-Hall prefactor of gate-edge component for drain-bulk junction				
18	XJUNSTID	m	$10^{-7}$	$10^{-9}$	_	Junction depth of STI-edge component for drain-bulk junction				
19	XJUNGATD	m	$10^{-7}$	$10^{-9}$	_	Junction depth of gate-edge component for drain-bulk junction				
	Trap-assisted Tunneling Parameters									
20	CTATBOTD	A/m <sup>3</sup>	$10^{2}$	0	_	Trap-assisted tunneling prefactor of bottom component for drain-bulk junction				
21	CTATSTID	A/m <sup>2</sup>	$10^{-4}$	0	_	Trap-assisted tunneling prefactor of STI-edge component for drain-bulk junction				
22	CTATGATD	A/m <sup>2</sup>	$10^{-4}$	0	_	Trap-assisted tunneling prefactor of gate- edge component for drain-bulk junction				
23	MEFFTATBOTD	ı	0.25	.01	_	Effective mass (in units of $m_0$ ) for trapassisted tunneling of bottom component for drain-bulk junction				
24	MEFFTATSTID	-	0.25	.01	_	Effective mass (in units of $m_0$ ) for trapassisted tunneling of STI-edge component for drain-bulk junction				
25	MEFFTATGATD	_	0.25	.01	_	Effective mass (in units of $m_0$ ) for trapassisted tunneling of gate-edge component for drain-bulk junction				
			and-to-bar	nd Tunne	ling Para	ameters				
26	CBBTBOTD	$AV^{-3}$	$10^{-12}$	0	_	Band-to-band tunneling prefactor of bot- tom component for drain-bulk junction				
27	CBBTSTID	$AV^{-3}$ m	$10^{-18}$	0	_	Band-to-band tunneling prefactor of STI- edge component for drain-bulk junction				
28	CBBTGATD	$AV^{-3}$ m	$10^{-18}$	0	_	Band-to-band tunneling prefactor of gate- edge component for drain-bulk junction				
29	FBBTRBOTD	Vm <sup>-1</sup>	10 <sup>9</sup>	_	_	Normalization field at the reference temperature for band-to-band tunneling of bottom component for drain-bulk junction				
30	FBBTRSTID	$ m Vm^{-1}$	$10^{9}$	_	_	Normalization field at the reference temperature for band-to-band tunneling of STI-edge component for drain-bulk junction				
31	FBBTRGATD	Vm <sup>-1</sup>	10 <sup>9</sup>	_	_	Normalization field at the reference temperature for band-to-band tunneling of gate-edge component for drain-bulk junction				
32	STFBBTBOTD	$K^{-1}$	$-10^{-3}$	_	_	Temperature scaling parameter for band- to-band tunneling of bottom component for drain-bulk junction				
33	STFBBTSTID	K <sup>-1</sup>	$-10^{-3}$	_	_	Temperature scaling parameter for band- to-band tunneling of STI-edge component for drain-bulk junction				

co	T						
No.	Name	Unit	Default	Min.	Max.	Description	
34	STFBBTGATD	K <sup>-1</sup>	$-10^{-3}$	_	_	Temperature scaling parameter for band- to-band tunneling of gate-edge component for drain-bulk junction	
		Av	alanche an	d Breakd	lown Pa	rameters	
35	VBRBOTD	V	10	0.1	_	Breakdown voltage of bottom component for drain-bulk junction	
36	VBRSTID	V	10	0.1	_	Breakdown voltage of STI-edge component for drain-bulk junction	
37	VBRGATD	V	10	0.1	_	Breakdown voltage of gate-edge component for drain-bulk junction	
38	PBRBOTD	V	4	0.1	_	Breakdown onset tuning parameter of bottom component for drain-bulk junction	
39	PBRSTID	V	4	0.1	_	Breakdown onset tuning parameter of STI- edge component for drain-bulk junction	
40	PBRGATD	V	4	0.1	_	Breakdown onset tuning parameter of gate- edge component for drain-bulk junction	
			JUNCAL	P Express	Parame	eters	
41	VJUNREFD	V	2.5	0.5	_	Typical maximum drain-bulk junction voltage; usually about $2 \cdot V_{\mathrm{sup}}$	
42	FJUNQD	V	0.03	0	_	Fraction below which drain-bulk junction capacitance components are neglected	

### 2.5.9 Parameters for parasitic resistances

The parameters in the following table are part of PSP's global and binning parameter sets.

No.	Name	Unit	Default	Min.	Max.	Description	
0	RGO	Ω	0	_	_	Gate resistance $R_{ m gate}$	
1	RINT	$\Omega/\Box$	0	0	_	Contact resistance between silicide and ploy	
2	RVPOLY	$\Omega/\Box$	0	0	_	Vertical poly resistance	
3	RSHG	$\Omega/\Box$	0	0	_	Gate electrode diffusion sheet resistance	
4	DLSIL	m	0			Silicide extension over the physical gate length	
5	RBULKO	Ω	0	_	_	Bulk resistance $R_{\rm bulk}$	
6	RWELLO	Ω	0	_	_	Well resistance $R_{ m well}$	
7	RJUNSO	Ω	0	_	_	Source-side bulk resistance $R_{ m juns}$	
8	RJUNDO	Ω	0	_	_	Drain-side bulk resistance $R_{ m jund}$	

The parameters in the following table are part of PSP's local parameter set.

No.	Name	Unit	Default	Min.	Max.	Iax. Description	
0	RG	Ω	0	0	$-$ Gate resistance $R_{ m gate}$		
1	RBULK	Ω	0	0	_	- Bulk resistance $R_{ m bulk}$	
2	RWELL	Ω	0	0	_	Well resistance $R_{\mathrm{well}}$	
3	RJUNS	Ω	0	0	_	Source-side bulk resistance $R_{ m juns}$	
4	RJUND	Ω	0	0	_	Drain-side bulk resistance $R_{ m jund}$	

### 2.5.10 Parameters for NQS

The parameters in the following table are part of PSP-NQS's global and binning parameter sets.

No.	Name	Unit	Default	Min.	Max.	Description	
0	SWNQS	_	0	0	9	Switch for NQS effects / number of collocation points	
1	MINOSO		1			1	
1	MUNQSO	_	1	_	-	Relative mobility for NQS modeling	

The parameters in the following table are part of PSP-NQS's local parameter set.

No.	Name	Unit	Default	Min.	Max.	Description	
0	SWNQS	-	0	0	9	Switch for NQS effects / number of collocation points	
1	MUNQS	_	1	0	_	Relative mobility for NQS modeling	

## **Section 3**

# Geometry dependence and Other effects

#### 3.1 Introduction

The physical geometry scaling rules of PSP (Section 3.2) have been developed to give a good description over the whole geometry range of CMOS technologies. As an alternative, the binning-rules can be used (Section 3.3) to allow for a more phenomenological geometry dependency. (Note that the user has to choose between the two options; the geometrical scaling rules and the binning scaling rules cannot be used at the same time.) In both cases, the result is a local parameter set (for a transistor of the specified L and W), which is fed into the local model.

Stress and well proximity effects are included in PSP. Use of the stress model (Section 3.5) and/or well proximity effect model (Section 3.6) leads to modification of some of the local parameters calculated from the geometrical or binning scaling rules.

### 3.2 Geometrical scaling rules

clipping is applied according to Section 2.5.7.

The physical scaling rules to calculate the local parameters from a global parameter set are given in this section. **Note:** After calculation of the local parameters (and possible application of the stress equations in Section 3.5),

Effective length and width

$$W_{\rm f} = \frac{W}{\mathbf{NF}} \tag{3.1}$$

$$L_{\rm EN} = 10^{-6} \tag{3.2}$$

$$W_{\rm EN} = 10^{-6} \tag{3.3}$$

$$\Delta L_{\rm PS} = \mathbf{LVARO} \cdot \left( 1 + \mathbf{LVARL} \cdot \frac{L_{\rm EN}}{L} \right) \cdot \left( 1 + \mathbf{LVARW} \cdot \frac{W_{\rm EN}}{W_{\rm f}} \right)$$
(3.4)

$$\Delta W_{\rm OD} = \mathbf{WVARO} \cdot \left( 1 + \mathbf{WVARL} \cdot \frac{L_{\rm EN}}{L} \right) \cdot \left( 1 + \mathbf{WVARW} \cdot \frac{W_{\rm EN}}{W_{\rm f}} \right)$$
(3.5)

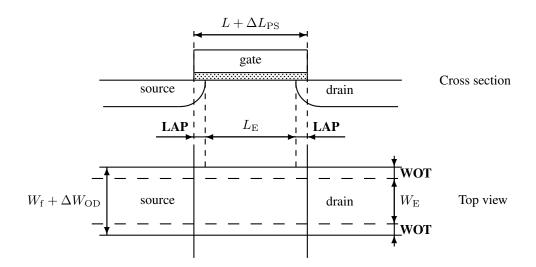


Figure 3.1: Specification of the dimensions of a MOS transistor

$$L_{\rm E} = L - \Delta L = L + \Delta L_{\rm PS} - 2 \cdot \mathbf{LAP}$$
(3.6)

$$W_{\rm E} = W_{\rm f} - \Delta W = W_{\rm f} + \Delta W_{\rm OD} - 2 \cdot \mathbf{WOT}$$
(3.7)

$$L_{\text{E.CV}} = L + \Delta L_{\text{PS}} - 2 \cdot \mathbf{LAP} + \mathbf{DLQ}$$
(3.8)

$$W_{\text{E.CV}} = W_{\text{f}} + \Delta W_{\text{OD}} - 2 \cdot \mathbf{WOT} + \mathbf{DWQ}$$
(3.9)

$$L_{G,CV} = L + \Delta L_{PS} + \mathbf{DLQ} \tag{3.10}$$

$$W_{\rm G,CV} = W_{\rm f} + \Delta W_{\rm OD} + \mathbf{DWQ} \tag{3.11}$$

**Note:** If the calculated  $L_{\rm E}$ ,  $W_{\rm E}$ ,  $L_{\rm E,CV}$ ,  $W_{\rm E,CV}$ ,  $L_{\rm G,CV}$ , or  $W_{\rm G,CV}$  is smaller than 1 nm (10<sup>-9</sup> m), the value is clipped to this lower bound of 1 nm.

#### **Process Parameters**

$$\mathbf{VFB} = \mathbf{VFBO} \cdot \left( 1 + \mathbf{VFBL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right) \cdot \left( 1 + \mathbf{VFBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \right)$$

$$\cdot \left( 1 + \mathbf{VFBLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}} \right) \quad (3.12)$$

$$\mathbf{STVFB} = \mathbf{STVFBO} \cdot \left(1 + \mathbf{STVFBL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right) \cdot \left(1 + \mathbf{STVFBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \mathbf{STVFBLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \quad (3.13)$$

$$TOX = TOXO (3.14)$$

$$EPSROX = EPSROXO (3.15)$$

$$N_{\mathrm{sub0,eff}} = \mathbf{NSUBO} \cdot \mathbf{MAX} \left( \left[ 1 + \mathbf{NSUBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \cdot \ln \left( 1 + \frac{W_{\mathrm{E}}}{\mathbf{WSEG}} \right) \right], 10^{-3} \right)$$
 (3.16)

$$N_{\text{pck,eff}} = \text{NPCK} \cdot \text{MAX} \left( \left[ 1 + \text{NPCKW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left( 1 + \frac{W_{\text{E}}}{\text{WSEGP}} \right) \right], 10^{-3} \right)$$
(3.17)

$$L_{\text{pck,eff}} = \mathbf{LPCK} \cdot \text{MAX} \left( \left[ 1 + \mathbf{LPCKW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \cdot \ln \left( 1 + \frac{W_{\text{E}}}{\mathbf{WSEGP}} \right) \right], 10^{-3} \right)$$
(3.18)

$$a = 7.5 \cdot 10^{10} \tag{3.19}$$

$$b = \sqrt{N_{\text{sub0,eff}} + 0.5 \cdot N_{\text{pck,eff}}} - \sqrt{N_{\text{sub0,eff}}}$$
(3.20)

$$N_{\rm sub0,eff} + N_{\rm pck,eff} \cdot \left[ 2 - \frac{L_{\rm E}}{L_{\rm pck,eff}} \right] \qquad \text{for } L_{\rm E} < L_{\rm pck,eff}$$

$$N_{\rm sub0,eff} + N_{\rm pck,eff} \cdot \frac{L_{\rm pck,eff}}{L_{\rm E}} \qquad \text{for } L_{\rm pck,eff} \le L_{\rm E} \le 2 \cdot L_{\rm pck,eff}$$

$$\left[ \sqrt{N_{\rm sub0,eff}} + a \cdot \ln \left( 1 + 2 \cdot \frac{L_{\rm pck,eff}}{L_{\rm E}} \cdot \left[ \exp \left( \frac{b}{a} \right) - 1 \right] \right) \right]^2 \qquad \text{for } L_{\rm E} > 2 \cdot L_{\rm pck,eff}$$

$$(3.21)$$

$$NEFF = N_{\text{sub}} \cdot \left( 1 - FOL1 \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} - FOL2 \cdot \left[ \frac{L_{\text{EN}}}{L_{\text{E}}} \right]^2 \right)$$
(3.22)

$$VNSUB = VNSUBO (3.23)$$

$$NSLP = NSLPO (3.24)$$

$$DNSUB = DNSUBO (3.25)$$

$$\begin{aligned} \mathbf{DPHIB} &= \left(\mathbf{DPHIBO} + \mathbf{DPHIBL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{DPHIBLEXP}}\right) \\ &\quad \cdot \left(1 + \mathbf{DPHIBW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right) \cdot \left(1 + \mathbf{DPHIBLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \end{aligned} \tag{3.26}$$

$$\mathbf{NP} = \mathbf{NPO} \cdot \text{MAX} \left( 10^{-6}, 1 + \mathbf{NPL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right)$$
 (3.27)

$$\mathbf{CT} = \left(\mathbf{CTO} + \mathbf{CTL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{CTLEXP}}\right) \cdot \left(1 + \mathbf{CTW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \mathbf{CTLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \quad (3.28)$$

$$TOXOV = TOXOVO (3.29)$$

$$TOXOVD = TOXOVDO (3.30)$$

$$NOV = NOVO (3.31)$$

$$NOVD = NOVDO (3.32)$$

#### **DIBL Parameters**

$$\mathbf{CF} = \mathbf{CFL} \cdot \left[ \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right]^{\mathbf{CFLEXP}} \cdot \left( 1 + \mathbf{CFW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \right)$$
(3.33)

$$\mathbf{CFB} = \mathbf{CFBO} \tag{3.34}$$

#### **Mobility Parameters**

$$F_{\beta 1,\text{eff}} = \mathbf{FBET1} \cdot \left( 1 + \mathbf{FBET1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.35)

$$L_{\text{P1,eff}} = \mathbf{LP1} \cdot \text{MAX} \left( \left[ 1 + \mathbf{LP1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right], 10^{-3} \right)$$
 (3.36)

$$G_{\rm P,E} = 1 + F_{\beta 1,\rm eff} \cdot \frac{L_{\rm P1,eff}}{L_{\rm E}} \cdot \left[ 1 - \exp\left(-\frac{L_{\rm E}}{L_{\rm P1,eff}}\right) \right]$$
(3.37)

$$+ \ \mathbf{FBET2} \cdot \frac{\mathbf{LP2}}{L_{\mathrm{E}}} \cdot \left[1 - \exp\left(-\frac{L_{\mathrm{E}}}{\mathbf{LP2}}\right)\right]$$

$$G_{\mathrm{W,E}} = 1 + \mathbf{BETW1} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{BETW2} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \cdot \ln\left(1 + \frac{W_{\mathrm{E}}}{\mathbf{WBET}}\right)$$
 (3.38)

$$\mathbf{BETN} = \frac{\mathbf{UO}}{G_{P,E}} \cdot \frac{W_{E}}{L_{E}} \cdot G_{W,E}$$
(3.39)

$$\begin{aligned} \textbf{STBET} &= \textbf{STBETO} \cdot \left(1 + \textbf{STBETL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}}\right) \cdot \left(1 + \textbf{STBETW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}}\right) \\ & \cdot \left(1 + \textbf{STBETLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}}\right) \end{aligned}$$

$$\mathbf{MUE} = \mathbf{MUEO} \cdot \left[ 1 + \mathbf{MUEW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \right]$$
 (3.40)

$$STMUE = STMUEO (3.41)$$

$$THEMU = THEMUO (3.42)$$

$$STTHEMU = STTHEMUO (3.43)$$

$$\mathbf{CS} = \left(\mathbf{CSO} + \mathbf{CSL} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{CSLEXP}}\right) \cdot \left(1 + \mathbf{CSW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \mathbf{CSLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \quad (3.44)$$

$$STCS = STCSO (3.45)$$

$$\begin{aligned} \mathbf{XCOR} &= \mathbf{XCORO} \cdot \left(1 + \mathbf{XCORL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right) \cdot \left(1 + \mathbf{XCORW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right) \\ & \cdot \left(1 + \mathbf{XCORLW} \cdot \frac{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{E}} \cdot L_{\mathrm{E}}}\right) \end{aligned} \tag{3.46}$$

$$STXCOR = STXCORO (3.47)$$

$$\mathbf{FETA} = \mathbf{FETAO} \tag{3.48}$$

**Series Resistance Parameters** 

$$\mathbf{RS} = \mathbf{RSW1} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \cdot \left[ 1 + \mathbf{RSW2} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \right]$$
(3.49)

$$STRS = STRSO (3.50)$$

$$\mathbf{RSB} = \mathbf{RSBO} \tag{3.51}$$

$$RSG = RSGO (3.52)$$

**Velocity Saturation Parameters** 

$$\begin{aligned} \textbf{THESAT} &= \left( \textbf{THESATO} + \textbf{THESATL} \cdot \frac{G_{\text{W,E}}}{G_{\text{P,E}}} \cdot \left[ \frac{L_{\text{EN}}}{L_{\text{E}}} \right]^{\textbf{THESATLEXP}} \right) \\ & \cdot \left( 1 + \textbf{THESATW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right) \cdot \left( 1 + \textbf{THESATLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}} \right) \end{aligned} \tag{3.53}$$

$$\mathbf{STTHESAT} = \mathbf{STTHESATO} \cdot \left(1 + \mathbf{STTHESATL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right)$$

$$\cdot \left(1 + \textbf{STTHESATW} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}}\right) \cdot \left(1 + \textbf{STTHESATLW} \cdot \frac{W_{\text{EN}} \cdot L_{\text{EN}}}{W_{\text{E}} \cdot L_{\text{E}}}\right) \quad (3.54)$$

$$THESATB = THESATBO (3.55)$$

$$THESATG = THESATGO (3.56)$$

#### **Saturation Voltage Parameter**

$$\mathbf{AX} = \frac{\mathbf{AXO}}{1 + \mathbf{AXL} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}}}$$
(3.57)

#### **Channel Length Modulation (CLM) Parameters**

$$\mathbf{ALP} = \mathbf{ALPL} \cdot \left[ \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} \right]^{\mathbf{ALPLEXP}} \cdot \left( 1 + \mathbf{ALPW} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} \right)$$
(3.58)

$$\mathbf{ALP1} = \frac{\mathbf{ALP1L1} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}}\right]^{\mathbf{ALP1LEXP}}}{1 + \mathbf{ALP1L2} \cdot \left[\frac{L_{\text{EN}}}{L_{\text{E}}}\right]^{\mathbf{ALP1LEXP+1}} \cdot \left(1 + \mathbf{ALP1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}}\right)$$
(3.59)

$$\mathbf{ALP2} = \frac{\mathbf{ALP2L1} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{ALP2LEXP}}}{1 + \mathbf{ALP2L2} \cdot \left[\frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}\right]^{\mathbf{ALP2LEXP}+1}} \cdot \left(1 + \mathbf{ALP2W} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}}\right)$$
(3.60)

$$\mathbf{VP} = \mathbf{VPO} \tag{3.61}$$

#### Impact Ionization (II) Parameters

$$\mathbf{A1} = \mathbf{A10} \cdot \left( 1 + \mathbf{A1L} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left( 1 + \mathbf{A1W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.62)

$$A2 = A2O \tag{3.63}$$

$$STA2 = STA2O (3.64)$$

$$\mathbf{A3} = \mathbf{A3O} \cdot \left( 1 + \mathbf{A3L} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left( 1 + \mathbf{A3W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.65)

$$\mathbf{A4} = \mathbf{A4O} \cdot \left( 1 + \mathbf{A4L} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} \right) \cdot \left( 1 + \mathbf{A4W} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \right)$$
(3.66)

#### **Gate Current Parameters**

$$GCO = GCOO (3.67)$$

$$\mathbf{IGINV} = \mathbf{IGINVLW} \cdot \frac{W_{\text{E}} \cdot L_{\text{E}}}{W_{\text{EN}} \cdot L_{\text{EN}}}$$
(3.68)

$$\mathbf{IGOV} = \mathbf{IGOVW} \cdot \frac{W_{\text{E}} \cdot \mathbf{LOV}}{W_{\text{EN}} \cdot L_{\text{EN}}}$$
(3.69)

$$\mathbf{IGOVD} = \mathbf{IGOVDW} \cdot \frac{W_{\text{E}} \cdot \mathbf{LOVD}}{W_{\text{EN}} \cdot L_{\text{EN}}}$$
(3.70)

$$STIG = STIGO (3.71)$$

$$GC2 = GC2O (3.72)$$

$$GC3 = GC3O (3.73)$$

$$\mathbf{CHIB} = \mathbf{CHIBO} \tag{3.74}$$

#### Gate-Induced Drain Leakage (GIDL) Parameters

$$\mathbf{AGIDL} = \mathbf{AGIDLW} \cdot \frac{W_{\mathrm{E}} \cdot \mathbf{LOV}}{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}$$
(3.75)

$$\mathbf{AGIDLD} = \mathbf{AGIDLDW} \cdot \frac{W_{\mathrm{E}} \cdot \mathbf{LOVD}}{W_{\mathrm{EN}} \cdot L_{\mathrm{EN}}}$$
(3.76)

$$BGIDL = BGIDLO (3.77)$$

$$BGIDLD = BGIDLDO (3.78)$$

$$STBGIDL = STBGIDLO (3.79)$$

$$STBGIDLD = STBGIDLDO (3.80)$$

$$CGIDL = CGIDLO (3.81)$$

$$CGIDLD = CGIDLDO (3.82)$$

#### **Charge Model Parameters**

$$\epsilon_{\text{ox}} = \epsilon_0 \cdot \mathbf{EPSROX} \tag{3.83}$$

$$\mathbf{COX} = \epsilon_{\text{ox}} \cdot \frac{W_{\text{E,CV}} \cdot L_{\text{E,CV}}}{\mathbf{TOX}}$$
(3.84)

$$\mathbf{CGOV} = \epsilon_{\mathrm{ox}} \cdot \frac{W_{\mathrm{E,CV}} \cdot \mathbf{LOV}}{\mathbf{TOXOV}}$$
(3.85)

$$\mathbf{CGOVD} = \epsilon_{ox} \cdot \frac{W_{E,CV} \cdot \mathbf{LOVD}}{\mathbf{TOXOVD}}$$
(3.86)

$$\mathbf{CGBOV} = \mathbf{CGBOVL} \cdot \frac{L_{G,CV}}{L_{EN}}$$
(3.87)

$$\mathbf{CFR} = \mathbf{CFRW} \cdot \frac{W_{\mathrm{G,CV}}}{W_{\mathrm{EN}}}$$
 (3.88)

$$\mathbf{CFRD} = \mathbf{CFRDW} \cdot \frac{W_{G,CV}}{W_{EN}} \tag{3.89}$$

#### **Noise Model Parameters**

$$L_{\text{noi}} = \text{MAX}\left(1 - \frac{2 \cdot \textbf{LINTNOI}}{L_{\text{E}}}, 10^{-3}\right)$$
(3.90)

$$L_{\rm red} = \frac{1}{L_{\rm noi}^{\rm ALPNOI}} \tag{3.91}$$

$$NFA = L_{red} \cdot NFALW \cdot \frac{W_{EN} \cdot L_{EN}}{W_{E} \cdot L_{E}}$$
(3.92)

$$NFB = L_{red} \cdot NFBLW \cdot \frac{W_{EN} \cdot L_{EN}}{W_{E} \cdot L_{E}}$$
(3.93)

$$NFC = L_{red} \cdot NFCLW \cdot \frac{W_{EN} \cdot L_{EN}}{W_{E} \cdot L_{E}}$$
(3.94)

$$\mathbf{EF} = \mathbf{EFO} \tag{3.95}$$

#### **WPE** parameters

$$K_{\rm vthowe} = \textbf{KVTHOWEO} + \textbf{KVTHOWEL} \cdot \frac{L_{\rm EN}}{L_{\rm E}} + \textbf{KVTHOWEW} \cdot \frac{W_{\rm EN}}{W_{\rm E}} \\ + \textbf{KVTHOWELW} \cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}} \quad (3.96)$$

$$K_{\rm uowe} = {\bf KUOWEO} + {\bf KUOWEL} \cdot \frac{L_{\rm EN}}{L_{\rm E}} + {\bf KUOWEW} \cdot \frac{W_{\rm EN}}{W_{\rm E}} \\ + {\bf KUOWELW} \cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}} \quad (3.97)$$

### 3.3 Binning equations

The binning equations are provided as a (phenomenological) alternative to the physical scaling equations for computing local parameters. The physical geometrical scaling rules have been developed to give a good description over the whole geometry range of CMOS technologies. For processes under development, however, it is sometimes useful to have more flexible scaling relations. In that case on could opt for a binning strategy, where the accuracy with geometry is mostly determined by the number of bins used. The physical scaling rules of Section 3.2 are generally not suitable for binning strategies, since they may result in discontinuities in local parameter values at the bin boundaries. Consequently, special binning geometrical scaling relations have been developed, which guarantee continuity of the resulting local model parameters at the bin boundaries.

Only four different types of binning scaling rules are used, which are based on first order developments of the geometrical scaling rules in terms of  $L_{\rm E}$ ,  $1/L_{\rm E}$ ,  $W_{\rm E}$ , and  $1/W_{\rm E}$  (examples below are for a fictitious parameter YYY):

1. Type I

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWYYY} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWYYY} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.98)

2. Type II

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{\mathrm{E}}}{L_{\mathrm{EN}}} + \mathbf{PWYYY} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWYYY} \cdot \frac{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}$$
(3.99)

3. Type III

$$\mathbf{YYY} = \mathbf{POYYY} + \mathbf{PLYYY} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWYYY} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWYYY} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}}$$
(3.100)

4. Type IV (no binning)

$$\mathbf{YYY} = \mathbf{POYYY} \tag{3.101}$$

In Table 3.1 a survey of the binning type used for each local parameter is given. In some cases where the geometrical scaling rule is constant, the binning rule is chosen to be more flexible.

When using the binning rules above, the binning parameters for one bin can be directly calculated from the local parameter sets of the four corner devices of the bin (see Sec. 7.6). This results in a *separate parameter set* for each bin. The binning scheme ensures that the local parameters are exactly reproduced at the bin corners and that no humps occur in the local parameter values across bin boundaries.

**Note:** After calculation of the local parameters from the binning rules (and possible application of the stress equations in Section 3.5), clipping is applied according to Section 2.5.7.

Table 3.1: Overview of local parameters and binning type. The third column indicates whether there is a physical geometrical scaling rule for the local parameters.

#	parameter	physical	binning	#	parameter	physical	binning
		scaling				scaling	
0	LEVEL	no	no	42	STTHESAT	yes	type I
1	ТҮРЕ	no	no	43	THESATB	no	type I
2	TR	no	no	44	THESATG	no	type I
3	SWIGATE	no	no	45	AX	yes	type I
4	SWIMPACT	no	no	46	ALP	yes	type I
5	SWGIDL	no	no	47	ALP1	yes	type I
6	SWJUNCAP	no	no	48	ALP2	yes	type I
7	SWJUNASYM	no	no	49	VP	no	no
8	QMC	no	no	50	A1	yes	type I
9	VFB	yes	type I	51	A2	no	no
10	STVFB	yes	type I	52	STA2	no	no
11	TOX	no	no	53	A3	yes	type I
12	EPSROX	no	no	54	A4	yes	type I
13	NEFF	yes	type I	55	GCO	no	no
14	VNSUB	no	no	56	IGINV	yes	type II
15	NSLP	no	no	57	IGOV	yes	type III
16	DNSUB	no	no	58	IGOVD	yes	type III
17	DPHIB	yes	type I	59	STIG	no	no
18	NP	yes	type I	60	GC2	no	no
19	CT	yes	type I	61	GC3	no	no
20	TOXOV	no	no	62	CHIB	no	no
21	TOXOVD	no	no	63	AGIDL	yes	type III
22	NOV	no	type I	64	AGIDLD	yes	type III
23	NOVD	no	Type I	65	BGIDL	no	no
24	CF	yes	type I	66	BGIDLD	no	no
25	CFB	no	no	67	STBGIDL	no	no
26	BETN	yes	type III	68	STBGIDLD	no	no
27	STBET	yes	type I	69	CGIDL	no	no
28	MUE	yes	type I	70	CGIDLD	no	no
29	STMUE	no	no	71	COX	yes	type II
30	THEMU	no	no	72	CGOV	yes	type III
31	STTHEMU	no	no	73	CGOVD	yes	type III
32	CS	yes	type I	74	CGBOV	yes	type II
33	STCS	no	no	75	CFR	yes	type III
34	XCOR	yes	type I	76	CFRD	yes	type III
35	STXCOR	no	no	77	FNT	no	no
36	FETA	no	no	78	NFA	yes	type I
37	RS	yes	type I	79	NFB	yes	type I
38	STRS	no	no	80	NFC	yes	type I
39	RSB	no	no	81	EF	no	no
40	RSG	no	no	82	DTA	no	no
41	THESAT	yes	type I				

#### Effective length and width

$$L_{\rm EN} = 10^{-6} \tag{3.102}$$

$$W_{\rm EN} = 10^{-6} \tag{3.103}$$

$$\Delta L_{\rm PS} = \mathbf{LVARO} \cdot \left( 1 + \mathbf{LVARL} \cdot \frac{L_{\rm EN}}{L} \right)$$
 (3.104)

$$\Delta W_{\rm OD} = \mathbf{WVARO} \cdot \left( 1 + \mathbf{WVARW} \cdot \frac{W_{\rm EN}}{W_{\rm f}} \right)$$
 (3.105)

$$L_{\rm E} = L - \Delta L = L + \Delta L_{\rm PS} - 2 \cdot \mathbf{LAP}$$
(3.106)

$$W_{\rm E} = W_{\rm f} - \Delta W = W_{\rm f} + \Delta W_{\rm OD} - 2 \cdot \mathbf{WOT} \tag{3.107}$$

$$L_{\rm E,CV} = L + \Delta L_{\rm PS} - 2 \cdot \mathbf{LAP} + \mathbf{DLQ}$$
(3.108)

$$W_{E,CV} = W_f + \Delta W_{OD} - 2 \cdot WOT + DWQ$$
 (3.109)

$$L_{G,CV} = L + \Delta L_{PS} + \mathbf{DLQ} \tag{3.110}$$

$$W_{G,CV} = W_f + \Delta W_{OD} + \mathbf{DWQ} \tag{3.111}$$

**Note:** If the calculated  $L_{\rm E}$ ,  $W_{\rm E}$ ,  $L_{\rm E,CV}$ ,  $W_{\rm E,CV}$ ,  $L_{\rm G,CV}$ , or  $W_{\rm G,CV}$  is smaller than 1 nm (10<sup>-9</sup> m), the value is clipped to this lower bound of 1 nm.

#### **Process Parameters**

$$\mathbf{VFB} = \mathbf{POVFB} + \mathbf{PLVFB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWVFB} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWVFB} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.112)

$$\mathbf{STVFB} = \mathbf{POSTVFB} + \mathbf{PLSTVFB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWSTVFB} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWSTVFB} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} (3.113)$$

$$TOX = POTOX (3.114)$$

$$EPSROX = POEPSROX (3.115)$$

$$\mathbf{NEFF} = \mathbf{PONEFF} + \mathbf{PLNEFF} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNEFF} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNEFF} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.116)

$$VNSUB = POVNSUB$$
 (3.117)

$$NSLP = PONSLP (3.118)$$

$$DNSUB = PODNSUB$$
 (3.119)

$$\mathbf{DPHIB} = \mathbf{PODPHIB} + \mathbf{PLDPHIB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWDPHIB} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWDPHIB} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} (3.120)$$

$$\mathbf{NP} = \mathbf{PONP} + \mathbf{PLNP} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNP} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNP} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.121)

$$\mathbf{CT} = \mathbf{POCT} + \mathbf{PLCT} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWCT} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWCT} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.122)

$$TOXOV = POTOXOV (3.123)$$

$$TOXOVD = POTOXOVD (3.124)$$

$$\mathbf{NOV} = \mathbf{PONOV} + \mathbf{PLNOV} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNOV} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNOV} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.125)

$$\mathbf{NOVD} = \mathbf{PONOVD} + \mathbf{PLNOVD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNOVD} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNOVD} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.126)$$

#### **DIBL Parameters**

$$\mathbf{CF} = \mathbf{POCF} + \mathbf{PLCF} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWCF} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWCF} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.127)

$$\mathbf{CFB} = \mathbf{POCFB} \tag{3.128}$$

#### **Mobility Parameters**

$$\mathbf{BETN} = \mathbf{POBETN} + \mathbf{PLBETN} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWBETN} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWBETN} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}}$$
(3.129)

$$\mathbf{STBET} = \mathbf{POSTBET} + \mathbf{PLSTBET} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWSTBET} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWSTBET} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} (3.130)$$

$$\mathbf{MUE} = \mathbf{POMUE} + \mathbf{PLMUE} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWMUE} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWMUE} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.131)

$$\mathbf{STMUE} = \mathbf{POSTMUE} \tag{3.132}$$

$$THEMU = POTHEMU (3.133)$$

$$\mathbf{STTHEMU} = \mathbf{POSTTHEMU} \tag{3.134}$$

$$\mathbf{CS} = \mathbf{POCS} + \mathbf{PLCS} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWCS} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWCS} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.135)

$$STCS = POSTCS (3.136)$$

$$\mathbf{XCOR} = \mathbf{POXCOR} + \mathbf{PLXCOR} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWXCOR} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWXCOR} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.137)$$

$$\mathbf{STXCOR} = \mathbf{POSTXCOR} \tag{3.138}$$

$$\mathbf{FETA} = \mathbf{POFETA} \tag{3.139}$$

#### **Series Resistance Parameters**

$$\mathbf{RS} = \mathbf{PORS} + \mathbf{PLRS} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWRS} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWRS} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.140)

$$STRS = POSTRS \tag{3.141}$$

$$RSB = PORSB \tag{3.142}$$

$$RSG = PORSG (3.143)$$

#### **Velocity Saturation Parameters**

 $\mathbf{THESAT} = \mathbf{POTHESAT} + \mathbf{PLTHESAT} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$ 

$$+ \mathbf{PWTHESAT} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWTHESAT} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.144)$$

 $\mathbf{STTHESAT} = \mathbf{POSTTHESAT} + \mathbf{PLSTTHESAT} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$ 

$$+ \mathbf{PWSTTHESAT} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWSTTHESAT} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}} \quad (3.145)$$

 $\mathbf{THESATB} = \mathbf{POTHESATB} + \mathbf{PLTHESATB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$ 

+ PWTHESATB 
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWTHESATB  $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$  (3.146)

 $\mathbf{THESATG} = \mathbf{POTHESATG} + \mathbf{PLTHESATG} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$ 

+ PWTHESATG 
$$\cdot \frac{W_{\text{EN}}}{W_{\text{E}}}$$
 + PLWTHESATG  $\cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$  (3.147)

#### **Saturation Voltage Parameters**

$$\mathbf{AX} = \mathbf{POAX} + \mathbf{PLAX} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \mathbf{PWAX} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} + \mathbf{PLWAX} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}}$$
(3.148)

### **Channel Length Modulation (CLM) Parameters**

$$\mathbf{ALP} = \mathbf{POALP} + \mathbf{PLALP} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWALP} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWALP} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.149)

$$\mathbf{ALP1} = \mathbf{POALP1} + \mathbf{PLALP1} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWALP1} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWALP1} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.150)

$$\mathbf{ALP2} = \mathbf{POALP2} + \mathbf{PLALP2} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWALP2} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWALP2} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.151)

$$\mathbf{VP} = \mathbf{POVP} \tag{3.152}$$

#### **Impact Ionization (II) Parameters**

$$\mathbf{A1} = \mathbf{POA1} + \mathbf{PLA1} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWA1} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWA1} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.153)

$$\mathbf{A2} = \mathbf{POA2} \tag{3.154}$$

$$STA2 = POSTA2 (3.155)$$

$$\mathbf{A3} = \mathbf{POA3} + \mathbf{PLA3} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWA3} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWA3} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.156)

$$\mathbf{A4} = \mathbf{POA4} + \mathbf{PLA4} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWA4} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWA4} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.157)

**Gate Current Parameters** 

$$GCO = POGCO (3.158)$$

$$\mathbf{IGINV} = \mathbf{POIGINV} + \mathbf{PLIGINV} \cdot \frac{L_{\mathrm{E}}}{L_{\mathrm{EN}}}$$

$$+ \mathbf{PWIGINV} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWIGINV} \cdot \frac{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}} \quad (3.159)$$

$$\mathbf{IGOV} = \mathbf{POIGOV} + \mathbf{PLIGOV} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWIGOV} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWIGOV} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}}$$
(3.160)

$$\mathbf{IGOVD} = \mathbf{POIGOVD} + \mathbf{PLIGOVD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWIGOVD} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWIGOVD} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}} (3.161)$$

$$STIG = POSTIG (3.162)$$

$$GC2 = POGC2 (3.163)$$

$$GC3 = POGC3 \tag{3.164}$$

$$\mathbf{CHIB} = \mathbf{POCHIB} \tag{3.165}$$

#### Gate-Induced Drain Leakage (GIDL) Parameters

$$\mathbf{AGIDL} = \mathbf{POAGIDL} + \mathbf{PLAGIDL} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$$

$$+ \mathbf{PWAGIDL} \cdot \frac{W_{\mathrm{E}}}{W_{\mathrm{EN}}} + \mathbf{PLWAGIDL} \cdot \frac{W_{\mathrm{E}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E}}} \quad (3.166)$$

$$\mathbf{AGIDLD} = \mathbf{POAGIDLD} + \mathbf{PLAGIDLD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}}$$

+ PWAGIDLD 
$$\cdot \frac{W_{\rm E}}{W_{\rm EN}}$$
 + PLWAGIDLD  $\cdot \frac{W_{\rm E} \cdot L_{\rm EN}}{W_{\rm EN} \cdot L_{\rm E}}$  (3.167)

$$BGIDL = POBGIDL (3.168)$$

$$BGIDLD = POBGIDLD (3.169)$$

$$STBGIDL = POSTBGIDL (3.170)$$

$$STBGIDLD = POSTBGIDLD (3.171)$$

$$CGIDL = POCGIDL (3.172)$$

$$CGIDLD = POCGIDLD (3.173)$$

#### **Charge Model Parameters**

$$\mathbf{COX} = \mathbf{POCOX} + \mathbf{PLCOX} \cdot \frac{L_{\mathrm{E,CV}}}{L_{\mathrm{EN}}} + \mathbf{PWCOX} \cdot \frac{W_{\mathrm{E,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCOX} \cdot \frac{L_{\mathrm{E,CV}} \cdot W_{\mathrm{E,CV}}}{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}$$
(3.174)

$$\mathbf{CGOV} = \mathbf{POCGOV} + \mathbf{PLCGOV} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{ECV}}}$$

+ **PWCGOV** · 
$$\frac{W_{\text{E,CV}}}{W_{\text{EN}}}$$
 + **PLWCGOV** ·  $\frac{W_{\text{E,CV}} \cdot L_{\text{EN}}}{W_{\text{EN}} \cdot L_{\text{E,CV}}}$  (3.175)

$$\mathbf{CGOVD} = \mathbf{POCGOVD} + \mathbf{PLCGOVD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E.CV}}}$$

$$+ \mathbf{PWCGOVD} \cdot \frac{W_{\mathrm{E,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCGOVD} \cdot \frac{W_{\mathrm{E,CV}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{E,CV}}} \quad (3.176)$$

$$\mathbf{CGBOV} = \mathbf{POCGBOV} + \mathbf{PLCGBOV} \cdot \frac{L_{\mathrm{G,CV}}}{L_{\mathrm{EN}}}$$

+ PWCGBOV · 
$$\frac{W_{G,CV}}{W_{EN}}$$
 + PLWCGBOV ·  $\frac{L_{G,CV} \cdot W_{G,CV}}{L_{EN} \cdot W_{EN}}$  (3.177)

$$\mathbf{CFR} = \mathbf{POCFR} + \mathbf{PLCFR} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{G,CV}}} + \mathbf{PWCFR} \cdot \frac{W_{\mathrm{G,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCFR} \cdot \frac{W_{\mathrm{G,CV}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{G,CV}}}$$
(3.178)

$$\mathbf{CFRD} = \mathbf{POCFRD} + \mathbf{PLCFRD} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{G,CV}}} + \mathbf{PWCFRD} \cdot \frac{W_{\mathrm{G,CV}}}{W_{\mathrm{EN}}} + \mathbf{PLWCFRD} \cdot \frac{W_{\mathrm{G,CV}} \cdot L_{\mathrm{EN}}}{W_{\mathrm{EN}} \cdot L_{\mathrm{G,CV}}} (3.179)$$

#### **Noise Model Parameters**

$$\mathbf{FNT} = \mathbf{POFNT} \tag{3.180}$$

$$NFA = PONFA + PLNFA \cdot \frac{L_{EN}}{L_{E}} + PWNFA \cdot \frac{W_{EN}}{W_{E}} + PLWNFA \cdot \frac{L_{EN} \cdot W_{EN}}{L_{E} \cdot W_{E}}$$
(3.181)

$$\mathbf{NFB} = \mathbf{PONFB} + \mathbf{PLNFB} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNFB} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNFB} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.182)

$$\mathbf{NFC} = \mathbf{PONFC} + \mathbf{PLNFC} \cdot \frac{L_{\mathrm{EN}}}{L_{\mathrm{E}}} + \mathbf{PWNFC} \cdot \frac{W_{\mathrm{EN}}}{W_{\mathrm{E}}} + \mathbf{PLWNFC} \cdot \frac{L_{\mathrm{EN}} \cdot W_{\mathrm{EN}}}{L_{\mathrm{E}} \cdot W_{\mathrm{E}}}$$
(3.183)

$$\mathbf{EF} = \mathbf{POEF} \tag{3.184}$$

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#### WPE parameters

$$K_{\rm vthowe} = \textbf{POKVTHOWE} + \textbf{PLKVTHOWE} \cdot \frac{L_{\rm EN}}{L_{\rm E}} + \textbf{PWKVTHOWE} \cdot \frac{W_{\rm EN}}{W_{\rm E}} \\ + \textbf{PLWKVTHOWE} \cdot \frac{L_{\rm EN} \cdot W_{\rm EN}}{L_{\rm E} \cdot W_{\rm E}} \quad (3.185)$$

$$\begin{split} K_{\text{uowe}} &= \textbf{POKUOWE} + \textbf{PLKUOWE} \cdot \frac{L_{\text{EN}}}{L_{\text{E}}} + \textbf{PWKUOWE} \cdot \frac{W_{\text{EN}}}{W_{\text{E}}} \\ &+ \textbf{PLWKUOWE} \cdot \frac{L_{\text{EN}} \cdot W_{\text{EN}}}{L_{\text{E}} \cdot W_{\text{E}}} \quad (3.186) \end{split}$$

### 3.4 Parasitic resistances

PSP model contains a network of parasitic elements: a gate resistance and four bulk resistances. Note that the junction diodes are no longer directly connected to the bulk terminal of the intrinsic MOS-transistor. The complete circuit is shown in Fig. 3.2. At this moment, only the gate resistance is scaled with geometry (facilitating the implementation of multi-finger devices).

$$L_{\rm f} = L + \Delta L_{\rm PS} \tag{3.187}$$

$$L_{\rm sil,f} = L_{\rm f} + \mathbf{DLSIL} \tag{3.188}$$

$$W_{\rm E,f} = W_{\rm f} + \Delta W_{\rm OD} \tag{3.189}$$

$$X_{\text{GWE}} = \mathbf{XGW} - 0.5 \cdot \Delta W_{\text{OD}} \tag{3.190}$$

$$\mathbf{RG} = \mathbf{RGO} + \frac{1}{\mathbf{NF}} \cdot \left[ \frac{\mathbf{RSHG} \cdot \left( \frac{W_{\mathrm{E,f}}}{3 \cdot \mathbf{NGCON}} + X_{\mathrm{GWE}} \right)}{\mathbf{NGCON} \cdot L_{\mathrm{sil,f}}} + \frac{\mathbf{RINT} + \mathbf{RVPOLY}}{W_{\mathrm{E,f}} \cdot L_{\mathrm{f}}} \right]$$
(3.191)

$$\mathbf{RBULK} = \mathbf{RBULKO} \tag{3.192}$$

$$\mathbf{RWELL} = \mathbf{RWELLO} \tag{3.193}$$

$$RJUNS = RJUNSO (3.194)$$

$$\mathbf{RJUND} = \mathbf{RJUNDO} \tag{3.195}$$

**Note:** The values of  $L_{\rm f}$ ,  $L_{\rm sil,f}$ ,  $W_{\rm E,f}$  and  $X_{\rm GWE}$  are clipped to a minimum value of 1 nm. The calculated local parameters are subject to the boundaries specified in Section 2.5.9.

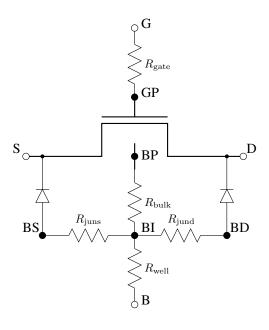


Figure 3.2: Parasitics circuit

#### 3.5 **Stress effects**

The stress model of BSIM4.4.0 [3] has been adopted in PSP without any modifications, except for two changes: (1) in the original BSIM parameter names all zeros have been replaced by "O"s, in order to comply with PSP conventions and (2) the BSIM parameters STK2 and LODK2 are not available in PSP. Some trivial conversion of parameters BSIM  $\rightarrow$  PSP is still necessary, see [2].

The local PSP parameters affected by the stress equations are BETN, THESAT, VFB, and CF.

Calculation of SA and SB for irregular layouts is given in Section B.1.

- **Note:** After modification of the local parameters by the stress equations, clipping is applied according to Sec-
  - If both **SA** and **SB** are set to 0, the stress-equations are *not* computed.

#### 3.5.1 Layout effects for multi-finger devices

For multi-finger devices, effective values  $SA_{\mathrm{eff}}$  and  $SB_{\mathrm{eff}}$  for the instance parameters are calculated (see Fig.

$$\frac{1}{\mathbf{SA}_{\text{eff}} + 0.5 \cdot L} = \frac{1}{\mathbf{NF}} \cdot \sum_{i=0}^{\mathbf{NF}-1} \frac{1}{\mathbf{SA} + 0.5 \cdot L + i \cdot (\mathbf{SD} + L)}$$
(3.196)

$$\frac{1}{\mathbf{SB}_{\text{eff}} + 0.5 \cdot L} = \frac{1}{\mathbf{NF}} \cdot \sum_{i=0}^{\mathbf{NF}-1} \frac{1}{\mathbf{SB} + 0.5 \cdot L + i \cdot (\mathbf{SD} + L)}$$
(3.197)

#### 3.5.2 Layout effects for regular shapes

$$R_{\mathcal{A}} = \frac{1}{\mathbf{S}\mathbf{A}_{\text{eff}} + 0.5 \cdot L} \tag{3.198}$$

$$R_{\rm B} = \frac{1}{\mathbf{SB}_{\rm eff} + 0.5 \cdot L} \tag{3.199}$$

$$R_{\text{A,ref}} = \frac{1}{\text{SAREF} + 0.5 \cdot L} \tag{3.200}$$

$$R_{\text{B,ref}} = \frac{1}{\text{SBREF} + 0.5 \cdot L} \tag{3.201}$$

#### 3.5.3 Parameter modifications

**Mobility-related equations** 

$$\begin{split} K_{\text{u0}} &= \left(1 + \frac{\textbf{LKUO}}{\left(L + \Delta L_{\text{PS}}\right)^{\textbf{LLODKUO}}} + \frac{\textbf{WKUO}}{\left(W_{\text{f}} + \Delta W_{\text{OD}} + \textbf{WLOD}\right)^{\textbf{WLODKUO}}} \right. \\ &\quad \left. + \frac{\textbf{PKUO}}{\left(L + \Delta L_{\text{PS}}\right)^{\textbf{LLODKUO}} \cdot \left(W_{\text{f}} + \Delta W_{\text{OD}} + \textbf{WLOD}\right)^{\textbf{WLODKUO}}} \right) \\ &\quad \left. \cdot \left[1 + \textbf{TKUO} \cdot \left(\frac{T_{\text{KD}}}{T_{\text{KR}}} - 1\right)\right] \quad (3.202) \end{split}$$

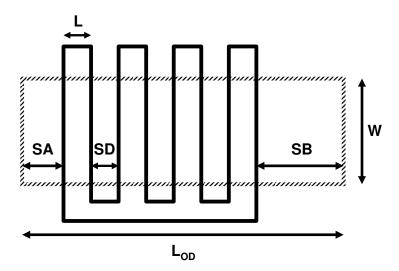


Figure 3.3: A typical layout of multi-finger devices with an additional instance parameters **SD**.

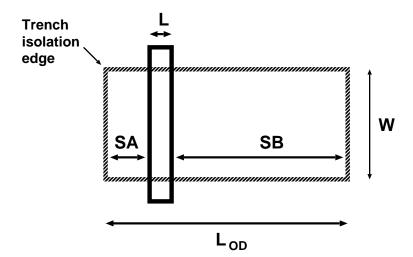


Figure 3.4: Typical layout of a MOSFET. Note that  $L_{\rm OD} = {\bf SA} + {\bf SB} + L$ , where OD is the active region definition.

$$\rho_{\beta} = \frac{\text{KUO}}{K_{\text{u0}}} \cdot (R_{\text{A}} + R_{\text{B}}) \tag{3.203}$$

$$\rho_{\beta,\text{ref}} = \frac{\text{KUO}}{K_{\text{u0}}} \cdot (R_{\text{A,ref}} + R_{\text{B,ref}}) \tag{3.204}$$

$$\mathbf{BETN} = \frac{1 + \rho_{\beta}}{1 + \rho_{\beta,\text{ref}}} \cdot \mathbf{BETN}_{\text{ref}}$$
(3.205)

$$\mathbf{THESAT} = \frac{1 + \rho_{\beta}}{1 + \rho_{\beta, ref}} \cdot \frac{1 + \mathbf{KVSAT} \cdot \rho_{\beta, ref}}{1 + \mathbf{KVSAT} \cdot \rho_{\beta}} \cdot \mathbf{THESAT}_{ref}$$
(3.206)

# Threshold-voltage-related equations

$$K_{\rm vth0} = 1 + \frac{{\bf LKVTHO}}{{(L + \Delta L_{\rm PS})}^{{\bf LLODVTH}}} + \frac{{\bf WKVTHO}}{{(W_{\rm f} + \Delta W_{\rm OD} + {\bf WLOD})}^{{\bf WLODVTH}}} \\ + \frac{{\bf PKVTHO}}{{(L + \Delta L_{\rm PS})}^{{\bf LLODVTH}} \cdot (W_{\rm f} + \Delta W_{\rm OD} + {\bf WLOD})^{{\bf WLODVTH}}}} \quad (3.207)$$

$$\Delta R = R_{\rm A} + R_{\rm B} - R_{\rm A,ref} - R_{\rm B,ref} \tag{3.208}$$

$$\mathbf{VFB} = \mathbf{VFB}_{ref} + \mathbf{KVTHO} \cdot \frac{\Delta R}{K_{vth0}}$$
(3.209)

$$\mathbf{CF} = \mathbf{CF}_{\text{ref}} + \mathbf{STETAO} \cdot \frac{\Delta R}{K_{\text{vth0}}^{\text{LODETAO}}}$$
(3.210)

# 3.6 Well proximity effects

The well proximity effect (WPE) model from BSIM4.5.0 [4, 5, 6] has been adopted in PSP with two changes relative to BSIM4.5.0: (1) in the original BSIM parameter names all zeros have been replaced by 'O's in order to comply with PSP naming convention and (2) the BSIM parameter K2WE is not available in PSP. Except for some trivial conversion of parameters BSIM $\rightarrow$ PSP [2], WPE parameters from BSIM can be used directly in PSP.

The local PSP parameters affected by the WPE equations are VFB and BETN.

How to calculate SCA, SCB, and SCC is shown in Section B.2.

# Note:

- After modification of the local parameters by the WPE equations, clipping is applied according to Section 2.5.7.
- If SCA, SCB, SCC and SC are all set to 0, the WPE equations are *not* computed.

# 3.6.1 Parameters for pre-layout simulation

If SCA = SCB = SCC = 0 and SC > 0, SCA, SCB, and SCC will be computed from SC according to Eqs. (B.9)–(B.11), as shown below. Here, SC should be taken as the distance to the nearest well edge (see Fig. 3.5). If any of the parameters SCA, SCB, or SCC is positive, all three values as supplied will be used and SC will be ignored.

If SCA = SCB = SCC = 0 and SC > 0

$$\mathbf{SCA} = \frac{\mathbf{SCREF}^2}{W_{\mathrm{f}}} \cdot \left(\frac{1}{\mathbf{SC}} - \frac{1}{\mathbf{SC} + W_{\mathrm{f}}}\right)$$
(3.211)

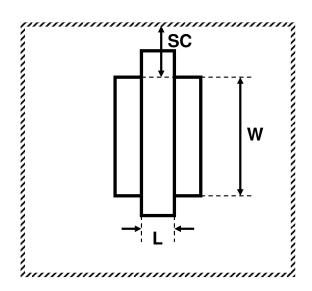


Figure 3.5: A layout of MOS devices for pre-layout simulation using estimated value for SC.

$$\begin{aligned} \mathbf{SCB} &= \frac{1}{W_{\mathrm{f}} \cdot \mathbf{SCREF}} \cdot \left[ \frac{\mathbf{SCREF}}{10} \cdot \mathbf{SC} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) + \frac{\mathbf{SCREF}^2}{100} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) \right. \\ &\left. - \frac{\mathbf{SCREF}}{10} \cdot (\mathbf{SC} + W_{\mathrm{f}}) \cdot \exp\left(-10 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}}\right) \right. \\ &\left. - \frac{\mathbf{SCREF}^2}{100} \cdot \exp\left(-10 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}}\right) \right] \quad (3.212) \\ \mathbf{SCC} &= \frac{1}{W_{\mathrm{f}} \cdot \mathbf{SCREF}} \cdot \left[ \frac{\mathbf{SCREF}}{20} \cdot \mathbf{SC} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) + \frac{\mathbf{SCREF}^2}{400} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC}}{\mathbf{SCREF}}\right) \right] \end{aligned}$$

 $-\frac{\mathbf{SCREF}}{20} \cdot (\mathbf{SC} + W_{\mathrm{f}}) \cdot \exp\left(-20 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}}\right)$ 

# 3.6.2 Calculation of parameter modifications

The calculation of  $K_{\text{vthowe}}$  and  $K_{\text{uowe}}$  is given in Section 3.2 (global model) or 3.3 (binning model).

$$VFB = VFB_{ref} + K_{vthowe} \cdot (SCA + WEB \cdot SCB + WEC \cdot SCC)$$
(3.214)

 $-\frac{\mathbf{SCREF}^2}{400} \cdot \exp\left(-20 \cdot \frac{\mathbf{SC} + W_{\mathrm{f}}}{\mathbf{SCREF}}\right)$ 

$$BETN = BETN_{ref} \cdot [1 + K_{uowe} \cdot (SCA + WEB \cdot SCB + WEC \cdot SCC)]$$
(3.215)

# 3.7 Asymmetric junctions

From PSP 102.3 onwards, asymmetric junction can be modeled in PSP. This includes asymmetric source-bulk and drain-bulk junctions, GIDL/GISL, overlap gate currents, overlap capacitances and outer fringe capacitances. The asymmetric junction model can be switched on by means of the parameter SWJUNASYM. Note that if SWJUNASYM = 1, the new parameters for the drain side are used all together. Those whose values are not explicitly specified in the model card are set to their default value, *not* to their counterparts for the source side. In other words, it is not possible to activate the parameters for the drain side on a one-by-one basis. The physical scaling and binning rules to calculate the related local parameters for the drain side are given in Section 3.2 and 3.3.

If **SWJUNASYM** = 0, the related parameters for the drain side are ignored. Effectively, the following assignments are applied before evaluation of the calculations described in Section 4.

#### If SWJUNASYM = 0:

TOXOVD = TOXOV	(3.216)
NOVD = NOV	(3.217)
AGIDLD = AGIDL	(3.218)
BGIDLD = BGIDL	(3.219)
$\mathbf{STBGIDLD} = \mathbf{STBGIDL}$	(3.220)
CGIDLD = CGIDL	(3.221)
$\mathbf{IGOVD} = \mathbf{IGOV}$	(3.222)
CGOVD = CGOV	(3.223)
CFRD = CFR	(3.224)

# **Section 4**

# **PSP Model Equations**

# 4.1 Internal Parameters (including Temperature Scaling)

In this section, bias-independent internal parameters will be calculated, including temperature scaling. These parameters are computed from local parameters. Local parameters are (as usual) denoted by capital characters in bold font, whereas the internal parameters are denoted by symbols in bold font.

#### **Transistor temperature**

$$T_{\rm KR} = T_0 + \mathbf{TR} \tag{4.1}$$

$$T_{\rm KD} = T_0 + T_{\rm A} + \mathbf{DTA} \tag{4.2}$$

$$\Delta T = T_{\rm KD} - T_{\rm KR} \tag{4.3}$$

$$\phi_{\mathbf{T}} = \frac{k_{\mathbf{B}} \cdot T_{\mathbf{KD}}}{q} \tag{4.4}$$

## Local process parameters

$$\phi_{\mathbf{T}}^* = \phi_{\mathbf{T}} \cdot \left( 1 + \mathbf{C} \mathbf{T} \cdot \frac{T_{KR}}{T_{KD}} \right) \tag{4.5}$$

$$V_{FB} = VFB + STVFB \cdot \Delta T + DELVTO$$
(4.6)

$$E_{\rm g}/q = 1.179 - 9.025 \cdot 10^{-5} \cdot T_{\rm KD} - 3.05 \cdot 10^{-7} \cdot T_{\rm KD}^{2}$$
 (4.7)

$$r_{\rm T} = (1.045 + 4.5 \cdot 10^{-4} \cdot T_{\rm KD}) \cdot (0.523 + 1.4 \cdot 10^{-3} \cdot T_{\rm KD} - 1.48 \cdot 10^{-6} \cdot T_{\rm KD}^{2})$$
(4.8)

$$n_{\rm i} = 2.5 \cdot 10^{25} \cdot r_{\rm T}^{3/4} \cdot (T_{\rm KD}/300)^{3/2} \cdot \exp\left(-\frac{E_{\rm g}/q}{2 \cdot \phi_{\rm T}}\right)$$
 (4.9)

$$\phi_{\mathrm{B}}^{\mathrm{cl}} = \mathrm{MAX}\left(\mathbf{DPHIB} + 2 \cdot \phi_{\mathbf{T}} \cdot \ln\left[\mathbf{NEFF}/n_{\mathrm{i}}\right], 0.05\right)$$
 (4.10)

$$\epsilon_{\text{ox}} = \mathbf{EPSROX} \cdot \epsilon_0 \tag{4.11}$$

$$C_{\rm ox} = \epsilon_{\rm ox}/{\rm TOX}$$
 (4.12)

$$\epsilon_{\rm Si} = \epsilon_{\rm r,Si} \cdot \epsilon_0 \tag{4.13}$$

$$\gamma_0 = \sqrt{2 \cdot q \cdot \epsilon_{\rm Si} \cdot NEFF} / C_{\rm ox} \tag{4.14}$$

$$G_0^{\rm cl} = \gamma_0 / \sqrt{\phi_{\rm T}} \tag{4.15}$$

## Polysilicon depletion parameter

$$\mathbf{k}_{\mathbf{P}} = \begin{cases} \text{if } \mathbf{NP} = 0 & \begin{cases} \mathbf{k}_{\mathbf{P}} = 0 \\ \\ \text{NP}_{1} = \text{MAX}(\mathbf{NP}, 8 \cdot 10^{7} / \mathbf{TOX}^{2}) \end{cases} \\ \text{NP}_{2} = \text{MAX}(\text{NP}_{1}, 5 \cdot 10^{24}) \\ \mathbf{k}_{\mathbf{P}} = 2 \cdot \phi_{\mathbf{T}} \cdot C_{\text{ox}}^{2} / (q \cdot \epsilon_{\text{Si}} \cdot \text{NP}_{2}) \end{cases}$$

$$(4.16)$$

# Quantum-mechanical correction parameters

$$q_{\lim} = 10 \cdot \phi_{\mathrm{T}} \tag{4.17}$$

$$\boldsymbol{q}_{\mathbf{q}} = \left\{ \begin{array}{l} 0.4 \cdot \mathbf{QMC} \cdot Q\boldsymbol{M}_{\mathrm{N}} \cdot \boldsymbol{C}_{\mathrm{ox}}^{2/3} & \text{ for NMOS} \\ \\ 0.4 \cdot \mathbf{QMC} \cdot Q\boldsymbol{M}_{\mathrm{P}} \cdot \boldsymbol{C}_{\mathrm{ox}}^{2/3} & \text{ for PMOS} \end{array} \right. \tag{4.18}$$

$$q_{\rm b0} = \gamma_0 \cdot \sqrt{\phi_{\rm B}^{\rm cl}} \tag{4.19}$$

$$\phi_{\mathbf{B}} = \phi_{\mathbf{B}}^{\text{cl}} + 0.75 \cdot \mathbf{q}_{\mathbf{a}} \cdot q_{\mathbf{b}0}^{2/3} \tag{4.20}$$

$$G_0 = G_0^{\text{cl}} \cdot \left( 1 + q_q \cdot q_{\text{b0}}^{-1/3} \right) \tag{4.21}$$

## $V_{\rm SB}$ -clipping parameters

$$\phi_{\mathbf{X}} = 0.95 \cdot \phi_{\mathbf{B}} \tag{4.22}$$

$$\boldsymbol{a}_{\phi} = 2.5 \cdot 10^{-3} \cdot \boldsymbol{\phi}_{\mathbf{B}}^2 \tag{4.23}$$

$$\boldsymbol{b_{\phi}} = 2.5 \cdot 10^{-3} \cdot \boldsymbol{\phi_{\mathbf{B}}^2} \tag{4.24}$$

$$\phi_{\mathbf{X}}^{\star} = 0.5 \cdot \sqrt{b_{\phi}} \tag{4.25}$$

$$\boldsymbol{\phi}_{\mathbf{X}}^* = \text{MINA} \left( \boldsymbol{\phi}_{\mathbf{X}} - \boldsymbol{\phi}_{\mathbf{X}}^*, 0, \boldsymbol{a}_{\boldsymbol{\phi}} \right) \tag{4.26}$$

## Local process parameters in gate overlap regions

$$\gamma_{\rm ov} = \sqrt{2 \cdot q \cdot \epsilon_{\rm Si} \cdot {\rm NOV}} \cdot {\rm TOXOV} / \epsilon_{\rm ox}$$
 (4.27)

$$\gamma_{\rm dov} = \sqrt{2 \cdot q \cdot \epsilon_{\rm Si} \cdot \text{NOVD}} \cdot \text{TOXOVD} / \epsilon_{\rm ox}$$
 (4.28)

$$G_{\rm ov} = \gamma_{\rm ov} / \sqrt{\phi_{\rm T}} \tag{4.29}$$

$$G_{
m dov} = \gamma_{
m dov} / \sqrt{\phi_{
m T}}$$
 (4.30)

$$\boldsymbol{\xi}_{\mathbf{ov}} = 1 + \boldsymbol{G}_{\mathbf{ov}} / \sqrt{2} \tag{4.31}$$

$$\boldsymbol{\xi_{\text{dov}}} = 1 + \boldsymbol{G_{\text{dov}}} / \sqrt{2} \tag{4.32}$$

$$x_{\text{mrgov}} = 10^{-5} \cdot \xi_{\text{ov}} \tag{4.33}$$

$$x_{\text{mrgdov}} = 10^{-5} \cdot \xi_{\text{dov}} \tag{4.34}$$

## **Mobility parameters**

$$\beta = \text{FACTUO} \cdot \text{BETN} \cdot C_{\text{ox}} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\text{STBET}}$$
(4.35)

$$\theta_{\mu} = \text{THEMU} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\text{STTHEMU}}$$
 (4.36)

$$\mu_{\rm E} = {\rm MUE} \cdot (T_{\rm KR}/T_{\rm KD})^{\rm STMUE} \tag{4.37}$$

$$X_{cor} = XCOR \cdot (T_{KR}/T_{KD})^{STXCOR}$$
 (4.38)

$$C_{S} = CS \cdot (T_{KR}/T_{KD})^{STCS}$$
(4.39)

$$\boldsymbol{E}_{\text{eff0}} = 10^{-8} \cdot C_{\text{ox}} / \epsilon_{\text{Si}} \tag{4.40}$$

$$\eta_{\mu} = \begin{cases} 1/2 \cdot \mathbf{FETA} & \text{for NMOS} \\ 1/3 \cdot \mathbf{FETA} & \text{for PMOS} \end{cases}$$
(4.41)

# Series resistance parameter

$$R_{\rm s} = \mathbf{RS} \cdot (T_{\rm KR}/T_{\rm KD})^{\mathbf{STRS}} \tag{4.42}$$

$$\theta_{\mathbf{R}} = 2 \cdot \beta \cdot R_{\mathbf{s}} \tag{4.43}$$

# Velocity saturation parameter

$$\theta_{\text{sat}} = \text{THESAT} \cdot (T_{\text{KR}}/T_{\text{KD}})^{\text{STTHESAT}}$$
 (4.44)

# Impact-ionization parameter

$$a_2 = \mathbf{A2} \cdot (T_{KD}/T_{KR})^{\mathbf{STA2}} \tag{4.45}$$

## **Gate current parameters**

$$I_{\text{GINV}} = \text{IGINV} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\text{STIG}}$$
 (4.46)

$$I_{\text{GOV}} = \text{IGOV} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\text{STIG}}$$
 (4.47)

$$I_{\text{GOVD}} = I\text{GOVD} \cdot (T_{\text{KD}}/T_{\text{KR}})^{\text{STIG}}$$
 (4.48)

$$\boldsymbol{B} = \frac{4}{3} \cdot \frac{\mathbf{TOX}}{\hbar} \cdot \sqrt{2 \cdot q \cdot m_0 \cdot \mathbf{CHIB}} = 6.830909 \cdot 10^9 \cdot \mathbf{TOX} \cdot \sqrt{\mathbf{CHIB}}$$
(4.49)

$$B_{ov} = B \cdot TOXOV/TOX \tag{4.50}$$

$$B_{\text{ovd}} = B \cdot \text{TOXOVD/TOX} \tag{4.51}$$

$$GC_{\mathbf{Q}} = \begin{cases} -0.99 \cdot \frac{\mathbf{GC2}}{2 \cdot \mathbf{GC3}} & \text{for } \mathbf{GC3} < 0 \\ 0 & \text{for } \mathbf{GC3} \ge 0 \end{cases}$$

$$(4.52)$$

$$\alpha_{\mathbf{b}} = \frac{E_{\mathbf{g}}/q + \phi_{\mathbf{B}}}{2} \tag{4.53}$$

$$D_{\rm ch} = {\rm GCO} \cdot \phi_{\rm T}^* \tag{4.54}$$

$$D_{ov} = GCO \cdot \phi_{T} \tag{4.55}$$

## Gate-induced drain leakage parameters

$$A_{GIDL} = AGIDL \cdot \left(\frac{2 \cdot 10^{-9}}{TOXOV}\right)^2$$
 (4.56)

$$A_{GIDLD} = AGIDLD \cdot \left(\frac{2 \cdot 10^{-9}}{TOXOVD}\right)^{2}$$
(4.57)

$$\boldsymbol{B_{\text{GIDL}}} = \mathbf{BGIDL} \cdot \text{MAX} \left( \left[ 1 + \mathbf{STBGIDL} \cdot \Delta T \right], 0 \right) \cdot \left( \frac{\mathbf{TOXOV}}{2 \cdot 10^{-9}} \right)$$
(4.58)

$$\boldsymbol{B_{\text{GIDLD}}} = \mathbf{BGIDLD} \cdot \text{MAX} \left( \left[ 1 + \mathbf{STBGIDLD} \cdot \Delta T \right], 0 \right) \cdot \left( \frac{\mathbf{TOXOVD}}{2 \cdot 10^{-9}} \right)$$
(4.59)

# Noise parameter

$$N_{\rm T} = FNT \cdot 4 \cdot k_{\rm B} \cdot T_{\rm KD} \tag{4.60}$$

## Additional internal parameters

$$x_1 = 1.25 (4.61)$$

$$x_{g1} = x_1 + G_{ov} \cdot \sqrt{\exp(-x_1) + x_1 - 1}$$
 (4.62)

$$x_{\text{dg1}} = x_1 + G_{\text{dov}} \cdot \sqrt{\exp(-x_1) + x_1 - 1}$$
 (4.63)

# **4.2** Model Equations

In this section, the model equations of the PSP-model are given. Use is made of the applied terminal bias values  $V_{\rm GS}$ ,  $V_{\rm DS}$  and  $V_{\rm SB}$ , the local parameters listed in Section 2.5.7 and the internal parameters introduced in Section 4.1. Local parameters are denoted by capital characters in bold font, whereas internal (bias-independent) parameters are denoted by symbols in bold font.

The definitions of the auxiliary functions MINA(.), MAXA(.),  $\chi$ (.) and  $\sigma_{1,2}$ (.) can be found in Appendix A.

# 4.2.1 Conditioning of Terminal Voltages

$$\phi_{V} = MINA (V_{SB}, V_{SB} + V_{DS}, \boldsymbol{b}_{\phi}) + \boldsymbol{\phi}_{X}$$

$$(4.64)$$

$$V_{\mathrm{SB}}^* = V_{\mathrm{SB}} - \mathrm{MINA}\left(\phi_{\mathrm{V}}, 0, \boldsymbol{a}_{\boldsymbol{\phi}}\right) + \boldsymbol{\phi}_{\mathbf{X}}^* \tag{4.65}$$

$$V_{\rm DB}^* = V_{\rm DS} + V_{\rm SB}^* \tag{4.66}$$

$$V_{\rm dsx} = \sqrt{V_{\rm DS}^2 + 0.01} - 0.1 \tag{4.67}$$

$$V_{\rm sbx} = V_{\rm SB}^* + \frac{V_{\rm DS} - V_{\rm dsx}}{2} \tag{4.68}$$

Drain-induced barrier lowering:

$$\Delta V_{\rm G} = \mathbf{CF} \cdot V_{\rm dsx} \cdot (1 + \mathbf{CFB} \cdot V_{\rm sbx}) \tag{4.69}$$

$$V_{\rm GB}^* = V_{\rm GS} + V_{\rm SB}^* + \Delta V_{\rm G} - V_{\rm FB}$$
(4.70)

$$x_{\mathbf{g}} = V_{\mathbf{GB}}^* / \phi_{\mathbf{T}}^* \tag{4.71}$$

# 4.2.2 Bias-Dependent Body Factor

$$D_{\text{nsub}} = \mathbf{DNSUB} \cdot \text{MAXA}(0, V_{\text{GS}} + V_{\text{SB}} - \mathbf{VNSUB}, \mathbf{NSLP})$$
(4.72)

$$G = G_0 \cdot \sqrt{1 + D_{\text{nsub}}} \tag{4.73}$$

## 4.2.3 Surface Potential at Source Side and Related Variables

$$\xi = 1 + G/\sqrt{2} \tag{4.74}$$

$$x_{\rm ns} = \frac{\phi_{\rm B} + V_{\rm SB}^*}{\phi_{\rm T}^*} \tag{4.75}$$

$$\Delta_{\rm ns} = \exp\left(-x_{\rm ns}\right) \tag{4.76}$$

$$x_{\rm mrg} = 10^{-5} \cdot \xi \tag{4.77}$$

$$\begin{aligned} & y_{\rm K} = -x_{\rm K} \\ & z = 1.25 \cdot y_z/\xi \\ & \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64}\right]/2 \\ & a = (y_{\rm S} - \eta)^2 + G^2 \cdot (\eta + 1) \\ & c = 2 \cdot (y_{\rm S} - \eta) - G^2 \end{aligned}$$
 
$$(4.78)$$
 
$$(4.78)$$
 
$$y_0 = \sigma_1(a, c, \tau, \eta)$$
 
$$\Delta_0 = \exp\left(y_0\right)$$
 
$$p = 2 \cdot (y_{\rm K} - y_0) + G^2 \cdot \left[\Delta_0 - 1 + \Delta_{\rm ns} \cdot (1 - \chi'(y_0) - 1/\Delta_0)\right]$$
 
$$q = (y_x - y_0)^2 + G^2 \cdot \left[y_0 - \Delta_0 + 1 + \Delta_{\rm ns} \cdot (1 + \chi(y_0) - 1/\Delta_0 - 2 \cdot y_0)\right]$$
 
$$x_{\rm S} = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - G^2 \cdot [\Delta_0 + \Delta_{\rm ns} \cdot (1/\Delta_0 - \chi''(y_0)))]}$$
 
$$if |x_{\rm g}| \le x_{\rm marg} \left\{ x_{\rm s} = \frac{x_{\rm g}}{\xi} \cdot \left[1 + G \cdot x_{\rm g} \cdot \frac{1 - \Delta_{\rm ns}}{\epsilon^2 \cdot 6 \cdot \sqrt{2}}\right] \right.$$
 
$$\left\{ x_{\rm f} = x_1 + G \cdot \sqrt{\exp(-x_1) + x_1 - 1} \right.$$
 
$$\frac{x_{\rm g}}{\xi} \cdot \left[1 + x_{\rm g} \cdot (\xi \cdot x_1 - \hat{x}_{\rm g})/\hat{x}_{\rm g1}^2\right]$$
 
$$x_0 = x_{\rm g} + G^2/2 - G \cdot \sqrt{x_{\rm g} + G^2/4 - 1 + \exp(-x)} \right.$$
 
$$b_{\rm h} = x_{\rm ns} + 3$$
 
$$\eta = \text{MINA}(x_0, b_{\rm h}, 5) - \left(b_{\rm h} - \sqrt{b_{\rm g}^2 + 5}\right)/2$$
 
$$a = (x_{\rm g} - \eta)^2 - G^2 \cdot \left[\exp(-\eta) + \eta - 1 - \Delta_{\rm ns} \cdot (\eta + 1 + \chi(\eta))\right]$$
 
$$b = 1 - G^2/2 \cdot \left[\exp(-\eta) - \Delta_{\rm ns} \cdot \chi''(\eta)\right]$$
 
$$c = 2 \cdot (x_{\rm g} - \eta) + \operatorname{Im}\left(a/G^2\right)$$
 
$$y_0 = \sigma_2(a, b, c, \tau, \eta)$$
 
$$\Delta_0 = \exp(y_0)$$
 
$$p = 2 \cdot (x_{\rm g} - \eta_0) + G^2 \cdot \left[1 - 1/\Delta_0 + \Delta_{\rm ns} \cdot (\Delta_0 - 1 - \chi'(y_0))\right]$$
 
$$q = (x_{\rm g} - y_0)^2 - G^2 \cdot \left[y_0 + 1/\Delta_0 - 1 + \Delta_{\rm ns} \cdot (\Delta_0 - y_0 - 1 - \chi(y_0))\right]$$
 
$$x_{\rm g} = y_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot (2 - G^2 \cdot [1/\Delta_0 + \Delta_{\rm ns} \cdot (\Delta_0 - \chi''(y_0))]}$$
 
$$E_{\rm g}. (4.81) \cdot (4.83) \text{ are only calculated for } x_{\rm g} > 0.$$

Eqs. (4.81)-(4.83) are only calculated for  $x_g > 0$ 

$$E_{\rm s} = \exp\left(-x_{\rm s}\right) \tag{4.81}$$

$$D_{\rm s} = [1/E_{\rm s} - x_{\rm s} - 1 - \chi(x_{\rm s})] \cdot \Delta_{\rm ns}$$
(4.82)

$$P_{\rm s} = x_{\rm s} - 1 + E_{\rm s} \tag{4.83}$$

$$x_{\rm gs} = \begin{cases} x_{\rm g} - x_{\rm s} & \text{for } x_{\rm g} \le 0\\ G \cdot \sqrt{D_{\rm s} + P_{\rm s}} & \text{for } x_{\rm g} > 0 \end{cases}$$

$$(4.84)$$

$$\psi_{\rm ss} = \phi_{\rm T}^* \cdot x_{\rm s} \tag{4.85}$$

# 4.2.4 Drain Saturation Voltage

Eqs. (4.86)-(4.106) are only calculated for  $x_{\rm g}>0$ .

$$q_{\rm is} = \frac{G^2 \cdot \phi_{\rm T}^* \cdot D_{\rm s}}{x_{\rm gs} + G \cdot \sqrt{P_{\rm s}}} \tag{4.86}$$

$$\alpha_{\rm s} = 1 + \frac{G \cdot (1 - E_{\rm s})}{2 \cdot \sqrt{P_{\rm s}}} \tag{4.87}$$

$$q_{\rm bs} = \phi_{\rm T}^* \cdot G \cdot \sqrt{P_{\rm s}} \tag{4.88}$$

$$\rho_{b} = \begin{cases} 1 + \mathbf{RSB} \cdot V_{\text{sbx}} & \text{for } \mathbf{RSB} \ge 0\\ \frac{1}{1 - \mathbf{RSB} \cdot V_{\text{sbx}}} & \text{for } \mathbf{RSB} < 0 \end{cases}$$

$$(4.89)$$

$$\rho_{\rm g,s} = \begin{cases} \frac{1}{1 + \mathbf{RSG} \cdot q_{\rm is}} & \text{for } \mathbf{RSG} \ge 0\\ 1 - \mathbf{RSG} \cdot q_{\rm is} & \text{for } \mathbf{RSG} < 0 \end{cases}$$

$$(4.90)$$

$$\rho_{\rm s} = \boldsymbol{\theta}_{\mathbf{R}} \cdot \rho_{\rm b} \cdot \rho_{\rm g,s} \cdot q_{\rm is} \tag{4.91}$$

$$\mu_{\mathbf{x}} = \frac{1 + \boldsymbol{X}_{\mathbf{cor}} \cdot V_{\mathbf{sbx}}}{1 + 0.2 \cdot \boldsymbol{X}_{\mathbf{cor}} \cdot V_{\mathbf{sbx}}}$$
(4.92)

$$E_{\text{eff,s}} = E_{\text{eff0}} \cdot \left( q_{\text{bs}} + \eta_{\mu} \cdot q_{\text{is}} \right) \tag{4.93}$$

$$G_{\text{mob,s}} = \frac{1 + (\boldsymbol{\mu}_{\mathbf{E}} \cdot E_{\text{eff,s}})^{\boldsymbol{\theta}_{\boldsymbol{\mu}}} + \boldsymbol{C}_{\mathbf{S}} \cdot \left(\frac{q_{\text{bs}}}{q_{\text{is}} + q_{\text{bs}}}\right)^{2} + \rho_{\text{s}}}{\mu_{\text{x}}}$$
(4.94)

$$\xi_{\rm tb} = \begin{cases} 1 + \text{THESATB} \cdot V_{\rm sbx} & \text{for THESATB} \ge 0 \\ \\ \frac{1}{1 - \text{THESATB} \cdot V_{\rm sbx}} & \text{for THESATB} < 0 \end{cases}$$

$$(4.95)$$

$$w_{\text{sat,s}} = \frac{100 \cdot q_{\text{is}} \cdot \xi_{\text{tb}}}{100 + q_{\text{is}} \cdot \xi_{\text{tb}}}$$
(4.96)

$$\theta_{\text{sat,s}}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob,s}}} \cdot (1 + \text{THESATG} \cdot w_{\text{sat,s}}) & \text{for THESATG} \ge 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob,s}}} \cdot \frac{1}{1 - \text{THESATG} \cdot w_{\text{sat,s}}} & \text{for THESATG} < 0 \end{cases}$$

$$(4.97)$$

$$\phi_{\infty} = q_{\rm is}/\alpha_{\rm s} + \phi_{\rm T}^* \tag{4.98}$$

$$y_{\text{sat}} = \begin{cases} \theta_{\text{sat,s}}^* \cdot \phi_{\infty} / \sqrt{2} & \text{for NMOS} \\ \frac{\theta_{\text{sat,s}}^* \cdot \phi_{\infty} / \sqrt{2}}{\sqrt{1 + \theta_{\text{sat,s}}^* \cdot \phi_{\infty} / \sqrt{2}}} & \text{for PMOS} \end{cases}$$

$$(4.99)$$

$$z_{\rm a} = \frac{2}{1 + \sqrt{1 + 4 \cdot y_{\rm sat}}} \tag{4.100}$$

$$\phi_0 = \phi_{\infty} \cdot z_{\rm a} \cdot \left[ 1 + 0.86 \cdot z_{\rm a} \cdot y_{\rm sat} \cdot \frac{1 - z_{\rm a}^2 \cdot y_{\rm sat}}{1 + 4 \cdot z_{\rm a}^3 \cdot y_{\rm sat}^2} \right]$$
(4.101)

$$a_{\rm sat} = x_{\rm gs} + G^2/2 \tag{4.102}$$

$$\phi_2 = \frac{\phi_{\mathbf{T}}^* \cdot 0.98 \cdot G^2 \cdot D_{\mathbf{s}}}{a_{\mathbf{sat}} + \sqrt{a_{\mathbf{sat}}^2 - 0.98 \cdot G^2 \cdot D_{\mathbf{s}}}}$$
(4.103)

$$\phi_{\text{sat}} = \frac{2 \cdot \phi_0 \cdot \phi_2}{\phi_0 + \phi_2 + \sqrt{(\phi_0 + \phi_2)^2 - 3.96 \cdot \phi_0 \cdot \phi_2}}$$
(4.104)

$$V_{\text{dsat}} = \phi_{\text{sat}} - \phi_{\mathbf{T}}^* \cdot \ln \left[ 1 + \frac{\phi_{\text{sat}} \cdot \left( \phi_{\text{sat}} - 2 \cdot a_{\text{sat}} \cdot \phi_{\mathbf{T}}^* \right)}{G^2 \cdot D_{\text{s}} \cdot {\phi_{\mathbf{T}}^*}^2} \right]$$
(4.105)

$$V_{\rm dse} = \frac{V_{\rm DS}}{\left[1 + (V_{\rm DS}/V_{\rm dsat})^{\mathbf{AX}}\right]^{1/\mathbf{AX}}} \tag{4.106}$$

#### 4.2.5 Surface Potential at Drain Side and Related Variables

Eqs. (4.107)-(4.116) are only calculated for  $x_{\rm g}>0$ .

$$x_{\rm nd} = \frac{\phi_{\rm B} + V_{\rm SB}^* + V_{\rm dse}}{\phi_{\rm T}^*}$$
 (4.107)

$$k_{\rm ds} = \exp\left(-V_{\rm dse}/\phi_{\rm T}^*\right) \tag{4.108}$$

$$\Delta_{\rm nd} = \Delta_{\rm ns} \cdot k_{\rm ds} \tag{4.109}$$

if 
$$x_{\rm g} \le x_{\rm mrg} \left\{ x_{\rm d} = \frac{x_{\rm g}}{\xi} \cdot \left[ 1 + G \cdot x_{\rm g} \cdot \frac{1 - \Delta_{\rm nd}}{\xi^2 \cdot 6 \cdot \sqrt{2}} \right] \right\}$$
 (4.110)

$$\begin{cases} b_{x} = x_{\text{nd}} + 3.0 \\ \eta = \text{MINA}(x_{0}, b_{x}, 5) - \left(b_{x} - \sqrt{b_{x}^{2} + 5}\right) / 2 \\ a = (x_{g} - \eta)^{2} - G^{2} \cdot \left[\exp(-\eta) + \eta - 1 - \Delta_{\text{nd}} \cdot (\eta + 1 + \chi(\eta))\right] \\ b = 1 - G^{2} / 2 \cdot \left[\exp(-\eta) - \Delta_{\text{nd}} \cdot \chi''(\eta)\right] \\ c = 2 \cdot (x_{g} - \eta) + G^{2} \cdot \left[1 - \exp(-\eta) - \Delta_{\text{nd}} \cdot (1 + \chi'(\eta))\right] \\ \tau = x_{\text{nd}} - \eta + \ln\left(a/G^{2}\right) \\ y_{0} = \sigma_{2}(a, b, c, \tau, \eta) \\ \Delta_{0} = \exp\left(y_{0}\right) \\ p = 2 \cdot (x_{g} - y_{0}) + G^{2} \cdot \left[1 - 1/\Delta_{0} + \Delta_{\text{nd}} \cdot (\Delta_{0} - 1 - \chi'(y_{0}))\right] \\ q = (x_{g} - y_{0})^{2} - G^{2} \cdot \left[y_{0} + 1/\Delta_{0} - 1 + \Delta_{\text{nd}} \cdot (\Delta_{0} - y_{0} - 1 - \chi(y_{0}))\right] \\ x_{\text{d}} = y_{0} + \frac{2 \cdot q}{p + \sqrt{p^{2} - 2 \cdot q \cdot \left\{2 - G^{2} \cdot \left[1/\Delta_{0} + \Delta_{\text{nd}} \cdot (\Delta_{0} - \chi''(y_{0}))\right]\right\}} \end{cases}$$

$$(4.112)$$

$$x_{\rm ds} = x_{\rm d} - x_{\rm s}$$

$$\begin{cases} p = 2 \cdot x_{\rm gs} + G^2 \cdot [1 - E_{\rm s} + \Delta_{\rm nd} \cdot (1/E_{\rm s} - 1 - \chi'(x_{\rm s}))] \\ q = G^2 \cdot (1 - k_{\rm ds}) \cdot D_{\rm s} \\ \xi = 1 - G^2/2 \cdot [E_{\rm s} + \Delta_{\rm nd} (1/E_{\rm s} - \chi''(x_{\rm s}))] \\ x_{\rm ds} = \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot \xi \cdot q}} \\ x_{\rm d} = x_{\rm s} + x_{\rm ds} \end{cases}$$

$$(4.114)$$

$$E_d = \exp\left(-x_d\right) \tag{4.114}$$

$$D_{\rm d} = (1/E_{\rm d} - x_{\rm d} - 1 - \chi(x_{\rm d})) \cdot \Delta_{\rm nd} \tag{4.115}$$

$$E_{d} = \exp(-x_{d})$$

$$D_{d} = (1/E_{d} - x_{d} - 1 - \chi(x_{d})) \cdot \Delta_{nd}$$

$$\Delta \psi = \phi_{\mathbf{T}}^{*} \cdot x_{ds}$$

$$\psi_{sd} = \phi_{\mathbf{T}}^{*} \cdot x_{d}$$
(4.115)
$$(4.116)$$

$$\psi_{\rm sd} = \phi_{\rm T}^* \cdot x_{\rm d} \tag{4.117}$$

# 4.2.6 Mid-Point Surface Potential and Related Variables

if 
$$x_{\rm g} > 0$$

$$\begin{cases}
x_{\rm m} = (x_{\rm s} + x_{\rm d})/2 \\
E_{\rm m} = \sqrt{E_{\rm s} \cdot E_{\rm d}} \\
\bar{D} = (D_{\rm s} + D_{\rm d})/2 \\
D_{\rm m} = \bar{D} + x_{\rm ds}^2/8 \cdot (E_{\rm m} - 2/G^2) \\
P_{\rm m} = x_{\rm m} - 1 + E_{\rm m} \\
x_{\rm gm} = G \cdot \sqrt{D_{\rm m} + P_{\rm m}}
\end{cases}$$
(4.118)

if 
$$x_{\rm g} \le 0$$

$$\begin{cases} x_{\rm m} = x_{\rm s} \\ x_{\rm gm} = x_{\rm g} - x_{\rm s} \end{cases}$$
(4.119)

# 4.2.7 Polysilicon Depletion

Eqs. (4.120)-(4.134) are only calculated for  $k_{
m P}>0$  and  $x_{
m g}>0$  (otherwise  $\eta_{
m p}=1$ ):

$$x_{\rm m}^{(0)} = x_{\rm m}, x_{\rm ds}^{(0)} = x_{\rm ds}, D_{\rm m}^{(0)} = D_{\rm m}, E_{\rm m}^{(0)} = E_{\rm m}, (4.120)$$

$$d_0 = 1 - E_{\rm m}^{(0)} + 2 \cdot x_{\rm gm}/G^2 \tag{4.121}$$

$$\eta_{\rm p} = 1/\sqrt{1 + \mathbf{k_P} \cdot x_{\rm gm}} \tag{4.122}$$

$$x_{\rm pm} = k_{\rm P} \cdot \left[ \frac{\eta_{\rm p} \cdot x_{\rm gm}}{1 + \eta_{\rm p}} \right]^2 \cdot \frac{D_{\rm m}^{(0)}}{D_{\rm m}^{(0)} + P_{\rm m}}$$
(4.123)

$$p = 2 \cdot (x_{\rm gm} - x_{\rm pm}) + G^2 \cdot \left(1 - E_{\rm m}^{(0)} + D_{\rm m}^{(0)}\right)$$
(4.124)

$$q = x_{\text{pm}} \cdot (x_{\text{pm}} - 2 \cdot x_{\text{gm}}) \tag{4.125}$$

$$\xi_{\rm p} = 1 - G^2/2 \cdot \left(E_{\rm m}^{(0)} + D_{\rm m}^{(0)}\right)$$
 (4.126)

$$u_{\mathbf{p}} = \frac{p \cdot q}{p^2 - \xi_{\mathbf{p}} \cdot q} \tag{4.127}$$

$$x_{\rm m} = x_{\rm m}^{(0)} + u_{\rm p}$$
 (4.128)

$$E_{\rm m} = E_{\rm m}^{(0)} \cdot \exp\left(-u_{\rm p}\right)$$
 (4.129)

$$D_{\rm m} = D_{\rm m}^{(0)} \cdot \exp\left(u_{\rm p}\right)$$
 (4.130)

$$P_{\rm m} = x_{\rm m} - 1 + E_{\rm m} \tag{4.131}$$

$$x_{\rm gm} = G \cdot \sqrt{D_{\rm m} + P_{\rm m}} \tag{4.132}$$

$$x_{\rm ds} = x_{\rm ds}^{(0)} \cdot \frac{\exp(u_{\rm p}) \cdot \left[\bar{D} + d_{0}\right]}{1 - E_{\rm m} + 2 \cdot x_{\rm gm} \cdot \eta_{\rm p} / G^{2} + \exp(u_{\rm p}) \cdot \bar{D}}$$
(4.133)

$$\Delta \psi = \phi_{\mathbf{T}}^* \cdot x_{\mathrm{ds}} \tag{4.134}$$

# 4.2.8 Potential Mid-Point Inversion Charge and Related Variables

Eqs. (4.135)-(4.142) are only calculated for  $x_{\rm g}>0$ .

$$q_{\rm im} = \frac{G^2 \cdot \phi_{\rm T}^* \cdot D_{\rm m}}{x_{\rm gm} + G \cdot \sqrt{P_{\rm m}}} \tag{4.135}$$

$$\alpha_{\rm m} = \eta_{\rm p} + \frac{G \cdot (1 - E_{\rm m})}{2 \cdot \sqrt{P_{\rm m}}} \tag{4.136}$$

$$q_{\rm im}^* = q_{\rm im} + \phi_{\rm T}^* \cdot \alpha_{\rm m} \tag{4.137}$$

$$q_{\rm bm} = \phi_{\rm T}^* \cdot G \cdot \sqrt{P_{\rm m}} \tag{4.138}$$

Series resistance:

$$\rho_{\rm g} = \begin{cases}
\frac{1}{1 + \mathbf{RSG} \cdot q_{\rm im}} & \text{for } \mathbf{RSG} \ge 0 \\
1 - \mathbf{RSG} \cdot q_{\rm im} & \text{for } \mathbf{RSG} < 0
\end{cases}$$
(4.139)

$$\rho_{\rm s} = \boldsymbol{\theta}_{\mathbf{R}} \cdot \rho_{\rm b} \cdot \rho_{\rm g} \cdot q_{\rm im} \tag{4.140}$$

Mobility reduction:

$$E_{\text{eff}} = E_{\text{eff0}} \cdot (q_{\text{bm}} + \eta_{\mu} \cdot q_{\text{im}}) \tag{4.141}$$

$$G_{\text{mob}} = \frac{1 + (\boldsymbol{\mu}_{\mathbf{E}} \cdot E_{\text{eff}})^{\boldsymbol{\theta}_{\boldsymbol{\mu}}} + C_{\mathbf{S}} \cdot \left(\frac{q_{\text{bm}}}{q_{\text{im}} + q_{\text{bm}}}\right)^{2} + \rho}{\mu_{x}}$$
(4.142)

# 4.2.9 Drain-Source Channel Current

Eqs. (4.143)-(4.154) are only calculated for  $x_{\rm g}>0$ :

Channel length modulation:

$$R_1 = q_{\rm im}/q_{\rm im}^* \tag{4.143}$$

$$R_2 = \phi_{\mathbf{T}}^* \cdot \alpha_{\mathbf{m}} / q_{\mathbf{im}}^* \tag{4.144}$$

$$T_{1} = \ln \left( \frac{1 + \frac{V_{DS} - \Delta \psi}{\mathbf{VP}}}{1 + \frac{V_{dse} - \Delta \psi}{\mathbf{VP}}} \right)$$
(4.145)

$$T_2 = \ln\left(1 + \frac{V_{\rm dsx}}{\mathbf{VP}}\right) \tag{4.146}$$

$$\Delta L/L = \mathbf{ALP} \cdot T_1 \tag{4.147}$$

$$G_{\Delta L} = \frac{1}{1 + \Delta L/L + (\Delta L/L)^2}$$
 (4.148)

$$\Delta L_1/L = \left[ \mathbf{ALP} + \frac{\mathbf{ALP1}}{q_{\text{im}}^*} \cdot R_1 \right] \cdot T_1 + \mathbf{ALP2} \cdot q_{\text{bm}} \cdot R_2^2 \cdot T_2$$
(4.149)

$$F_{\Delta L} = \left[1 + \Delta L_1 / L + (\Delta L_1 / L)^2\right] \cdot G_{\Delta L} \tag{4.150}$$

Velocity saturation:

$$w_{\text{sat}} = \frac{100 \cdot q_{\text{im}} \cdot \xi_{\text{tb}}}{100 + q_{\text{im}} \cdot \xi_{\text{tb}}} \tag{4.151}$$

$$\theta_{\text{sat}}^* = \begin{cases} \frac{\theta_{\text{sat}}}{G_{\text{mob,s}} \cdot G_{\Delta L}} \cdot (1 + \text{THESATG} \cdot w_{\text{sat}}) & \text{for THESATG} \ge 0 \\ \frac{\theta_{\text{sat}}}{G_{\text{mob,s}} \cdot G_{\Delta L}} \cdot \frac{1}{1 - \text{THESATG} \cdot w_{\text{sat}}} & \text{for THESATG} < 0 \end{cases}$$

$$(4.152)$$

$$z_{\text{sat}} = \begin{cases} (\theta_{\text{sat}}^* \cdot \Delta \psi)^2 & \text{for NMOS} \\ \frac{(\theta_{\text{sat}}^* \cdot \Delta \psi)^2}{1 + \theta_{\text{sat}}^* \cdot \Delta \psi} & \text{for PMOS} \end{cases}$$

$$(4.153)$$

$$G_{\text{vsat}} = \frac{G_{\text{mob}} \cdot G_{\Delta L}}{2} \cdot \left(1 + \sqrt{1 + 2 \cdot z_{\text{sat}}}\right) \tag{4.154}$$

Drain-Source channel current:

$$I_{\rm DS} = \begin{cases} 0 & \text{for } x_{\rm g} \le 0 \\ \beta \cdot F_{\Delta L} \cdot \frac{q_{\rm im}^*}{G_{\rm test}} \cdot \Delta \psi & \text{for } x_{\rm g} > 0 \end{cases}$$

$$(4.155)$$

# 4.2.10 Auxiliary Variables for Calculation of Intrinsic Charges and Gate Current

Eqs. (4.156)-(4.158) are only calculated for  $x_{\rm g}>0$ .

$$V_{\text{oxm}} = \phi_{\mathbf{T}}^* \cdot x_{\text{gm}} \tag{4.156}$$

$$\alpha'_{\rm m} = \alpha_{\rm m} \cdot \left[ 1 + \frac{z_{\rm sat}}{2} \cdot \left( \frac{G_{\rm mob} \cdot G_{\Delta L}}{G_{\rm vsat}} \right)^2 \right]$$
 (4.157)

$$H = \frac{G_{\text{mob}} \cdot G_{\Delta L}}{G_{\text{vsat}}} \cdot \frac{q_{\text{im}}^*}{\alpha_{\text{m}}'}$$
(4.158)

# **4.2.11** Impact Ionization or Weak-Avalanche

The equations in this Section are only calculated when SWIMPACT = 1 and  $x_g > 0$ .

$$a_2^* = \mathbf{a_2} \cdot \left[ 1 + \mathbf{A4} \cdot \left( \sqrt{V_{\text{SB}}^* + \phi_{\mathbf{B}}} - \sqrt{\phi_{\mathbf{B}}} \right) \right]$$
(4.159)

$$\Delta V_{\rm sat} = V_{\rm DS} - \mathbf{A3} \cdot \Delta \psi \tag{4.160}$$

$$M_{\rm avl} = \begin{cases} 0 & \text{for } \Delta V_{\rm sat} \le 0 \\ \mathbf{A1} \cdot \Delta V_{\rm sat} \cdot \exp\left(-\frac{a_2^*}{\Delta V_{\rm sat}}\right) & \text{for } \Delta V_{\rm sat} > 0 \end{cases}$$

$$(4.161)$$

$$I_{\text{avl}} = M_{\text{avl}} \cdot I_{\text{DS}} \tag{4.162}$$

#### 4.2.12 **Surface Potential in Gate Overlap Regions**

$$\begin{cases} y_{\rm g} = -x_{\rm g} \\ z = x_1 \cdot y_{\rm g}/\xi_{\rm ov} \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64}\right]/2 \\ a = (y_{\rm g} - \eta)^2 + G_{\rm ov}^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_{\rm g} - \eta) - G_{\rm ov}^2 \\ \tau = -\eta + \ln\left(a/G_{\rm ov}^2\right) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp\left(y_0\right) \\ p = 2 \cdot (y_{\rm g} - y_0) + G_{\rm ov}^2 \cdot (\Delta_0 - 1) \\ q = (y_{\rm g} - y_0)^2 + G_{\rm ov}^2 \cdot (y_0 - \Delta_0 + 1) \\ x_{\rm sov} = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot \left(2 - G_{\rm ov}^2 \cdot \Delta_0\right)}} \end{cases}$$
 (4.163) 
$$\text{if } |x_{\rm g}| < x_{\rm mrgov} \left\{ x_{\rm sov} = x_{\rm g}/\xi_{\rm ov} \right. \\ \left[ \begin{array}{c} \bar{x} = x_{\rm g}/\xi_{\rm ov} \cdot \left[1 + x_{\rm g} \cdot (\xi_{\rm ov} \cdot x_1 - x_{\rm g1})/x_{\rm g1}^2\right] \\ \omega = 1 - \exp\left(-\bar{x}\right) \\ x_0 = x_{\rm g} + G_{\rm ov}^2/2 - G_{\rm ov} \cdot \sqrt{x_{\rm g} + G_{\rm ov}^2/4 - \omega} \\ \Delta_0 = \exp\left(-x_0\right) \\ p = 2 \cdot (x_{\rm g} - x_0) + G_{\rm ov}^2 \cdot (1 - \Delta_0) \\ q = (x_{\rm g} - x_0)^2 - G_{\rm ov}^2 \cdot (x_0 + \Delta_0 - 1) \\ x_{\rm sov} = x_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 2 \cdot q \cdot \left(2 - G_{\rm ov}^2 \cdot \Delta_0\right)}} \end{cases}$$

$$\psi_{\text{sov}} = -\phi_{\mathbf{T}} \cdot x_{\text{sov}} \left( -\frac{V_{\text{GS}}}{\phi_{\mathbf{T}}} \right) \tag{4.165}$$

$$\psi_{\text{dov}} = -\phi_{\mathbf{T}} \cdot x_{\text{dov}} \left( -\frac{V_{\text{GS}} - V_{\text{DS}}}{\phi_{\mathbf{T}}} \right) \tag{4.166}$$

$$V_{\text{ov}_0} = V_{\text{GS}} - \psi_{\text{sov}} \tag{4.167}$$

$$V_{\text{OVL}} = V_{\text{GS}} - V_{\text{DS}} - \psi_{\text{dov}} \tag{4.168}$$

#### 4.2.13 Gate Current

The equations in this Section are only calculated when SWIGATE = 1.

Source/Drain gate overlap current:

Source/Drain gate overlap current: 
$$\begin{cases} V_{\rm ov}^* = \sqrt{V_{\rm ov}^2 + 10^{-6}} \\ \psi_{\rm tov} = {\rm MINA}\left(0, V_{\rm ov} + \boldsymbol{D_{\rm ov}}, 0.01\right) \\ z_{\rm g} = \begin{cases} {\rm MINA}\left(\frac{V_{\rm ov}^*}{{\rm CHIB}}, \boldsymbol{GC_{\rm Q}}, 10^{-6}\right) & {\rm for} \; {\rm GC3} < 0 \\ \frac{V_{\rm ov}^*}{{\rm CHIB}} & {\rm for} \; {\rm GC3} \ge 0 \end{cases} \\ A_{\rm Siov} = \exp\left(\frac{3.0 \cdot \phi_{\rm T} + \psi_{\rm ov} + \psi_{\rm tov}}{\phi_{\rm T}}\right) \\ E_{\rm Sov} = \ln\left[\frac{1 + \Delta_{\rm Siov}}{1 + \Delta_{\rm Siov} \cdot \exp\left(-V_{\rm GX}/\phi_{\rm T}\right)}\right] \\ I_{\rm Gov} = I_{\rm Gov} \cdot F_{\rm Sov} \cdot \\ \exp\left(\boldsymbol{B_{\rm ov}} \cdot \left[-\frac{3}{2} + z_{\rm g} \cdot ({\rm GC2} + {\rm GC3} \cdot z_{\rm g})\right]\right) \end{cases} \\ \begin{cases} V_{\rm ov}^* = \sqrt{V_{\rm ov}^2 + 10^{-6}} \\ \psi_{\rm tov} = {\rm MINA}\left(0, V_{\rm ov} + \boldsymbol{D_{\rm ov}}, 0.01\right) \\ z_{\rm g} = \begin{cases} {\rm MINA}\left(\frac{V_{\rm ov}^*}{{\rm CHIB}}, \boldsymbol{GC_{\rm Q}}, 10^{-6}\right) & {\rm for} \; {\rm GC3} < 0 \\ \frac{V_{\rm ov}^*}{{\rm CHIB}}, \boldsymbol{GC_{\rm Q}}, 10^{-6}\right) & {\rm for} \; {\rm GC3} \le 0 \end{cases} \\ I_{\rm GDov}(V_{\rm GX}, \psi_{\rm ov}, V_{\rm ov}) = \begin{cases} A_{\rm Siov} = \exp\left(\frac{3.0 \cdot \phi_{\rm T} + \psi_{\rm ov} + \psi_{\rm tov}}{\phi_{\rm T}}\right) \\ A_{\rm Siov} = \exp\left(\frac{3.0 \cdot \phi_{\rm T} + \psi_{\rm ov} + \psi_{\rm tov}}{\phi_{\rm T}}\right) \\ I_{\rm Gov} = I_{\rm GOvp} \cdot F_{\rm Sov} \cdot \\ \exp\left(\boldsymbol{B_{\rm dov}} \cdot \left[-\frac{3}{2} + z_{\rm g} \cdot ({\rm GC2} + {\rm GC3} \cdot z_{\rm g})\right]\right) \end{cases} \end{cases}$$

$$I_{\text{GSov}} = I_{\text{GSov}} \left( V_{\text{GS}}, \psi_{\text{sov}}, V_{\text{ov}_0} \right) \tag{4.171}$$

$$I_{\text{GDov}} = I_{\text{GDov}} \left( V_{\text{GS}} - V_{\text{DS}}, \psi_{\text{dov}}, V_{\text{ov}_{\text{L}}} \right) \tag{4.172}$$

Gate-channel current:

$$V_{\rm m} = V_{\rm SB}^* + \phi_{\rm T}^* \cdot \left[ \frac{x_{\rm ds}}{2} - \ln \left( \frac{1 + \exp(x_{\rm ds} - V_{\rm dse}/\phi_{\rm T}^*)}{2} \right) \right]$$
(4.173)

$$\psi_{\rm t} = {\rm MINA} \left( 0, V_{\rm oxm} + D_{\rm ch}, 0.01 \right)$$
 (4.174)

$$V_{\text{oxm}}^* = \sqrt{V_{\text{oxm}}^2 + 10^{-6}} \tag{4.175}$$

$$z_{\rm g} = \begin{cases} \text{MINA} \left( \frac{V_{\rm oxm}^*}{\mathbf{CHIB}}, \mathbf{GC_Q}, 10^{-6} \right) & \text{for } \mathbf{GC3} < 0 \\ \frac{V_{\rm oxm}^*}{\mathbf{CHIB}} & \text{for } \mathbf{GC3} \ge 0 \end{cases}$$

$$(4.176)$$

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$$\Delta_{\rm Si} = \exp\left(x_{\rm m} - \frac{\alpha_{\rm b} + V_{\rm m} - \psi_{\rm t}}{\phi_{\rm T}^*}\right) \tag{4.177}$$

$$F_{\rm S} = \ln \left[ \frac{1 + \Delta_{\rm Si}}{1 + \Delta_{\rm Si} \cdot \exp\left(-\frac{V_{\rm GS} + V_{\rm SB}^* - V_{\rm m}}{\phi_{\rm T}^*}\right)} \right]$$
(4.178)

$$I_{\text{GCO}} = I_{\text{GINV}} \cdot F_{\text{S}} \cdot \exp\left(\boldsymbol{B} \cdot \left[-3/2 + z_{\text{g}} \cdot (\mathbf{GC2} + \mathbf{GC3} \cdot z_{\text{g}})\right]\right)$$
(4.179)

$$\operatorname{if} x_{\mathrm{g}} > 0 \begin{cases} u_{0} = \operatorname{CHiB} / \left[ B \cdot (\operatorname{GC2} + 2 \cdot \operatorname{GC3} \cdot z_{\mathrm{g}}) \right] \\ x = \Delta \psi / \left( 2 \cdot u_{0} \right) \\ b = u_{0} / H \\ B_{\mathrm{g}} = b \cdot \left( 1 - b \right) / 2 \\ A_{\mathrm{g}} = 1 / 2 - 3 \cdot B_{\mathrm{g}} \\ p_{\mathrm{gc}} = \left( 1 - b \right) \cdot \frac{\sinh(x)}{x} + b \cdot \cosh(x) \\ p_{\mathrm{gd}} = \frac{p_{\mathrm{gc}}}{2} - B_{\mathrm{g}} \cdot \sinh(x) - A_{\mathrm{g}} \cdot \frac{\sinh(x)}{x} \cdot \left[ \coth(x) - \frac{1}{x} \right] \end{cases}$$

$$(4.180)$$

if 
$$x_{\rm g} \le 0 \begin{cases} p_{\rm gc} = 1 \\ p_{\rm gd} = 1/2 \end{cases}$$
 (4.181)

$$S_{\rm g} = \frac{1}{2} \cdot \left( 1 + \frac{x_{\rm g}}{\sqrt{x_{\rm g}^2 + 10^{-6}}} \right) \tag{4.182}$$

$$I_{\rm GC} = I_{\rm GCO} \cdot p_{\rm gc} \cdot S_{\rm g} \tag{4.183}$$

$$I_{\text{GCD}} = I_{\text{GCO}} \cdot p_{\text{gd}} \cdot S_{\text{g}} \tag{4.184}$$

$$I_{GCS} = I_{GC} - I_{GCD} \tag{4.185}$$

$$I_{\rm GB} = I_{\rm GCO} \cdot p_{\rm gc} \cdot (1 - S_{\rm g}) \tag{4.186}$$

#### **Gate-Induced Drain/Source Leakage Current** 4.2.14

The equations in this section are only calculated when SWGIDL = 1.

$$I_{\text{gisl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \text{CGIDL}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gisl}} = \begin{cases} -A_{\text{GIDL}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDL}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gidl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \text{CGIDLD}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gidl}} = \begin{cases} -A_{\text{GIDLD}} \cdot t \cdot \exp\left(-\frac{B_{\text{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$I_{\text{gisl}} = I_{\text{gisl}}(V_{\text{ov}_0}, V_{\text{SB}})$$

$$(4.189)$$

$$I_{\text{gidl}}(V_{\text{ov}}, V) = \begin{cases} V_{\text{tov}} = \sqrt{V_{\text{ov}}^2 + \mathbf{CGIDLD}^2 \cdot V^2 + 10^{-6}} \\ t = V \cdot V_{\text{tov}} \cdot V_{\text{ov}} \\ I_{\text{gidl}} = \begin{cases} -\mathbf{A_{GIDLD}} \cdot t \cdot \exp\left(-\frac{\mathbf{B_{GIDLD}}}{V_{\text{tov}}}\right) & \text{for } V_{\text{ov}} < 0 \\ 0 & \text{for } V_{\text{ov}} \ge 0 \end{cases}$$

$$(4.188)$$

$$I_{gisl} = I_{gisl}(V_{ovo}, V_{SB})$$
 (4.189)

$$I_{\text{gidl}} = I_{\text{gidl}}(V_{\text{ov}_{\text{L}}}, V_{\text{DS}} + V_{\text{SB}}) \tag{4.190}$$

## 4.2.15 Total Terminal Currents

$$I_{\rm D} = I_{\rm DS} + I_{\rm avl} - I_{\rm GDov} - I_{\rm GCD} + I_{\rm gidl}$$

$$\tag{4.191}$$

$$I_{\rm S} = -I_{\rm DS} - I_{\rm GSov} - I_{\rm GCS} + I_{\rm gisl}$$
 (4.192)

$$I_{\rm G} = I_{\rm GC} + I_{\rm GB} + I_{\rm GDov} + I_{\rm GSov} \tag{4.193}$$

$$I_{\rm B} = -I_{\rm avl} - I_{\rm GB} - I_{\rm gidl} - I_{\rm gisl}$$
 (4.194)

# 4.2.16 Quantum-Mechanical Corrections

$$q_{\text{eff}} = \begin{cases} V_{\text{oxm}} & \text{for } x_{\text{g}} \le 0 \\ q_{\text{bm}} + \eta_{\mu} \cdot q_{\text{im}} & \text{for } x_{\text{g}} > 0 \end{cases}$$

$$(4.195)$$

$$q_{\text{eff}} = \begin{cases} V_{\text{oxm}} & \text{for } x_{\text{g}} \leq 0 \\ q_{\text{bm}} + \boldsymbol{\eta}_{\boldsymbol{\mu}} \cdot q_{\text{im}} & \text{for } x_{\text{g}} > 0 \end{cases}$$

$$C_{\text{OX}}^{\text{qm}} = \begin{cases} \mathbf{COX} & \text{for } \boldsymbol{q}_{\mathbf{q}} = 0 \\ \frac{\mathbf{COX}}{1 + \boldsymbol{q}_{\mathbf{q}}/(q_{\text{eff}}^2 + \boldsymbol{q}_{\text{lim}}^2)^{1/6}} & \text{for } \boldsymbol{q}_{\mathbf{q}} > 0 \end{cases}$$

$$(4.195)$$

# 4.2.17 Intrinsic Charge Model

$$\begin{cases}
F_{j} = \Delta \psi / (2 \cdot H) \\
q_{\Delta L} = (1 - G_{\Delta L}) \cdot (q_{im} - \alpha_{m} \cdot \Delta \psi / 2) \\
q_{\Delta L}^{*} = q_{\Delta L} \cdot (1 + G_{\Delta L}) \\
Q_{G}^{(i)} = C_{OX}^{qm} \cdot \left[ V_{OXm} + \frac{\eta_{p} \cdot \Delta \psi}{2} \cdot \left( \frac{G_{\Delta L}}{3} \cdot F_{j} + G_{\Delta L} - 1 \right) \right] \\
Q_{I}^{(i)} = -C_{OX}^{qm} \cdot \left[ G_{\Delta L} \cdot \left( q_{im} + \frac{\alpha_{m} \cdot \Delta \psi}{6} \cdot F_{j} \right) + q_{\Delta L} \right] \\
Q_{D}^{(i)} = -\frac{C_{OX}^{qm}}{2} \cdot \left[ G_{\Delta L}^{2} \cdot \left( q_{im} + \frac{\alpha_{m} \cdot \Delta \psi}{6} \cdot \left[ \frac{F_{j}^{2}}{5} + F_{j} - 1 \right] \right) + q_{\Delta L}^{*} \right]
\end{cases}$$

if 
$$x_{\rm g} \le 0$$

$$\begin{cases}
Q_{\rm G}^{(i)} = C_{\rm OX}^{\rm qm} \cdot V_{\rm oxm} \\
Q_{\rm I}^{(i)} = 0 \\
Q_{\rm D}^{(i)} = 0
\end{cases}$$
(4.198)

$$Q_{\rm S}^{(i)} = Q_{\rm I}^{(i)} - Q_{\rm D}^{(i)} \tag{4.199}$$

$$Q_{\rm B}^{(i)} = -Q_{\rm I}^{(i)} - Q_{\rm C}^{(i)} \tag{4.200}$$

# 4.2.18 Extrinsic Charge Model

The charges of the source and drain overlap regions:

$$Q_{\text{sov}} = \mathbf{CGOV} \cdot (V_{\text{GS}} - \psi_{\text{sov}}) \tag{4.201}$$

$$Q_{\text{dov}} = \mathbf{CGOVD} \cdot (V_{\text{GS}} - V_{\text{DS}} - \psi_{\text{dov}}) \tag{4.202}$$

The charge of the bulk overlap region

$$Q_{\text{bov}} = \mathbf{CGBOV} \cdot (V_{\text{GS}} + V_{\text{SB}}) \tag{4.203}$$

Outer fringe charge:

$$Q_{\text{ofs}} = \mathbf{CFR} \cdot V_{\text{GS}} \tag{4.204}$$

$$Q_{\text{ofd}} = \mathbf{CFRD} \cdot (V_{\text{GS}} - V_{\text{DS}}) \tag{4.205}$$

# **4.2.19** Total Terminal Charges

$$Q_{\rm G} = Q_{\rm G}^{(i)} + Q_{\rm sov} + Q_{\rm dov} + Q_{\rm ofs} + Q_{\rm ofd} + Q_{\rm bov}$$
(4.206)

$$Q_{\rm S} = Q_{\rm S}^{(i)} - Q_{\rm sov} - Q_{\rm ofs} \tag{4.207}$$

$$Q_{\rm D} = Q_{\rm D}^{(i)} - Q_{\rm dov} - Q_{\rm ofd} \tag{4.208}$$

$$Q_{\rm B} = Q_{\rm B}^{(i)} - Q_{\rm bov} \tag{4.209}$$

# 4.2.20 Noise Model

Eqs. (4.210)-(4.226) are only calculated for  $x_{\rm g}>0$ . In these equations  $f_{\rm op}$  represents the operation frequency of the transistor and  $j=\sqrt{-1}$ .

$$N^* = \frac{C_{\text{ox}}}{q} \cdot \alpha_{\text{m}} \cdot \phi_{\mathbf{T}} \tag{4.210}$$

$$N_{\rm m}^* = \frac{C_{\rm ox}}{q} \cdot q_{\rm im}^* \tag{4.211}$$

$$\Delta N = \frac{C_{\text{ox}}}{q} \cdot \alpha_{\text{m}} \cdot \Delta \psi \tag{4.212}$$

$$S_{\mathrm{fl}} = \frac{q \cdot \phi_{\mathbf{T}}^2 \cdot \boldsymbol{\beta} \cdot I_{\mathrm{DS}}}{f_{\mathrm{op}}^{\mathbf{EF}} \cdot C_{\mathrm{ox}} \cdot G_{\mathrm{vsat}} \cdot N^*} \cdot \left[ (\mathbf{NFA} - \mathbf{NFB} \cdot N^* + \mathbf{NFC} \cdot N^{*\,2}) \cdot \ln \left( \frac{N_{\mathrm{m}}^* + \Delta N/2}{N_{\mathrm{m}}^* - \Delta N/2} \right) \right]$$

+ 
$$\left(\mathbf{NFB} + \mathbf{NFC} \cdot [N_{\mathrm{m}}^* - 2 \cdot N^*]\right) \cdot \Delta N$$
 (4.213)

$$H_0 = \frac{q_{\rm im}^*}{\alpha_{\rm m}} \tag{4.214}$$

$$t_1 = \frac{q_{\rm im}}{q_{\rm im}^*} \tag{4.215}$$

$$t_2 = \left(\frac{\Delta\psi}{12 \cdot H_0}\right)^2 \tag{4.216}$$

$$R = \frac{H_0}{H} - 1 \tag{4.217}$$

$$l_{\rm c} = 1 - 12 \cdot t_2 \cdot R \tag{4.218}$$

$$g_{\text{ideal}} = \frac{\beta \cdot q_{\text{im}}^*}{G_{\text{vsat}}} \cdot F_{\Delta L} \tag{4.219}$$

$$C_{\text{Geff}} = \left(\frac{G_{\text{vsat}}}{G_{\text{mob}} \cdot G_{\Delta L}}\right)^2 \cdot C_{\text{OX}}^{\text{qm}} \cdot \eta_{\text{p}}$$
(4.220)

$$m_{\rm id} = \frac{g_{\rm ideal}}{l_c^2} \cdot [t_1 + 12 \cdot t_2 - 24 \cdot (1 + t_1) \cdot t_2 \cdot R]$$
(4.221)

$$S_{\rm id} = N_{\rm T} \cdot m_{\rm id} \tag{4.222}$$

$$m_{\text{ig}} = \frac{1}{l_c^2 \cdot g_{\text{ideal}}} \cdot \left[ \frac{t_1}{12} - t_2 \cdot \left( t_1 + \frac{1}{5} - 12 \cdot t_2 \right) - \frac{8}{5} \cdot t_2 \cdot (t_1 + 1 - 12 \cdot t_2) \cdot R \right]$$
(4.223)

$$S_{ig} = N_{T} \cdot \frac{(2 \cdot \pi \cdot f_{op} \cdot C_{Geff})^{2} \cdot m_{ig}}{1 + (2 \cdot \pi \cdot f_{op} \cdot C_{Geff} \cdot m_{ig})^{2}}$$

$$(4.224)$$

$$m_{\text{igid}} = \frac{\sqrt{t_2}}{l_c^2} \cdot \left[ 1 - 12 \cdot t_2 - \left( t_1 + \frac{96}{5} \cdot t_2 - 12 \cdot t_1 \cdot t_2 \right) \cdot R \right]$$
 (4.225)

$$S_{\text{igid}} = N_{\text{T}} \cdot \frac{2 \cdot \pi \cdot j \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{igid}}}{1 + 2 \cdot \pi \cdot j \cdot f_{\text{op}} \cdot C_{\text{Geff}} \cdot m_{\text{ig}}}$$
(4.226)

Gate current shot noise:

$$S_{igs} = 2 \cdot q \cdot (I_{GCS} + I_{GSov}) \tag{4.227}$$

$$S_{\text{igd}} = 2 \cdot q \cdot (I_{\text{GCD}} + I_{\text{GDov}}) \tag{4.228}$$

Avalanche current shot noise:

$$S_{\text{avl}} = 2 \cdot q \cdot (1 + M_{\text{avl}}) \cdot I_{\text{avl}} \tag{4.229}$$

Thermal noise for parasitic resistances (see Fig. 3.2):

$$S_{\rm R_G} = 4 \cdot k_{\rm B} \cdot T_{\rm KD} / R_{\rm gate} \tag{4.230}$$

$$S_{R_{\text{BULK}}} = 4 \cdot k_{\text{B}} \cdot T_{\text{KD}} / R_{\text{bulk}} \tag{4.231}$$

$$S_{\text{Rwell}} = 4 \cdot k_{\text{B}} \cdot T_{\text{KD}} / R_{\text{well}} \tag{4.232}$$

$$S_{\rm R_{\rm JUNS}} = 4 \cdot k_{\rm B} \cdot T_{\rm KD} / R_{\rm juns} \tag{4.233}$$

$$S_{\rm R_{\rm JUND}} = 4 \cdot k_{\rm B} \cdot T_{\rm KD} / R_{\rm jund} \tag{4.234}$$

# **Section 5**

# Non-quasi-static RF model

# 5.1 Introduction

For high-frequency modeling and fast transient simulations, a special version of the PSP model is available, which enables the simulation of non-quasi-static (NQS) effects, and includes several parasitic resistances.

# 5.2 NQS-effects

In the PSP-NQS model, NQS-effects are introduced by applying the one-dimensional current continuity equation  $(\partial I/\partial y \propto -\partial \rho/\partial t)$  to the channel. A full numerical solution of this equation is too inefficient for compact modeling, therefore an approximate technique is used. The channel is partitioned into N+1 sections of equal length by assigning N equidistant *collocation points*. The charge density (per unit channel area) along the channel is then approximated by a cubic spline through these collocation points, assuring that both the charge and its first and second spatial derivatives are continuous along the channel. Within this approximation, the current continuity equation reduces to a system of N coupled first order ordinary differential equations, from which the channel charge at each collocation point can be found:

$$\begin{cases}
\frac{dQ_1}{dt} = f_1(Q_1, \dots, Q_N) \\
\vdots & \vdots \\
\frac{dQ_N}{dt} = f_N(Q_1, \dots, Q_N)
\end{cases}$$
(5.1)

Here,  $Q_i$  is the charge density at the *i*-th collocation point and  $f_i$  are functions, which contain the *complete* PSP-charge model. These equations are implemented by the definition of appropriate subcircuits (see left part of Fig. 5.1) and solved by the circuit simulator. Finally, the four terminal charges are calculated from the channel charges, using the Ward-Dutton partitioning scheme for the source and drain charges.

A full description of the PSP-NQS model is given in Section 5.3. More background information can be found in literature [7, 8].

# 5.3 NQS Model Equations

In this section, several symbols and notations are used which were defined in Section 4. Moreover, y denotes the (normalized) position along the channel (y=0 is source side, y=1 is drain side), while x denotes the surface potential (normalized to  $\phi_T^*$ ) at a certain position.

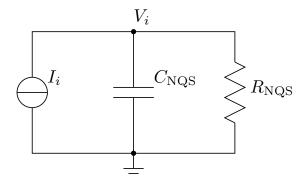


Figure 5.1: The subcircuit used to solve one of the differential equations of Eq. (5.1). The current is set to  $I_i = C_{\text{NQS}} \cdot f(V_1, \dots, V_N)$ , where the voltage  $V_i$  represents the charge density  $Q_i$  at the i-th collocation point and is solved by the circuit simulator. N of these circuits are defined and they are coupled through the dependence of  $I_i$  on the voltages of the other circuits. The resistance  $R_{\text{NQS}}$  has a very large value and is present only for convergence purposes. Right: The full network of parasitic elements in the PSP-NQS model. The large full dots indicate the five additional internal nodes.

# **5.3.1** Internal constants

Eqs. (5.2)–(5.7) are independent of bias conditions and time. Consequently, they have to be computed only once.

**Note:** In PSP, only **SWNQS** = 0, 1, 2, 3, 5, 9 are allowed!

$$n = SWNQS + 1 \tag{5.2}$$

$$h = 1/n \tag{5.3}$$

The matrix A is a square  $(n+1) \times (n+1)$ -matrix with elements  $A_{i,j}$   $(0 \le i, j \le n)$ , which are used in Eq. 5.25. They are computed using the following algorithm (adapted from [9]):

1. Initial values:

$$A_{i,j} = 0 \qquad \text{for } 0 \le i, j \le n \tag{5.4}$$

$$v_i = 0 \qquad \text{for } 0 \le i \le n \tag{5.5}$$

2. First loop:

$$p = 2 + v_{i-1}/2$$

$$v_{i} = -1/(2 \cdot p)$$

$$A_{i,i-1} = 1/h$$

$$A_{i,i} = -2/h$$

$$A_{i,i+1} = 1/h$$

$$A_{i,j} = \frac{1}{p} \cdot (3 \cdot A_{i,j}/h - A_{i-1,j}/2)$$
 for  $j = 0 \dots n$  (5.6)

# 3. Second loop (back substitution):

$$A_{i,j} = v_i \cdot A_{i+1,j} + A_{i,j}$$
 for  $j = 0 \dots n$  
$$\begin{cases} \text{for } i = (n-1) \dots 0 \end{cases}$$
 (5.7)

# 5.3.2 Position independent quantities

The following quantities depend on the bias conditions, but are constant along the channel:

$$if x_{g} > 0 \begin{cases}
y_{m} = \frac{1}{2} \cdot \left(1 + \frac{\Delta \psi}{4 \cdot H}\right) \\
p_{d} = \frac{x_{gm}}{x_{g} - x_{m}} \\
G_{p} = G/p_{d}
\end{cases} (5.8)$$

if 
$$x_{\rm g} \le 0$$

$$\begin{cases} y_{\rm m} = 1/2 \\ p_{\rm d} = 1 \\ G_{\rm p} = G \end{cases}$$

$$(5.9)$$

$$a_{\rm p} = 1 + G_{\rm p}/\sqrt{2}$$
 (5.10)

$$p_{\rm mrg} = 10^{-5} \cdot a_{\rm p}$$
 (5.11)

# 5.3.3 Position dependent surface potential and charge

Interpolated (quasi-static) surface potential along the channel:

$$\Psi(y) = x_{\rm m} + \frac{H}{\phi_{\rm T}^*} \cdot \left(1 - \sqrt{1 - \frac{2 \cdot \Delta \psi}{H} \cdot (y - y_{\rm m})}\right)$$
(5.12)

Normalized bulk-charge and its first two derivatives as functions of surface potential:

$$q_{\rm b}(x) = -\operatorname{sgn}(x) \cdot G_{\rm p} \cdot \sqrt{\exp(-x) + x - 1}$$

$$(5.13)$$

$$q_{\rm b}'(x) = \frac{G_{\rm p}^2 \cdot [1 - \exp(-x)]}{2 \cdot q_{\rm b}(x)}$$
(5.14)

$$q_{\rm b}''(x) = -q_{\rm b}'(x) - \frac{q_{\rm b}'(x)^2 - G_{\rm p}^2/2}{q_{\rm b}(x)}$$
(5.15)

Surface potential as a function of normalized inversion charge (note that these equations are identical to Eq. (4.163), despite the different notation and physical background):

$$\Pi(x_g) = \begin{cases} y_g = -x_g \\ z = 1.25 \cdot y_g/a_p \\ \eta = \left[z + 10 - \sqrt{(z - 6)^2 + 64}\right]/2 \\ a = (y_g - \eta)^2 + G_p^2 \cdot (\eta + 1) \\ c = 2 \cdot (y_g - \eta) - G_p^2 \\ \tau = -\eta + \ln\left(a/G_p^2\right) \\ y_0 = \sigma_1(a, c, \tau, \eta) \\ \Delta_0 = \exp(y_0) \\ \xi = 1 - G_p^2 \cdot \Delta_0/2 \\ p = 2 \cdot (y_g - y_0) + G_p^2 \cdot (\Delta_0 - 1) \\ \eta = (y_g - y_0)^2 + G_p^2 \cdot (y_0 - \Delta_0 + 1) \\ \Pi = -y_0 - \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot q \cdot \xi}} \\ \Pi = \frac{x_g}{a_p} \cdot \left[1 + x_g \cdot (x_1 \cdot a_p/\hat{x}_{g1} - 1)/\hat{x}_{g1}\right] \\ x_0 = x_g + G_p^2/2 - G_p \cdot \sqrt{x_g + G_p^2/4 - 1 + \exp(-\bar{x})} \\ \Delta_0 = \exp(-x_0) \\ \xi = 1 - G_p^2 \cdot \Delta_0/2 \\ p = 2 \cdot (x_g - x_0) + G_p^2 \cdot (1 - \Delta_0) \\ q = (x_g - x_0)^2 - G_p^2 \cdot (x_0 + \Delta_0 - 1) \\ \Pi = x_0 + \frac{2 \cdot q}{p + \sqrt{p^2 - 4 \cdot q \cdot \xi}} \end{cases}$$

$$(5.17)$$

$$X(x_{\rm g}, q_{\rm inv}) = \Pi(x_{\rm g} + q_{\rm inv}/p_{\rm d})$$
 (5.17)

Auxiliary functions:

$$q(x) = -p_{\rm d} \cdot (x_{\rm g} - x) - q_{\rm b}(x) \tag{5.18}$$

$$\psi(q, q_{x1}) = \frac{q}{q_{x1}} - 1 \tag{5.19}$$

$$\phi(q, q_{x1}, q_{x2}) = \left(1 - \frac{q \cdot q_{x2}}{q_{x1}^2}\right) / q_{x1} \tag{5.20}$$

Normalized right-hand-side of continuity equation:

maintee right-hand-side of containty equation: 
$$\begin{cases} x_{\rm z} = X(x_{\rm g},q) \\ q_{x1} = \frac{\partial q}{\partial x}(x_{\rm z}) = p_{\rm d} - q_{\rm b}'(x_{\rm z}) \\ q_{x2} = \frac{\partial^2 q}{\partial x^2}(x_{\rm z}) = q_{\rm b}''(x_{\rm z}) \\ f_0 = \psi(q,q_{x1}) \cdot q'' + \phi(q,q_{x1},q_{x2}) \cdot q'^2 \\ x_{y1} = \frac{\partial x_{\rm z}}{\partial y} = q'/q_{x1} \\ \begin{cases} \left(\theta_{\rm sat}^* \cdot \phi_{\rm T}^* \cdot x_{y1}\right)^2 & \text{for NMOS} \\ \\ z_{\rm sat} = \begin{cases} \left(\theta_{\rm sat}^* \cdot \phi_{\rm T}^* \cdot x_{y1}\right)^2 & \text{for PMOS} \end{cases} \end{cases}$$
 
$$\zeta = \sqrt{1 + 2 \cdot z_{\rm sat}} \\ F_{\rm vsat} = 2/(1 + \zeta) \\ f = F_{\rm vsat} \cdot \left[f_0 - F_{\rm vsat} \cdot \frac{z_{\rm sat}}{\zeta} \cdot \psi(q,q_{x1}) \cdot (q'' + x_{y1}^2 \cdot q_{\rm b}''(x_{\rm z}))\right]$$
 rmalization constant:

Normalization constant:

$$T_{\text{norm}} = \frac{\text{MUNQS} \cdot \phi_{\mathbf{T}}^* \cdot \beta}{C_{\text{OX}}^{\text{qm}} \cdot G_{\text{mob}} \cdot G_{\Delta L}}$$
(5.22)

# **5.3.4** Cubic spline interpolation

Using cubic spline interpolation, the spatial derivatives  $\frac{\partial q_i}{\partial y}(t)$  and  $\frac{\partial^2 q_i}{\partial y^2}(t)$  can be expressed as functions of the  $q_i(t)$ .

$$q_0'' = 0$$
 (5.23)

$$q_n'' = 0 ag{5.24}$$

$$q_i'' = \sum_{j=0}^{n} A_{i,j} \cdot q_i$$
 for  $1 \le i \le n-1$  (5.25)

$$q_i' = \frac{q_{i+1} - q_i}{h} - \frac{h}{6} \cdot (2 \cdot q_i'' + q_{i+1}'') \qquad \text{for } 1 \le i \le n - 1$$
(5.26)

# 5.3.5 Continuity equation

Initial value for the  $q_i$  ( $0 \le i \le n$ ). These values are used for the DC operating point.

$$x_{i,0} = \Psi(i \cdot h) \tag{5.27}$$

$$q_{i,0} = q(x_{i,0}) (5.28)$$

**Note:**  $x_{0,0} = x_s$  and  $x_{n,0} = x_d$ . Moreover, these values coincide with those in the quasi-static part of PSP.

The core of the NQS-model is the solution of q(y,t) from the charge continuity equation along the channel. By approximating the y-dependence by a cubic spline through a number of collocation points, the problem is reduced to solving the  $q_i(t)$  from the following set of coupled differential equations.

$$\begin{cases}
\frac{\partial q_i}{\partial t}(t) + T_{\text{norm}} \cdot f\left(x_g, q_i(t), \frac{\partial q_i}{\partial y}(t), \frac{\partial^2 q_i}{\partial y^2}(t)\right) = 0 \\
q_i(0) = q_{i,0}
\end{cases}$$
for  $1 \le i \le n - 1$ 

Note that the boundary points  $q_0(t) = q(x_s) = q_{is}$  and  $q_n(t) = q(x_d) = q_{id}$  remain fixed to their quasi-static values; they are not solved from the equation above.

The set of differential equations defined above is solved by the circuit simulator via the subcircuits shown in the left part of Fig. 5.1.

# 5.3.6 Non-quasi-static terminal charges

Once the  $q_i$  are known, the NQS terminal charges can be computed:

$$S_0 = \sum_{i=1}^{n-1} q_i \tag{5.30}$$

$$S_2 = \sum_{i=1}^{n-1} q_i^{"} \tag{5.31}$$

$$q_{\rm I}^{\rm NQS} = \int_0^1 q(y) \, \mathrm{d}y = h \cdot S_0 + \frac{h}{2} \cdot (u_0 + u_n) - \frac{h^3}{12} \cdot S_2$$
 (5.32)

$$U_0 = \sum_{i=1}^{n-1} i \cdot q_i \tag{5.33}$$

$$U_2 = \sum_{i=1}^{n-1} i \cdot q_i'' \tag{5.34}$$

$$q_{\rm D}^{\rm NQS} = \int_0^1 y \cdot q(y) \, \mathrm{d}y = h^2 \cdot U_0 + \frac{h^2}{6} \cdot [q_0 + (3n - 1)u_n] - \frac{h^4}{12} \cdot U_2$$
 (5.35)

$$q_{\rm S}^{\rm NQS} = q_{\rm I}^{\rm NQS} - q_{\rm D}^{\rm NQS} \tag{5.36}$$

Currently, only **SWNQS** = 0, 1, 2, 3, 5, 9 are allowed. For odd values of **SWNQS** the gate charge is integrated along the channel using "Simpson's rule". If **SWNQS** = 2, "Simpson's 3/8-rule" is used.

• If **SWNQS** is odd (that is, n is even):

$$q_{G}^{NQS} = p_{d} \cdot \left[ x_{g} - \frac{h}{3} \cdot \left( X(x_{g}, q_{0}) + 4 \cdot \sum_{i=1}^{n/2} X(x_{g}, q_{2i-1}) + \frac{1}{2} \cdot \sum_{i=1}^{n/2-1} X(x_{g}, q_{2i}) + X(x_{g}, q_{n}) \right) \right]$$
(5.37)

• If SWNQS = 2 (that is, n = 3):

$$q_{\rm G}^{\rm NQS} = p_{\rm d} \cdot \left[ x_{\rm g} - \frac{3 \cdot h}{8} \cdot (X(x_{\rm g}, q_0) + 3 \cdot X(x_{\rm g}, q_1) + 3 \cdot X(x_{\rm g}, q_2) + X(x_{\rm g}, q_3)) \right]$$
(5.38)

Convert back to conventional units:

$$Q_{\rm S}^{\rm NQS} = C_{\rm OX}^{\rm qm} \cdot \boldsymbol{\phi}_{\rm T}^* \cdot q_{\rm S}^{\rm NQS} \tag{5.39}$$

$$Q_{\rm D}^{\rm NQS} = C_{\rm OX}^{\rm qm} \cdot \boldsymbol{\phi}_{\rm T}^* \cdot q_{\rm D}^{\rm NQS}$$
(5.40)

$$Q_{\rm G}^{\rm NQS} = C_{\rm OX}^{\rm qm} \cdot \phi_{\rm T}^* \cdot q_{\rm G}^{\rm NQS}$$
(5.41)

$$Q_{\rm B}^{\rm NQS} = -(Q_{\rm S}^{\rm NQS} + Q_{\rm D}^{\rm NQS} + Q_{\rm G}^{\rm NQS})$$
 (5.42)

# **Section 6**

# **Embedding**

# **6.1** Model selection

Circuit simulators have different ways for the user to determine which model must be used for simulation. Typically, model selection is either done by *name* or by assigning a value to the parameter **LEVEL**. The method to be used is prescribed by the circuit simulator vendor. If selection is done by name, the value of the parameter **LEVEL** is generally ignored. When Verilog-A code is used, model selection is always done by name

For the SiMKit and the Verilog-A code provided by the PSP model developers, the method and values to be used are given in the table below. For other implementations, the method/value provided by the circuit simulator vendor is to be used.

Simulator	Model selection by	Global (geom.)	Global (binning)	Local
Spectre	name	psp1020	psp1021	psp102e
Pstar	LEVEL	1020	1021	102
ADS	name	psp1020	psp1021	psp102e
Verilog-A	name	PSP102VA	PSP102BVA	PSP102EVA

# 6.2 Case of parameters

Throughout this document, all parameter names are printed in uppercase characters. Similarly, in the Verilog-A code provided by the PSP model developers, the parameters are in upper case characters. However, in other PSP implementations a different choice can be made. For example, the parameter names may be in lowercase characters (possibly first character capitalized) if this is conform the conventions of the circuit simulator.

# **6.3** Embedding PSP in a Circuit Simulator

In CMOS technologies both n- and p-channel MOS transistors are supported. It is convenient to use the same set of equations for both types of transistor instead of two separate models. This is accomplished by mapping a p-channel device with its bias conditions and parameter set onto an equivalent n-channel device with appropriately changed bias conditions (i.e. currents, voltages and charges) and parameters. In this way both types of transistor can be treated internally as an n-channel transistor. Nevertheless, the electrical behavior of electrons and holes is not exactly the same (e.g., the mobility and tunneling behavior), and consequently slightly different equations have to be used in case of n- or p-type transistors.

Designers are used to the standard terminology of source, drain, gate and bulk. Therefore, in the context of a circuit simulator it is traditionally possible to address, say, the drain of MOST number 17, even if in reality

the corresponding source is at a higher potential (n-channel case). More strongly, most circuit simulators provide for model evaluation values for  $V_{\rm DS}$ ,  $V_{\rm GS}$ , and  $V_{\rm SB}$  based on an a priori assignment of source, drain, and bulk, independent of the actual bias conditions. Since PSP assumes that saturation occurs at the drain side of the MOSFET, the basic model cannot cope with bias conditions that correspond to  $V_{\rm DS} < 0$ . Again a transformation of the bias conditions is necessary. In this case, the transformation corresponds to internally reassigning source and drain, applying the standard electrical model, and then reassigning the currents and charges to the original terminals. In PSP care has been taken to preserve symmetry with respect to drain and source at  $V_{\rm DS} = 0$ . In other words, no singularities will occur in the higher-order derivatives at  $V_{\rm DS} = 0$ .

In detail, for correct embedding of PSP into a circuit simulator, the following procedure—illustrated in Fig. 6.1—is followed. It is assumed that the simulator provides the nodal potentials  $V_{\rm D}^e$ ,  $V_{\rm G}^e$ ,  $V_{\rm S}^e$  and  $V_{\rm B}^e$  based on an a priori assignment of drain, gate, source and bulk.

- **Step 1** The voltages  $V'_{\rm DS}$ ,  $V'_{\rm GS}$ , and  $V'_{\rm SB}$  are calculated from the nodal potentials provided by the circuit simulator. In the same step, the value of the parameter **TYPE** is used to deal with the polarity of the device. From here onwards, all transistors can be treated as n-channel devices.
- **Step 2** Depending on the sign of  $V'_{DS}$ , 'source-drain interchange' is performed. At this level, the voltages comply to all the requirements for input quantities of PSP.
- **Step 3** All the internal output quantities (i.e. channel current, weak-avalanche current, gate current, nodal charges, and noise-power spectral densities) are evaluated using the standard PSP equations (Section 4) and the internal voltages.
- Step 4 The internal output quantities are corrected for a possible source-drain interchange.
- **Step 5** External output are corrected for a possible *p*-channel transformation and **MULT** is applied. The quantities of the intrinsic MOSFET and the junctions are combined.

In general, separate parameter sets are used for n- and p-channel transistors, which are distinguished by the value of **TYPE**. As a consequence, the changes in the parameter values necessary for a p-channel type transistor are normally already included in the parameter sets on file. The changes should therefore not be included in the simulator.

### 6.3.1 Selection of device type

In the SiMKit-based and built-in version of PSP in certain circuit simulators, the selection of device type (nmos or pmos) is done using a different parameter, or using different parameter values. The correct values for some circuit simulators are given in the table below.

Simulator	Parameter	Value NMOS	value PMOS
Spectre	type	n	р
Pstar	type	1	-1
ADS	gender	1	0
Verilog-A	type	1	-1

## 6.4 Integration of JUNCAP2 in PSP

### Introduction

The JUNCAP2 model 200.3 is an integral part of PSP 102.2. In addition, it is available as a stand-alone model. A complete description of the JUNCAP2-model (including all model equations) can be found in the documentation of JUNCAP2's stand alone version [10]. In this section, only the integration of JUNCAP2 in PSP is described.

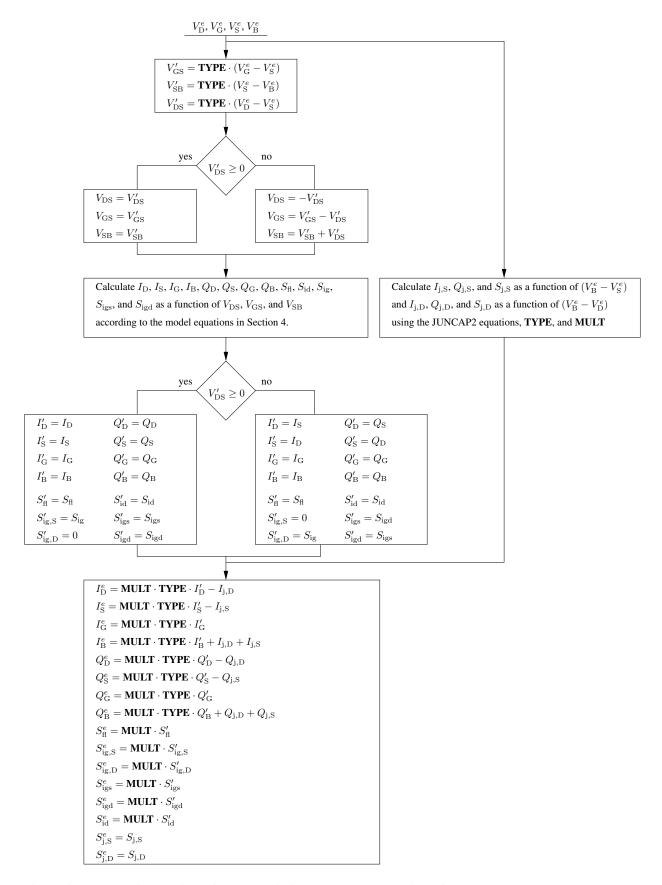


Figure 6.1: Schematic overview of source-drain interchange and handling of **TYPE** and **MULT**. Note that **TYPE** and **MULT** are included in the JUNCAP2 model equations.

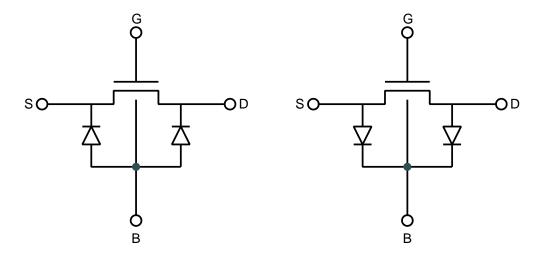


Figure 6.2: Topology of the PSP model. *Left: n*-channel MOSFET; *Right: p*-channel MOSFET. In PSP, the correct diode polarity is automatically chosen via the **TYPE**-parameter.

### **Topology**

In a MOS transistor, there are two junctions: one between source and bulk, and one between drain and bulk. In case of an n-channel MOSFET, the junction anode corresponds to the MOSFET bulk terminal, and the junction cathodes correspond to the source and the drain. In case of a p-channel MOSFET, it is the other way around: now the junction cathode corresponds to the MOSFET bulk terminal, and the junction anodes correspond to the source and the drain. The connections are schematically given in Fig. 6.2. In PSP, this change of junction terminal connections in case of a p-MOSFET is handled automatically via the **TYPE** parameter.

In most cases, the MOSFET is operated in such a way that the junctions are either biased in the reverse mode of operation or not biased at all. In some applications, however, the source-bulk junction has a small forward bias. This is also the case in partially depleted SOI (PDSOI).

As indicated in Fig. 6.1, the interchange of source and drain for  $V_{\rm DS} < 0$  (as explained above for the intrinsic MOS model) does *not* apply to the junctions. For example, **ABDRAIN** always refers to junction between the bulk and the terminal known as 'drain' to the simulator, independent of the sign of  $V_{\rm DS}$ .

### Global and local model level

As explained in the introduction, the PSP model has a local and a global level. The JUNCAP2 model is a geometrically scaled model, i.e. it is valid for a range of junction geometries (as described by the geometrical parameters **AB**, **LS**, and **LG**). It has turned out that it is very unnatural to create a local parameter set for JUNCAP2, valid for one particular junction geometry: such a parameter set would have as many parameters as the global parameter set, and would be of no use. (Note that, in contrast, the local model for the intrinsic MOSFET is very useful in, e.g., parameter extraction; this is not the case for JUNCAP2.)

Therefore, the JUNCAP2 model is connected in exactly the same way to both the local and global model levels of PSP. That means that the resulting PSP local model is valid for a MOSFET with one particular channel width and length, but with arbitrary junction geometry.

#### **Parameters**

Both junctions in the MOSFET are modeled with the same set of JUNCAP2 parameters. In the PSP model, the geometrical parameters **AB**, **LS**, and **LG** need to be specified for both source and drain. They will be denoted as **ABSOURCE**, **LSSOURCE**, and **LGSOURCE** for the source junction, and **ABDRAIN**, **LSDRAIN**, and **LGDRAIN** for the drain junction. For compatibility with BSIM instance parameters, there is also an option to use **AS**, **AD**, **PS**, and **PD**. The complete list of instance parameters (PSP and JUNCAP2) can be found in

Sections 2.5.1 and 2.5.2.

The parameter **MULT** is merged with the parameter **MULT** of the intrinsic MOSFET model. In other words, both intrinsic currents, charges, and noise as well as junction currents, charges and noise are multiplied by one single parameter **MULT**. Beside **MULT**, also the parameters **DTA** and **TYPE** are shared by the intrinsic MOSFET model and the junction model. For clarity, we mention here that the reference temperatures of the intrinsic MOSFET model and junction model are *not* merged; they each have their own value and name (**TR** and **TRJ**, respectively). The currents, charges and spectral noise densities of the source and drain junctions are labeled  $I_{i,S}$ ,  $Q_{i,S}$ ,  $S_{i,S}$ ,  $I_{i,D}$ ,  $Q_{i,D}$ , and  $S_{i,D}$  in Fig. 6.1.

### 6.5 Verilog-A versus C

As mentioned in Section 1.3, two implementations of the PSP-model are distributed: in Verilog-A language and in C-language (as part of the SiMKit). The C-version is automatically generated from the Verilog-A version by a software package called ADMS [1]. This procedure guarantees that the two implementations contain identical model equations.

Nevertheless, there are a few minor differences between the two, which are due to certain limitations of either the Verilog-A language or the circuit simulators supported in the SiMKit-framework. These differences are described below.

### **6.5.1** Implementation of GMIN

In both implementations, there is an additional term in Eqs. (4.191) and (4.192), resulting in

$$I_{\rm D} = I_{\rm DS} + I_{\rm avl} - I_{\rm GDov} - I_{\rm GCD} + I_{\rm gidl} + G_{\rm min} \cdot V_{\rm DS}$$

$$(6.1)$$

and

$$I_{\rm S} = -I_{\rm DS} - I_{\rm GSov} - I_{\rm GCS} + I_{\rm gisl} - G_{\rm min} \cdot V_{\rm DS}. \tag{6.2}$$

In the SiMKit,  $G_{\min}$  is a variable which is accessible by the circuit simulator. This allows the circuit simulator to improve the convergence properties of a circuit by making use of so-called ' $G_{\min}$ -stepping'.

In the Verilog-A version of PSP,  $G_{\min}$  is set to a fixed value  $G_{\min} = 1 \cdot 10^{-15} \text{ S.}^1$ 

### 6.5.2 Implementation of parasitic resistances

From PSP 102.2 onwards, a network of parasitic resistors has been inserted around the intrinsic MOSFET. If the user sets one or more of these resistance values to zero, the associated internal node(s) could be shorted to one of its neighbors, reducing the size of the matrix in the circuit simulator. This phenomenon is called 'node collapse' and is supported by most major circuit simulators.

Flexible topology (and thus node collapse) is presently supported by most Verilog-A compilers. As a result, node collapse is functional in the official PSP Verilog-A in the majority of today's circuit simulators.

From SiMKit 3.0 onwards, the SiMKit architecture allows for flexible topologies and therefore supports node collapse in PSP. This functionality is therefore available in circuit simulations with that can work with SiMKit. Besides, many circuit simulators that have a native implementation of PSP support node collapse.

 $<sup>^{1}</sup>$ If supported by the circuit simulator, Verilog-A version 2.2 allows the value of  $G_{\min}$  to be accessed by the circuit simulator. Once this feature is generally available in Verilog-A compilers, it will be included in PSP as well.

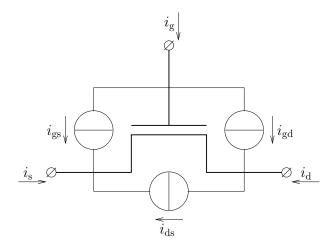


Figure 6.3: Definition of noise currents.

### 6.5.3 Implementation of the noise-equations

#### **Definition of noise model**

Eqs. (4.222), (4.224), and (4.226) describe the noise power spectral density of the thermal noise. In this section, the relationship between the quantities  $S_{\rm id}$ ,  $S_{\rm ig}$ , and  $S_{\rm igid}$  (as calculated in these equations) and noise sources in the model is defined.

Fig. 6.3 shows a schematic representation of a noiseless transistor (model) and three noise sources. The small-signal noise currents of these noise current sources are indicated by  $i_{\rm ds}$ ,  $i_{\rm gs}$ , and  $i_{\rm gd}$ . The two noise sources connected to G are fully correlated. Moreover, each of them is partly correlated with the noise source between S and D. More precisely, the noise powers and correlations associated with these sources are given by

$$\langle i_{\rm ds} \cdot i_{\rm ds}^* \rangle = S_{\rm id}$$

$$\langle i_{\rm gd} \cdot i_{\rm ds}^* \rangle = S_{\rm igid}/2$$

$$\langle i_{\rm gs} \cdot i_{\rm ds}^* \rangle = S_{\rm igid}/2$$

$$\langle i_{\rm gd} \cdot i_{\rm gd}^* \rangle = S_{\rm ig}/4$$

$$\langle i_{\rm gs} \cdot i_{\rm gd}^* \rangle = S_{\rm ig}/4$$

$$\langle i_{\rm gs} \cdot i_{\rm gs}^* \rangle = S_{\rm ig}/4$$

$$\langle i_{\rm gs} \cdot i_{\rm gs}^* \rangle = S_{\rm ig}/4$$
(6.3)

The non-listed elements follow from the fact that this is a complex correlation matrix and therefore self-adjoint. This defines the noise model of PSP.

For completeness, we will give the noise correlation matrix associated with the *terminal* currents  $i_{\rm d}$ ,  $i_{\rm g}$  and  $i_{\rm s}$ , because it is closer related to the numbers that are obtained in a circuit simulation. Because  $i_{\rm d}=i_{\rm ds}-i_{\rm gs}$ ,  $i_{\rm g}=i_{\rm gs}+i_{\rm gd}$  and  $i_{\rm s}=i_{\rm gs}-i_{\rm ds}$ , we find by straightforward substitution and some basic arithmetic

$$\langle i_{d} \cdot i_{d}^{*} \rangle = S_{id} + S_{ig}/4 - \operatorname{Re}(S_{igid})$$

$$\langle i_{g} \cdot i_{d}^{*} \rangle = S_{igid} - S_{ig}/2$$

$$\langle i_{s} \cdot i_{d}^{*} \rangle = -S_{id} + S_{ig}/4 - \operatorname{Im}(S_{igid})$$

$$\langle i_{g} \cdot i_{g}^{*} \rangle = S_{ig}$$

$$\langle i_{s} \cdot i_{g}^{*} \rangle = -S_{igid}^{*} - S_{ig}/2$$

$$\langle i_{s} \cdot i_{s}^{*} \rangle = S_{id} + S_{ig}/4 + \operatorname{Re}(S_{igid})$$
(6.4)

#### Verilog-A

In Verilog-A it is not possible to define noise sources that are frequency dependent (except for 1/f-noise), nor is it possible to directly define correlations between noise sources. Instead, the desired model must be created by using controlled sources and the frequency transfer of passive elements.<sup>2</sup>

The goal is to create the three noise sources shown in Fig. 6.3 with the noise powers (including frequency dependence and correlation) as described by Eq. (6.3).

To simplify notation, we rewrite Eqs. (4.224) and (4.226) as

$$S_{ig} = \frac{N_{T}}{m_{ig}} \cdot |T|^2 \tag{6.5}$$

and

$$S_{\text{igid}} = \frac{N_{\text{T}}}{m_{\text{ig}}} \cdot m_{\text{igid}} \cdot T,$$
 (6.6)

where

$$T = \frac{j \cdot \omega \cdot \tau}{1 + j \cdot \omega \cdot \tau},\tag{6.7}$$

 $au = m_{
m ig} \cdot C_{
m Geff}$  and  $\omega$  is the operating frequency.

Correlation between noise sources in verilog-A can be created by making linear combinations of independent sources. Therefore, we start with two *independent* white noise sources with current noise spectral densities  $S_1$ and  $S_2$  and noise currents  $i_1$  and  $i_2$ . If we set

$$i_{gs} = i_{gd} = \frac{1}{2} \cdot \alpha_1 \cdot i_1$$
 (6.8)  
 $i_{ds} = \beta_1 \cdot i_1 + \beta_2 \cdot i_2,$  (6.9)

$$i_{\rm ds} = \beta_1 \cdot i_1 + \beta_2 \cdot i_2, \tag{6.9}$$

where  $\alpha_1$ ,  $\beta_1$ , and  $\beta_2$  are certain (complex) coefficients, we get

$$S_{ig} = 4 \cdot \langle i_{gd} \cdot i_{gd}^* \rangle = |\alpha_1|^2 \cdot \langle i_1 \cdot i_1^* \rangle$$

$$= |\alpha_1|^2 \cdot S_1$$
(6.10)

$$S_{\text{id}} = \langle i_{\text{ds}} \cdot i_{\text{ds}}^* \rangle = |\beta_1|^2 \cdot \langle i_1 \cdot i_1^* \rangle + \beta_1 \cdot \beta_2^* \cdot \langle i_1 \cdot i_2^* \rangle + |\beta_2|^2 \cdot \langle i_2 \cdot i_2^* \rangle$$

$$= |\beta_1|^2 \cdot S_1 + |\beta_2|^2 \cdot S_2$$

$$(6.11)$$

$$S_{\text{igid}} = 2 \cdot \langle i_{\text{gd}} \cdot i_{\text{ds}}^* \rangle = \alpha_1 \cdot \beta_1^* \cdot \langle i_1 \cdot i_1^* \rangle + \alpha_1 \cdot \beta_2^* \cdot \langle i_1 \cdot i_2^* \rangle$$

$$= \alpha_1 \cdot \beta_1^* \cdot S_1. \tag{6.12}$$

Here we used that the noise currents  $i_1$  and  $i_2$  are independent, such that  $\langle i_1 \cdot i_2^* \rangle = 0$ . We need to choose proper values for the coefficients  $\alpha_1$ ,  $\beta_1$  and  $\beta_2$ , as well as  $S_1$  and  $S_2$ , such that  $S_{ig}$ ,  $S_{id}$ , and  $S_{igid}$  get the correct value. There is some freedom in choosing the numbers; the values that are used in the verilog-A implementation of PSP are

$$\alpha_1 = T \tag{6.13}$$

$$\beta_1 = m_{\text{igid}} \tag{6.14}$$

$$\beta_2 = 1 \tag{6.15}$$

$$S_1 = N_{\mathrm{T}}/m_{\mathrm{ig}} \tag{6.16}$$

$$S_2 = N_{\mathbf{T}} \cdot (1 - C_{\text{igid}}^2) \cdot m_{\text{id}}, \tag{6.17}$$

<sup>&</sup>lt;sup>2</sup>Although this appears to be a limitation, it is in fact very helpful to ensure that the resulting noise model is consistent with time-domain simulations.

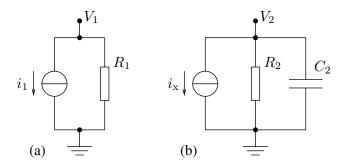


Figure 6.4: The two subcircuits used in PSP's Verilog-A implementation to model the correct frequency dependence of induced gate noise and its correlation with the channel thermal noise.

where

$$C_{\text{igid}} = \frac{m_{\text{igid}}}{\sqrt{m_{\text{ig}} \cdot m_{\text{id}}}},\tag{6.18}$$

and  $m_{\rm id}$ ,  $m_{\rm ig}$ , and  $m_{\rm igid}$  are given by Eqs. (4.221), (4.223), and (4.225), respectively.

To achieve this, we make use of the subcircuits depicted in Fig. 6.4. The first subcircuit (a) contains a parallel connection of a white noise source with current small-signal noise current  $i_1$  and a resistor  $R_1$ . The voltage over the elements is denoted by  $V_1$ . The second subcircuit (b) contains a voltage-controlled current source with current  $i_x$ , a resistor  $R_2$ , and a capacitor  $C_2$ . The nodal voltage is denoted by  $V_2$ .

The parameters of these components are given by

$$S_1 = \langle i_1 \cdot i_1^* \rangle = S_{ig}^0 \cdot S_f^2 \tag{6.19}$$

$$R_1 = 1\Omega \tag{6.20}$$

$$i_{\rm x} = -V_1/s_{\rm f} \tag{6.21}$$

$$R_2 = m_{ig} ag{6.22}$$

$$C_2 = C_{\text{Geff}}$$
 (6.23)

where the values of  $C_{\mathrm{Geff}}$  is given by Eqs. (4.220) and

$$S_{\rm ig}^0 = \frac{N_{\rm T}}{m_{\rm ig}}.\tag{6.24}$$

Moreover, we introduce a scaling factor  $s_{\rm f} = \omega_0 \cdot m_{\rm ig} \cdot C_{\rm Geff}$  with  $\omega_0 = 1$  MHz. Note that the value of  $s_{\rm f}$  and  $\omega_0$  do not affect the final result, but help to give the noise power of  $V_1$  a reasonable value.

Choosing the elements in this way, creates a frequency dependent current  $i_C$  through the capacitor  $C_2$  given by

$$i_C = T \cdot i_{\mathbf{x}}.$$
 (6.25)

The two noise sources connected to the gate in Fig. 6.3 are now realized as two current-controlled current sources with

$$i_{\rm gd} = i_{\rm gs} = \frac{1}{2} \cdot i_C.$$
 (6.26)

The third source in Fig. 6.3 (between source and drain) is realized by putting two elements in parallel:

- A voltage controlled current source with value  $(m_{\rm igid}/s_{\rm f}) \cdot V_1$  and
- A white noise source with current power spectral density  $S_2 = N_T \cdot (1 C_{\text{igid}}^2) \cdot m_{\text{id}}$ .

To complete the model, we remark that from Fig. 6.3 it is clear that source-drain interchange only affects the sign of  $i_{\rm ds}$ .

In summary, the relevant portion of the verilog-A implementation is given by (mult-scaling and labels are not included for clarity):

```
electrical NOI;
electrical NOI2;
branch (NOI) NOII;
branch (NOI) NOIR;
branch (NOI) NOIC;
// subcircuit (a)
I (NOI2)
          <+ V(NOI2);
             white_noise(sqig * sqig * sf * sf);
I (NOI2)
// subcircuit (b)
        \leftarrow -V(NOI2) / sf;
I (NOII)
I (NOIR)
          \leftarrow V(NOIR) / mig;
          <+ ddt(CGeff * V(NOIC));
I (NOIC)
// noise sources ids, igs, and igd
I(DI, SI)
          <+ white_noise(sqid * sqid * (1.0 - c_igid * c_igid));
               sigVds * migid * V(NOI2) / sf;
I(DI, SI)
          <+
          \leftarrow ddt(0.5 * CGeff * V(NOIC));
I(GP, SI)
I (GP, DI)
          \leftarrow ddt (0.5 * CGeff * V(NOIC));
```

It is straightforward to verify that this implementation of PSP's noise model in Verilog-A naturally yields the desired correlations and frequency dependence. However, it requires two additional internal nodes.

#### SiMKit C-code

Contrary to the limitation of Verilog-A language, most circuit simulators are able to directly deal with correlated and frequency dependent noise—without the use of additional internal nodes. In order to minimize the simulation time of the model, C-implementations should therefore avoid the use of such internal nodes whenever possible.

In SiMKit, the frequency dependence and correlation of the noise sources indicated in Fig. 6.3 are implemented directly according to Eq. (6.3). The result is therefore equivalent to the verilog-A implementation.

In summary, even though the SiMKit-implementation of the noise model in PSP is different from that in verilog-A (as it does not make use of additional internal nodes) the result of noise noise simulations will be identical.

### 6.5.4 Clip warnings

From SiMKit 3.7 onwards, it is possible to set the level of clip-warning information through the value of the parameter **PARAMCHK**. This functionality is available for most SiMKit models. It is *not* available in the verilog-A version of PSP.

If the value of **PARAMCHK** is

- < 0 All clip warnings are suppressed.
- $\geq 0$  (default) Clip warnings for instance parameters.
- $\geq 1$  Clip warnings for model parameters.
- $\geq 2$  Clip warnings for internally computed local parameters during model initialization.

 $\geq 3$  Clip warnings for internally computed local parameters during model evaluation.

This works in an accumulative manner: if a higher value of **PARAMCHK** is used, the warnings associated with lower levels are still included. Note that the highest level is of interest only for self heating models, where electrical parameters may change dependent on temperature. Hence, it is currently not applicable for PSP. Also note that the default value (0) results in less clip warnings than in earlier versions of the model.

# **Section 7**

## Parameter extraction

The parameter extraction strategy for PSP consists of four main steps:

- 1. Measurements
- 2. Extraction of local parameters at room temperature
- 3. Extraction of temperature scaling parameters
- 4. Extraction of geometry scaling (global) parameters

The above steps will be briefly described in the following sections. Note that the description of the extraction procedure is not 'complete' in the sense that only the most important parameters are discussed and in cases at hand it may be advantageous (or even necessary) to use an adapted procedure.

Throughout this section, bias and current conditions are given for an n-channel transistor only; for a p-channel transistor, all voltages and currents should be multiplied by -1.

As explained in the introduction, the hierarchical setup of PSP (local and global level) allows for the twostep parameter extraction procedure described in this section; this is the recommended method of operation. Nevertheless, it is possible to skip the first steps and start extracting global parameters directly. This procedure is not described here, but the directions below may still be useful.

### 7.1 Measurements

The parameter extraction routine consists of six different DC-measurements (two of which are optional) and two capacitance measurements.<sup>1</sup> Measurement V and VI are only used for extraction of gate-current, avalanche, and GIDL/GISL parameters.

```
• Measurement I ("idvg"): I_{\rm D} vs. V_{\rm GS} V_{\rm GS}=0\ldots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm DS}=25 or 50 mV V_{\rm BS}=0\ldots -V_{\rm sup} (3 or more values)
```

• Measurement II ("idvgh"):  $I_{\rm D}$  vs.  $V_{\rm GS}$   $V_{\rm GS}=0\ldots V_{\rm sup}$  (with steps of maximum 50 mV).  $V_{\rm DS}=V_{\rm sup}$   $V_{\rm BS}=0\ldots -V_{\rm sup}$  (3 or more values)

 $<sup>^1</sup>$ The bias conditions to be used for the measurements are dependent on the supply voltage of the process. Of course it is advisable to restrict the range of voltages to this supply voltage  $V_{\rm sup}$ . Otherwise physical effects atypical for normal transistor operation—and therefore less well described by PSP—may dominate the characteristics.

```
• Measurement III ("idvd"): I_{\rm D} vs. V_{\rm DS} V_{\rm GS}=0\ldots V_{\rm sup} (3 or more values) V_{\rm DS}=0\ldots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm BS}=0 V
```

• Measurement IV ("idvdh", optional): $I_{\rm D}$  vs.  $V_{\rm DS}$   $V_{\rm GS}=0\ldots V_{\rm sup}$  (3 or more values)  $V_{\rm DS}=0\ldots V_{\rm sup}$  (with steps of maximum 50 mV).  $V_{\rm BS}=-V_{\rm sup}$ 

```
• Measurement V ("igvg"): I_{\rm G} and I_{\rm B} vs. V_{\rm GS} V_{\rm GS} = -V_{\rm sup} \dots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm DS} = 0 \dots V_{\rm sup} (3 or more values) V_{\rm BS} = 0 V
```

• Measurement VI ("igvgh", optional):  $I_{\rm G}$  and  $I_{\rm B}$  vs.  $V_{\rm GS}$   $V_{\rm GS} = -V_{\rm sup} \dots V_{\rm sup}$  (with steps of maximum 50 mV).  $V_{\rm DS} = 0 \dots V_{\rm sup}$  (3 or more values)  $V_{\rm BS} = -V_{\rm sup}$ 

```
• Measurement VII ("cggvg"): C_{\rm GG} vs. V_{\rm GS} V_{\rm GS}=-V_{\rm sup}\dots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm DS}=0 V V_{\rm BS}=0 V
```

```
• Measurement VIII ("ccgvg"): C_{\rm CG} vs. V_{\rm GS} V_{\rm GS} = -V_{\rm sup} \dots V_{\rm sup} (with steps of maximum 50 mV). V_{\rm DS} = 0 V V_{\rm BS} = 0 V
```

For the extraction procedure, the transconductance  $g_{\rm m}$  (for Measurement I and II) and the output conductance  $g_{\rm DS}$  (for Measurement III and IV) are obtained by numerical differentiation of the measured I-V-curves. Furthermore,  $I_{\rm min}$  is the smallest current which can reliably measured by the system (noise limit) and  $I_{\rm T}$  is defined as 10% of the largest measured value of  $|I_{\rm D}|$  in Measurement I. The latter will be used to make a rough distinction between the subthreshold and superthreshold region.

The channel-to-gate capacitance  $C_{\rm CG}$  in Measurement VIII is the summation of the drain-to-gate capacitance  $C_{\rm DG}$  and the source-to-gate capacitance  $C_{\rm SG}$  (i.e., source and drain are short-circuited); it is needed to extract overlap capacitance parameters.

The local parameter extraction measurements I through VI have to be performed at room temperature for every device. In addition, capacitance measurements VII and VIII need to be performed for at least a long/wide and a short/wide (i.e.,  $L=L_{\rm min}$ ) transistor (at room temperature). Furthermore, for the extraction of temperature scaling parameters measurements I, III, and V have to be performed at different temperatures (at least two extra, typically  $-40\,^{\circ}{\rm C}$  and  $125\,^{\circ}{\rm C}$ ) for at least a long wide and a short wide transistor.

## 7.2 Extraction of local parameters at room temperature

### General remarks

The simultaneous determination of *all* local parameters for a specific device is not advisable, because the value of some parameters can be wrong due to correlation and suboptimization. Therefore it is more practical to

split the parameters into several small groups, where each parameter group can be determined using specific measurements. In this section, such a procedure will be outlined.

The extraction of local parameters is performed for every device. In order to ensure that the temperature scaling relations do not affect the behavior at room temperature, the reference temperature **TR** should be set equal to room temperature.

Before starting the parameter extraction procedure, one should make sure that **SWIGATE**, **SWIMPACT**, **SWGIDL**, **SWJUNCAP**, and **TYPE** are set to the desired value. Moreover, **QMC** should be set to 1, in order to include quantum mechanical corrections in the simulations.

It is not the case that all local parameters are extracted for every device. Several parameters are only extracted for one or a few devices, while they are kept fixed for all other devices. Moreover, a number of parameters can generally be kept fixed at their default values and need only occasionally be used for fine-tuning in the optimization procedure. Details are given later in this section.

As a special case, it is generally not necessary to extract values for  $\mathbf{AX}$ . In stead, they can be calculated from Eq. (3.57), using  $\mathbf{AXO} \sim 18$  and  $\mathbf{AXL} \sim 0.25$ . It may be necessary to tune the latter value such that the value of  $\mathbf{AX}$  is between 2 and 3 for the shortest channel in the technology under study.

It is recommended to start the extraction procedure with the long(est) wide(st) device, then the shortest device with the same width, followed by all remaining devices of the same width in order of decreasing length. Then the next widest-channel devices are extracted, where the various lengths are handled in the same order. In this way, one works ones way down to the narrowest channel devices.

#### **AC-parameters**

Some parameters (such as **TOX** and **NP**) that do affect the DC-behavior of a MOSFET can only be extracted accurately from C-V-measurements.<sup>2</sup> This should be done before the actual parameter extraction from DC-measurements is started. In Tables 7.1 and 7.2 the extraction procedure for the AC-parameters is given.

Table 7.1: AC-parameter extraction procedure for a long channel MOSFET.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	VFB,NEFF, DPHIB, NP, COX	VII: $C_{\mathrm{GG}}$	Relative	_
2	Repeat Step 1			

Table 7.2: AC-parameter extraction procedure for a short channel MOSFET. The values of **VFB** and **NP** are taken from the long-channel case.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF, DPHIB, COX	VII: $C_{\mathrm{GG}}$	Relative	_
2	CGOV, NOV	VIII: $C_{\rm CG}$	Relative	$V_{\rm GS} < 0$
3	Repeat Steps 1 and 2			

Starting from the default parameter set and setting **TOX** to a reasonable value (as known from technology), **VFB**, **NEFF**, **DPHIB**, **COX**, and **NP** can be extracted from  $C_{GG}$  in Measurement VII for a long, wide device.

Next, **NOV** and **CGOV** can be extracted from  $C_{CG}$  in Measurement VIII for a short, wide device (see also Table 7.1), where **VFB** and **NP** are taken from the long channel case. In general, one can assume **TOXOV** = **TOX**.

The value of **TOX** can be determined from  $\mathbf{COX} = \epsilon_{ox} \cdot L \cdot W/\mathbf{TOX}$ . If the device is sufficiently long and wide, drawn length and width can be used in this formula. Even better, if Measurement VII is available for a

<sup>&</sup>lt;sup>2</sup>Although parameter **NOV** can be determined from overlap gate current, it is nonetheless more accurately determined from Measurement VIII.

Table 7.3: Initial values for local parameter extraction for a *long*-channel device. For parameters which are not listed in this table, the default value (as given in Section 2.5.7) can be used as initial value.

Parameter	Initial value
BETN	$0.03 \cdot W/L$
RS	0
THESAT	0.1
AX	12
A1	0

few short/wide devices of different lengths, one can extract **TOX** and  $\Delta L$  from a series of extracted values of **COX** vs.  $L_{\rm draw}$ .

Some remarks:

- If C-V-measurements are not available, one could revert to values known from the fabrication process. Note that **TOX** and **TOXOV** are *physical* oxide thicknesses; poly-depletion and quantum-mechanical effects are taken care of by the model. If the gate dielectric is not pure SiO<sub>2</sub>, one should manually compensate for the deviating dielectric constant.
- In general, **VFB** and **NP** can be assumed independent of channel length and width (so, the long/wide-channel values can be used for all other devices as well). Only if no satisfactory fits are obtained, one could allow for a length dependence (for **NP**) or length *and* width dependence (for **VFB**). Then, one should proceed by extracting **VFB** and/or **NP** from capacitance measurements for various channel geometries, fit Eq. (3.12) / Eq. (3.27) to the result and use interpolated values in the DC parameter extraction procedure.
- The value of parameter **TOX** profoundly influences both the DC- and AC-behavior of the PSP-model and thus the values of many other parameters. It is therefore very important that this parameter is determined (as described above) and *fixed* before the rest of the extraction procedure is started.

If desired (e.g., for RF-characterization), parameters for several parasitic capacitances (gate-bulk overlap, fringe capacitance, etc.) can be extracted as well (**CGBOV** and **CFR**). However, this requires additional capacitance measurements

The obtained values of VFB, TOX, TOXOV, NP, and NOV can now be used in the DC-parameter extraction procedure. The above values of NEFF and DPHIB can be disregarded; they will be determined more accurately from the DC-measurements.

#### **DC-parameters**

Before the optimization is started a reasonably good starting value has to be determined, both for the parameters to be extracted and for the parameters which remain constant. For most parameters to be extracted for a *long* channel device, the default values from Section 2.5.7 can be taken as initial values. Exceptions are given in Table 7.3. Starting from these values, the optimization procedure following the scheme below is performed. This method yields a proper set of parameters after the repetition indicated as the final step in the scheme. Experiments with transistors of several processes show that repeating those steps more than once is generally not necessary.

For an accurate extraction of parameter values, the parameter set for a long-channel transistor has to be determined first. In the long-channel case most of the mobility related parameters (i.e. MUE and THEMU) and the gate tunneling parameters (GCO, GC2, and GC3) are determined and subsequently fixed for the shorter-channel devices.

Table 7.4: DC-parameter extraction procedure for a long-channel MOSFET. The parameters VFB, TOX, TOXOV, NP, and NOV must be taken from *C-V*-measurements. The optimization is either performed on the absolute or relative deviation between model and measurements, as shown in the table.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF, BETN, MUE, THEMU <sup>a</sup>	$I:I_{\mathrm{D}}$	Absolute	_
2	NEFF, DPHIB, CT	I: $I_{\mathrm{D}}$	Relative	$I_{ m min} < I_{ m D} < I_{ m T}$
3	MUE, THEMU $^a$ , CS, XCOR, BETN	I: $I_{\mathrm{D}}, g_{\mathrm{m}}$	Absolute	_
4	THESAT	III: $I_{ m D}$	Absolute	_
5	$ALP$ , $ALP1$ , $ALP2$ , $VP^a$ , $(AX)$	III: $g_{\mathrm{DS}}$	Relative	_
6	THESAT	$\mathrm{II}$ : $I_{\mathrm{D}}$	Absolute	_
7	$IGINV, GC2^a, GC3^a$	V: <i>I</i> <sub>G</sub>	Relative	$I_{ m G} > I_{ m min}$
8	$IGOV, (GCO^a)$	V: <i>I</i> <sub>G</sub>	Relative	$V_{ m GS} < 0$ V, $I_{ m G} < -I_{ m min}$
9	$A1, A2^a, A3$	V: <i>I</i> <sub>B</sub>	Relative	$V_{\mathrm{GS}} > 0$ V, $I_{\mathrm{B}} < -I_{\mathrm{min}}$
10	A4	$ ext{VI: }I_{ ext{B}}$	Relative	$V_{ m GS}>0$ V, $I_{ m B}<-I_{ m min}$
11	AGIDL, BGIDL <sup>a</sup>	V: <i>I</i> <sub>B</sub>	Relative	$V_{ m GS} < 0$ V, $I_{ m B} < -I_{ m min}$
12	CGIDL <sup>a</sup>	VI: I <sub>B</sub>	Relative	$V_{ m GS} < 0$ V, $I_{ m B} < -I_{ m min}$
13	Repeat Steps 2 – 12			

<sup>&</sup>lt;sup>a</sup>Only extracted for the widest long channel device and fixed for all other geometries.

In Table 7.4 the complete DC extraction procedure for long-channel transistors is given. The magnitude of the simulated  $I_{\rm D}$  and the overall shape of the simulated  $I_{\rm D}$ - $V_{\rm GS}$ -curve is roughly set in Step 1. Next the parameters NEFF, DPHIB, and CT—which are important for the subthreshold behavior—are optimized in Step 2, neglecting short-channel effects such as drain-induced barrier-lowering (DIBL). After that, the mobility parameters are optimized in Step 3, neglecting the influence of series-resistance. In Step 4 a preliminary value of the velocity saturation parameter is obtained, and subsequently the conductance parameters ALP, ALP1, ALP2, and VP are determined in Step 5. A more accurate value of THESAT can now be obtained using Step 6. The gate current parameters are determined in Steps 7 and 8, where it should be noted that GCO should only be extracted if the influence of gate-to-bulk tunneling is visible in the measurements. This is usually the case if  $V_{\rm sup} \gtrsim |{\rm VFB}|$ . This is followed by the weak-avalanche parameters in Step 9 and (optionally) 10, and finally, the gate-induced leakage current parameters are optimized in Step 11 and (optionally) 12.

After completion of the extraction for the long-channel device, it is recommended to first extract parameters for the shortest-channel device (of the same width). The mobility-reduction parameters (MUE, THEMU) and the gate tunneling probability factors (GCO, GC2, GC3) found from the corresponding long-channel device should be used. The extraction procedure as given in Table 7.5 should be used.

Once the value for **RS** has been found from the shortest device, it should be copied into the long-channel parameter set and steps 2–3 (Table 7.4) should be repeated, possibly leading to some readjustment of **MUE** and **THEMU**. If necessary, this procedure must be repeated. Similarly—once the value of **THESATG** and **THESATB** have been determined from the shortest widest channel device—steps 4, 5, and 6 of the long-channel extraction procedure (Table 7.4) must be repeated to obtain updated values for **THESAT**, **ALP**, **ALP1**, and **ALP2**.

If consistent parametersets have been found for the longest and shortest channel device, the extraction procedure as given in Table 7.5 can be executed for all intermediate channel lengths. The extracted parameter values of the next-longer device can be used as initial values.

Table 7.5: DC-parameter extraction procedure for a short-channel MOSFET. Parameters MUE, THEMU, VP, GCO, GC2, GC3, A2, A4, BGIDL, and CGIDL are taken from the corresponding long-channel case. The optimization is either performed on the absolute or relative deviation between model and measurements, as indicated in the table.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	NEFF, DPHIB, BETN, RS <sup>a</sup>	I: $I_{\mathrm{D}}$	Absolute	-
2	NEFF, DPHIB, CT	I: $I_{ m D}$	Relative	$I_{ m min} < I_{ m D} < I_{ m T}$
3	BETN, $RS^a$ , XCOR	I: $I_{\mathrm{D}}, g_{\mathrm{m}}$	Absolute	_
4	THESAT	III: $I_{ m D}$	Absolute	_
5	ALP, ALP1, ALP2, CF, (AX)	III: $g_{\mathrm{DS}}$	Relative	_
6	$\mathbf{CFB}^b$	IV: $g_{\mathrm{DS}}$	Relative	_
7	THESAT, THESATG $^b$ , THESATB $^b$	II: $I_{\mathrm{D}}, g_{\mathrm{m}}$	Absolute	_
8	IGINV, IGOV	$ m V$ : $I_{ m G}$	Relative	$ I_{ m G} >I_{ m min}$
9	A1, A3	$ ext{V:}\ I_{ ext{B}}$	Relative	$V_{ m GS} > 0$ V, $I_{ m B} < -I_{ m min}$
10	AGIDL	$V:I_{ m B}$	Relative	$V_{ m GS} < 0$ V, $I_{ m B} < -I_{ m min}$
11	Repeat Steps 2 – 10			

<sup>&</sup>lt;sup>a</sup>Only extracted for the *shortest* channel of each width and fixed for all other geometries.

Table 7.6: Temperature scaling parameter extraction procedure for a long wide channel MOSFET. This scheme only makes sense if measurements have been performed at one or (preferably) more temperatures which differ from room temperature.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	STVFB <sup>a</sup>	I: $I_{\mathrm{D}}$	Relative	$I_{ m D} < I_{ m T}$
2	STBETN <sup>a</sup> , STMUE, STTHEMU,	I: $I_{\mathrm{D}}$	Absolute	_
	STCS, STXCOR			
3	STTHESAT <sup>a</sup>	II: $I_{ m D}$	Absolute	_
4	STIG	$V:I_{\mathrm{G}}$	Relative	$ I_{ m G} >I_{ m min}$
5	STA2	$V:I_{\mathrm{B}}$	Relative	$V_{ m GS} > 0$ V, $I_{ m B} < -I_{ m min}$
6	STBGIDL	$V:I_{\mathrm{B}}$	Relative	$V_{ m GS} < 0$ V, $I_{ m B} < -I_{ m min}$

<sup>&</sup>lt;sup>a</sup>Also extracted for one or more long *narrow* devices.

### 7.3 Extraction of Temperature Scaling Parameters

For a specific device, the temperature scaling parameters can be extracted after determination of the local parameters at room temperature. In order to do so, measurements I, II and IV need to be performed at various temperature values (at least two values different from room temperature, typically  $-40\,^{\circ}\text{C}$  and  $125\,^{\circ}\text{C}$ ), at least for a long wide device and a short wide device. If the reference temperature **TR** has been chosen equal to room temperature (as recommended in Section 7.2), the modeled behavior at room temperature is insensitive to the value of the temperature scaling parameters. As a first-order estimate of the temperature scaling parameter values, the default values as given in Section 2.5.7 can be used. Again the parameter extraction scheme is slightly different for the long-channel and for the short-channel case.

For an accurate extraction, the temperature scaling parameters for a long-wide-channel device have to be determined first. In the long-wide-channel case the carrier mobility parameters can be determined, and they are

<sup>&</sup>lt;sup>b</sup>Only extracted for the *shortest widest* device and fixed for all other geometries.

Table 7.7: Temperature scaling parameter extraction procedure for short-channel MOSFETs (both wide and narrow). This scheme only makes sense if measurements have been performed at one or (preferably) more temperatures which differ from room temperature.

Step	Optimized parameters	Fitted on	Abs./Rel.	Conditions
1	STVFB	I: $I_{\mathrm{D}}$	Relative	$V_{\rm GS} < V_{ m T}$
2	STBETN, STRS <sup>a</sup>	I: $I_{ m D}$	Absolute	$V_{\rm GS} > V_{ m T}$
3	STTHESAT	$\Pi$ : $I_{ m D}$	Absolute	_

<sup>&</sup>lt;sup>a</sup>Only extracted for a short *narrow* device and fixed for all other geometries.

subsequently fixed for all other devices. In Table 7.6 the appropriate extraction procedure is given. In Step 1 the subthreshold temperature dependence is optimized, followed by the optimization of mobility reduction parameters in Step 2. Next the temperature dependence of velocity saturation is optimized in Step 3. In the subsequent steps, parameters for the temperature dependence of the gate current, the impact ionization current and gate-induced drain leakage are determined. The determined values of the mobility reduction temperature scaling parameters (i.e., **STMUE**, **STTHEMU**, **STCS**, and **STXCOR**) are copied to all other devices and kept fixed during the remainder of the temperature-scaling parameter extraction procedure. Step 1 and 2 could then be performed on one or more long narrow devices as well (for **STVFB**, **STBETN**, and **STTHESAT** only).

Next the extraction procedure as given in Table 7.7 is carried out for several short devices of different widths. Preferably, the extraction is done first for a short narrow device, such that the determined value of **STRS** can be used during the extraction of the wider devices.

### 7.4 Extraction of Geometry Scaling Parameters

The aim of the complete extraction procedure is the determination of the geometry scaling parameters (global parameters), i.e., a single set of parameters (see Section 2.5.3) which gives a good description of the MOSFET-behavior over the full geometry range of a CMOS technology.

#### Determination of $\Delta L$ and $\Delta W$

An extremely important part of the geometry scaling extraction scheme is an accurate determination of  $\Delta L$  and  $\Delta W$ , see Eqs. (3.6) and (3.7).<sup>3</sup> Since it affects the DC-, the AC- as well as the noise model and, moreover, it can heavily influence the quality of the resulting global parameter set, it is very important that this step is carried out with care.

Traditionally,  $\Delta W$  can be determined from the extrapolated zero-crossing in **BETN** versus mask width W. In a similar way  $\Delta L$  can be determined from 1/BETN versus mask length L. For modern MOS devices with pocket implants, however, it has been found that the above  $\Delta L$  extraction method is no longer valid [11, 12]. Another, more accurate method is to measure the gate-to-bulk capacitance  $C_{\text{GB}}$  in accumulation for different channel lengths [12, 13]. In this case the extrapolated zero-crossing in the  $C_{\text{GB}}$  versus mask length L curve will give  $\Delta L$ . Similarly, the extracted values for **COX** (from the procedure in Table 7.1 and 7.2) vs. mask length L may be used for this purpose. Unfortunately for CMOS technologies in which gate current is non-negligible, capacitance measurements may be hampered by gate current [14]. In this case gate current parameter **IGINV** plotted as a function of channel length L may be used to extract  $\Delta L$  [14]. If possible,  $\Delta L$  extraction from C-V-measurements is the preferred method.

Finally, LOV can be obtained from (a series of) extracted values of CGOV from one or more short devices.

 $<sup>^3</sup>$ Note that  $\Delta L_{\rm PS}$  and  $\Delta W_{\rm OD}$  are expected to be known from the fabrication process. So, in fact, only **LAP** and **WOT** are extracted from the electrical measurements.

#### From local to global

First of all, the global parameters **TYPE**, **QMC**, and the 'switch'-parameters should be set to the appropriate value. Next, parameters for which no geometrical scaling rules exist must be taken directly from the local set (this applies to **TR**, **TOXO**, **VNSUBO**, **NSLPO**, **DNSUBO**, **TOXOVO**, **NOVO**, **CFBO**, **STMUEO**, **THE-MUO**, **STTHEMUO**, **STCSO**, **STXCORO**, **FETAO**, **STRSO**, **RSBO**, **RSGO**, **THESATBO**, **THESATGO**, **VPO**, **A2O**, **STA2O**, **GCOO**, **STIGO**, **GC2O**, **GC3O**, **CHIBO**, **BGIDLO**, **STBGIDLO**, **CGIDLO**, and **DTA**). Generally, these parameters have been left at their default values or they have been extracted for one device only and subsequently fixed for all other devices. The parameters **LVARO**, **LVARL**, **LVARW**, **WVARO**, **WVARL**, and **WVARW** should be known from technology.

Once the values of  $\Delta L$  and  $\Delta W$  are firmly established (as described above), **LAP** and **WOT** can be set and the actual extraction procedure of the geometry scaling parameters can be started. It consists of several *independent* sub-steps (which can be carried out in random order), one for each geometry dependent local parameter.

To illustrate such a sub-step, the local parameter  $\mathbf{CT}$  is taken as an example. The relevant geometry scaling equation from Section 3.2 is Eq. (3.28), from which it can be seen that  $\mathbf{CTO}$ ,  $\mathbf{CTL}$ ,  $\mathbf{CTLEXP}$ , and  $\mathbf{CTW}$  are the global parameters which determine the value of  $\mathbf{CT}$  as a function of L and W. First, the extracted  $\mathbf{CT}$  of each device in a length-series of measured (preferably wide) devices are considered as a function of L. In this context  $\mathbf{CTO}$ ,  $\mathbf{CTL}$ , and  $\mathbf{CTLEXP}$  are optimized such that the fit of Eq. (3.28) to the extracted  $\mathbf{CT}$ -values is as good as possible, while keeping  $\mathbf{CTW}$  fixed at 0. Then  $\mathbf{CTW}$  is determined by considering the extracted  $\mathbf{CT}$ -values from a length-series of measured narrow devices. Finally, the four global parameters may be fine-tuned by optimizing all four parameters to all extracted  $\mathbf{CT}$ -values simultaneously. The default values given in Section 2.5.3 are good initial values for the optimization procedure.

All other parameters can be extracted in a similar manner. The local parameters **BETN** and **NEFF** have quite complicated scaling rules, particularly due to the non-uniform doping profiles employed in modern CMOS technologies. Therefore, a few additional guidelines are in place.

- The optimization procedure for **BETN** is facilitated if not **BETN**, but **BETN**<sub>sq</sub>  $\stackrel{\text{def}}{=}$  **BETN**  $\cdot$   $L_{\text{E}}/W_{\text{E}}$  is considered.
- Starting from the default values, first UO, FBET1, LP1, FBET2, and LP2 should be determined from a
  length-series of wide devices. Then BETW1, BETW2, and WBET should be determined from a widthseries of long devices. Finally, FBET1W and LP1W can be found by considering some short narrow
  devices.
- Starting from the default values, first extract FOL1, FOL2, NSUBO, NPCK, and LPCK from a length-series of wide devices. Here, NSUBO determines the long-channel value of NEFF. Moreover, NPCK and LPCK determine the increase of NEFF for shorter channels (reverse short channel effect), while FOL1 and FOL2 are used to describe the decrease of NEFF for very short channels (short channel effect).
- Then NSUBW and WSEG can be determined form a width-series of long devices. Finally, NPCKW,
   LPCKW and WEGP are determined from a width-series of short devices.
- Especially for **BETN** and **NEFF** it is advisable—after completing the procedure described above—to fine tune the global parameters found by considering all extracted values of **BETN** (or **NEFF**) simultaneously.

Note that in many cases it may not be necessary to use the full flexibility of PSP's parameter scaling, e.g., for many technologies **NP** and **VFB** may be considered as independent of geometry. If such a geometry-independence is anticipated, the corresponding local parameter should be fixed during local parameter extraction. Only if the resulting global parameter set is not satisfactory, the parameter should be allowed to vary during a subsequent optimization round.

### Fine tuning

Once the complete set of global parameters is found, the global model should give an accurate description of the measured I-V-curves and capacitance measurements. Either for fine tuning or to facilitate the extraction

of global parameters for which the geometry scaling of the corresponding extracted local parameters is not well-behaved, there are two more things that can be done.

- Local parameters for which the fitting of global parameters was completed satisfactorily could be replaced by the values calculated from the geometrical scaling rules and fixed. Then one could redo (parts of) the local parameter extraction procedure for the remaining local parameters, making them less sensitive for cross-correlations.
- Small groups of global parameters may be fitted directly to the measurements of a well-chosen series of devices, using the global model.

### 7.5 Summary – Geometrical scaling

Summarizing, for the determination of a full parameter set, the following procedure is recommended.

- 1. Determine local parameter sets (VFB, NEFF, ...) for all measured devices, as explained in Section 7.2 and 7.3.
- 2. Find  $\Delta L$  and  $\Delta W$ .
- 3. Determine the global parameters by fitting the appropriate geometry scaling rules to the extracted local parameters.
- 4. Finally, the resulting global can be fine-tuned, by fitting the result of the scaling rules and current equations to the measured currents of all devices simultaneously.

### 7.6 Extraction of Binning Parameters

In this section, expressions will be given for the parameters in the binning scaling rules, **POYYY**, **PLYYY**, **PWYYY**, and **PLWYYY**, as given in Section 3.3. These coefficients will be expressed in terms of parameter values at the corners of bin (see Fig. 7.1). These expressions can be easily found by substituting the parameter values at the bin corners into the binning scaling rules and inverting the resulting four equations. Note once

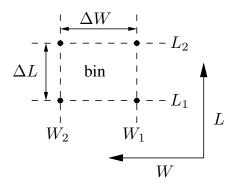


Figure 7.1: Schematic view of a bin, showing the coordinates of the four corners. Note that  $L_1$ ,  $L_2$ ,  $W_1$ , and  $W_2$  denote the *effective* length and width ( $L_E$  and  $W_E$ ) at the bin corners.

more that this results in a separate parameter set for each bin.

In the expression below, the value of parameter YYY at bin corner  $(L_i, W_j)$  is denoted by  $Y_{ij}$  (i=1,2, j=1,2). Moreover,  $\Delta L = L_2 - L_1$ ,  $\Delta W = W_2 - W_1$ ,  $A = 1/(\Delta L \cdot \Delta W)$ .

1. Coefficients for type I scaling

$$\mathbf{POYYY} = A \cdot (L_1 \cdot W_1 \cdot Y_{11} - L_1 \cdot W_2 \cdot Y_{12} - L_2 \cdot W_1 \cdot Y_{21} + L_2 \cdot W_2 \cdot Y_{22})$$
(7.1)

$$\mathbf{PLYYY} = A \cdot \frac{L_1 \cdot L_2}{L_{\text{EN}}} \cdot \left( -W_1 \cdot Y_{11} + W_2 \cdot Y_{12} + W_1 \cdot Y_{21} - W_2 \cdot Y_{22} \right)$$
(7.2)

$$\mathbf{PWYYY} = A \cdot \frac{W_1 \cdot W_2}{W_{\text{EN}}} \cdot \left( -L_1 \cdot Y_{11} + L_1 \cdot Y_{12} + L_2 \cdot Y_{21} - L_2 \cdot Y_{22} \right)$$
(7.3)

$$\mathbf{PLWYYY} = A \cdot \frac{L_1 \cdot L_2 \cdot W_1 \cdot W_2}{L_{\text{EN}} \cdot W_{\text{EN}}} \cdot (Y_{11} - Y_{12} - Y_{21} + Y_{22})$$
 (7.4)

#### 2. Coefficients for type II scaling

$$\mathbf{POYYY} = A \cdot (L_2 \cdot W_2 \cdot Y_{11} - L_2 \cdot W_1 \cdot Y_{12} - L_1 \cdot W_2 \cdot Y_{21} + L_1 \cdot W_1 \cdot Y_{22})$$
(7.5)

$$\mathbf{PLYYY} = A \cdot L_{\text{EN}} \cdot (-W_2 \cdot Y_{11} + W_1 \cdot Y_{12} + W_2 \cdot Y_{21} - W_1 \cdot Y_{22}) \tag{7.6}$$

$$\mathbf{PWYYY} = A \cdot W_{\text{EN}} \cdot (-L_2 \cdot Y_{11} + L_2 \cdot Y_{12} + L_1 \cdot Y_{21} - L_1 \cdot Y_{22}) \tag{7.7}$$

$$PLWYYY = A \cdot L_{EN} \cdot W_{EN} \cdot (Y_{11} - Y_{12} - Y_{21} + Y_{22})$$
(7.8)

### 3. Coefficients for type III scaling

$$\mathbf{POYYY} = A \cdot (-L_1 \cdot W_2 \cdot Y_{11} + L_1 \cdot W_1 \cdot Y_{12} + L_2 \cdot W_2 \cdot Y_{21} - L_2 \cdot W_1 \cdot Y_{22}) \tag{7.9}$$

$$\mathbf{PLYYY} = A \cdot \frac{L_1 \cdot L_2}{L_{\text{EN}}} \cdot (W_2 \cdot Y_{11} - W_1 \cdot Y_{12} - W_2 \cdot Y_{21} + W_1 \cdot Y_{22})$$
(7.10)

$$\mathbf{PWYYY} = A \cdot W_{\text{EN}} \cdot (L_1 \cdot Y_{11} - L_1 \cdot Y_{12} - L_2 \cdot Y_{21} + L_2 \cdot Y_{22})$$
 (7.11)

$$\mathbf{PLWYYY} = A \cdot \frac{L_1 \cdot L_2 \cdot W_{\text{EN}}}{L_{\text{EN}}} \cdot (-Y_{11} + Y_{12} + Y_{21} - Y_{22})$$
(7.12)

**Note:** For  $L_1$ ,  $L_2$ ,  $W_1$ , and  $W_2$  in the formulas above one must take the *effective* length and width ( $L_{\rm E}$  and  $W_{\rm E}$ ) as defined in Section 3.2.

## **Section 8**

# **DC Operating Point Output**

The DC operating point output facility gives information on the state of a device at its operation point. Beside terminal currents and voltages, the magnitudes of linearized internal elements are given. In some cases meaningful quantities can be derived which are then also given (e.g.,  $f_{\rm T}$ ). The objective of the DC operating point facility is twofold:

- Calculate small-signal equivalent circuit element values
- Open a window on the internal bias conditions of the device and its basic capabilities.

All accessible quantities are described in the table below. The symbols in the 'value' column are defined in Section 4. Besides, the following notation is used:  $P_D = 1 + k_p \cdot G/4$ , where  $k_p$  is defined in Eq. (4.16).

**Important note:** For *all* operating point output the signs are such as if the device is an NMOS. Moreover, whenever there is a reference to the 'drain', this is always the terminal which is acting as drain for the actual bias conditions. This is even true for variables such as **vds** (which is therefore always nonnegative) and the junction-related variables. The output variable **sdint** shows whether or not this 'drain' is the same as the terminal which was named 'drain' in the simulator.

No.	Name	Unit	Value	Description	
0	ctype	_	1 for NMOS, -1 for PMOS	Flag for channel-type	
1	sdint	-	$1 \text{ if } V'_{DS} \ge 0, -1 \text{ otherwise}$	Flag for source-drain interchange	
	Current components				
2	ise	A	$I_{ m S}-I_{ m JS}$	Total source current	
3	ige	A	$I_{ m G}$	Total gate current	
4	ide	A	$I_{ m D}-I_{ m JD}$	Total drain current	
5	ibe	A	$I_{ m B}+I_{ m JS}+I_{ m JD}$	Total bulk current	
6	ids	A	$I_{ m DS}$	Drain current, excl. avalanche and tunnel currents	
7	idb	A	$I_{ m avl} + I_{ m gidl} - I_{ m JD}$	Drain-to-bulk current	
8	isb	A	$I_{ m gisl}-I_{ m JS}$	Source-to-bulk current	
9	igs	A	$I_{ m GCS} + I_{ m GSov}$	Gate-source tunneling current	
10	igd	A	$I_{ m GCD} + I_{ m GDov}$	Gate-drain tunneling current	
11	igb	A	$I_{ m GB}$	Gate-bulk tunneling current	

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No.	Name	Unit	Value	Description
12	igcs	A	$I_{ m GCS}$	Gate-channel tunneling current (source component)
13	igcd	A	$I_{ m GCD}$	Gate-channel tunneling current (drain component)
14	iavl	A	$I_{ m avl}$	Substrate current due to weak-avalanche
15	igisl	A	$I_{ m gisl}$	Gate-induced source leakage current
16	igidl	A	$I_{ m gidl}$	Gate-induced drain leakage current
			Junction currents	
17	ijs	A	$I_{ m JS}$	Total source junction current
18	ijsbot	A	$I_{ m JS,bot}$	Source junction current, bottom component
19	ijsgat	A	$I_{ m JS,gat}$	Source junction current, gate-edge component
20	ijssti	A	$I_{ m JS,sti}$	Source junction current, STI-edge component
21	ijd	A	$I_{ m JD}$	Total drain junction current
22	ijdbot	A	$I_{ m JD,bot}$	Drain junction current, bottom component
23	ijdgat	A	$I_{ m JD,gat}$	Drain junction current, gate-edge component
24	ijdsti	A	$I_{ m JD,sti}$	Drain junction current, STI-edge component
		1	Voltages	
25	vds	V	$V_{ m DS}$	Drain-source voltage
26	vgs	V	$V_{ m GS}$	Gate-source voltage
27	vsb	V	$V_{ m SB}$	Source-bulk voltage
28	vto	V	$ \frac{\mathbf{VFB} + P_{\mathbf{D}} \cdot (\boldsymbol{\phi_{\mathbf{B}}} + 2 \cdot \boldsymbol{\phi_{\mathbf{T}}^*}) + G \cdot }{\sqrt{\boldsymbol{\phi_{\mathbf{T}}^*} \cdot (\boldsymbol{\phi_{\mathbf{B}}} + 2 \cdot \boldsymbol{\phi_{\mathbf{T}}^*})}} $	Zero-bias threshold voltage
29	vts	V	$ \begin{aligned} \mathbf{VFB} + P_{\mathrm{D}} \cdot (V_{\mathrm{SB}}^* + \boldsymbol{\phi_{\mathbf{B}}} + 2 \cdot \boldsymbol{\phi_{\mathbf{T}}^*}) - V_{\mathrm{SB}}^* + \\ G \cdot \sqrt{\boldsymbol{\phi_{\mathbf{T}}^*} \cdot (V_{\mathrm{SB}}^* + \boldsymbol{\phi_{\mathbf{B}}} + 2 \cdot \boldsymbol{\phi_{\mathbf{T}}^*})} \end{aligned} $	Threshold voltage including backbias effects
30	vth	V	$ ext{vts} - \Delta V_{ ext{G}}$	Threshold voltage including backbias and drain-bias effects
31	vgt	V	vgs — vth	Effective gate drive voltage including drain- and back-bias effects
32	vdss	V	$V_{ m dsat}$	Drain saturation voltage at actual bias
33	vsat	V	$V_{ m DS} - V_{ m dsat}$	Saturation limit
		•	(Trans-)conductances	
34	gm	A/V	$\partial {f ide}/\partial V_{ m GS}$	Transconductance
35	gmb	A/V	$-\partial {f ide}/\partial V_{ m SB}$	Substrate-transconductance

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No.	Name	Unit	Value	Description			
36	gds	A/V	$\partial {f ide}/\partial V_{ m DS}$	Output conductance			
37	gjs	A/V	$-\partial \mathbf{ijs}/\partial V_{\mathrm{SB}}$	Source junction conductance			
38	gjd	A/V	$-(\partial \mathbf{ijd}/\partial V_{\mathrm{DS}} + \partial \mathbf{ijd}/\partial V_{\mathrm{SB}})$	Drain junction conductance			
			Capacitances				
39	cdd	F	$\partial Q_{ m D}^{(i)}/\partial V_{ m DS}$	Drain capacitance			
40	cdg	F	$-\partial Q_{ m D}^{(i)}/\partial V_{ m GS}$	Drain-gate capacitance			
41	cds	F	cdd – cdg – cdb	Drain-source capacitance			
42	cdb	F	$\partial Q_{ m D}^{(i)}/\partial V_{ m SB}$	Drain-bulk capacitance			
43	cgd	F	$-\partial Q_{ m G}^{(i)}/\partial V_{ m DS}$	Gate-drain capacitance			
44	cgg	F	$\partial Q_{ m G}^{(i)}/\partial V_{ m GS}$	Gate capacitance			
45	cgs	F	cgg - cgd - cgb	Gate-source capacitance			
46	cgb	F	$\partial Q_{ m G}^{(i)}/\partial V_{ m SB}$	Gate-bulk capacitance			
47	csd	F	$-\partial Q_{ m S}^{(i)}/\partial V_{ m DS}$	Source-drain capacitance			
48	csg	F	$-\partial Q_{ m S}^{(i)}/\partial V_{ m GS}$	Source-gate capacitance			
49	css	F	csg + csd + csb	Source capacitance			
50	csb	F	$\partial Q_{ m S}^{(i)}/\partial V_{ m SB}$	Source-bulk capacitance			
51	cbd	F	$-\partial Q_{ m B}^{(i)}/\partial V_{ m DS}$	Bulk-drain capacitance			
52	cbg	F	$-\partial Q_{ m B}^{(i)}/\partial V_{ m GS}$	Bulk-gate capacitance			
53	cbs	F	cbb - cbd - cbg	Bulk-source capacitance			
54	cbb	F	$-\partial Q_{ m B}^{(i)}/\partial V_{ m SB}$	Bulk capacitance			
55	cgsol	F	$\partial (Q_{ m sov} + Q_{ m ofs})/\partial V_{ m GS}$	Total gate-source overlap capacitance			
56	cgdol	F	$\partial (Q_{ m dov} + Q_{ m ofd})/\partial V_{ m DS}$	Total gate-drain overlap capacitance			
			Junction capacitances				
57	cjs	F	$C_{ m JS}$	Total source junction capacitance			
58	cjsbot	F	$C_{ m JS, bot}$	Source junction capacitance, bottom component			
59	cjsgat	F	$C_{ m JS,gat}$	Source junction capacitance, gate- edge component			
60	cjssti	F	$C_{ m JS,sti}$	Source junction capacitance, STI-edge component			
61	cjd	F	$C_{ m JD}$	Total drain junction capacitance			
62	cjdbot	F	$C_{ m JD,bot}$	Drain junction capacitance, bottom component			
63	cjdgat	F	$C_{ m JD,gat}$	Drain junction capacitance, gate- edge component			
64	cjdsti	F	$C_{ m JD,sti}$	Drain junction capacitance, STI-edge component			

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No.	Name	Unit	Value	Description		
		1	Miscellaneous			
65	weff	m	$W_{ m E}$	Effective channel width for geometrical models		
66	leff	m	$L_{ m E}$	Effective channel length for geometrical models		
67	u	-	gm/gds	Transistor gain		
68	rout	Ω	1/ <b>gds</b>	Small-signal output resistance		
69	vearly	V	ide /gds	Equivalent Early voltage		
70	beff	A/V <sup>2</sup>	$2 \cdot  \mathbf{ide} /\mathbf{vgt}^2$	Gain factor		
71	fug	Hz	$\mathbf{gm}/[2 \cdot \pi \cdot (\mathbf{cgg} + \mathbf{cgsol} + \mathbf{cgdol})]$	Unity gain frequency at actual bias		
72	rg	Ω	RG	Gate resistance		
			Noise	·		
73	sfl	$A^2/Hz$	$S_{ m fl}(1~{ m Hz})$	Flicker noise current spectral density at 1 Hz		
74	sqrtsff	V/√Hz	$\sqrt{S_{ m fl}(1~{ m kHz})}/{ m gm}$	Input-referred RMS white noise voltage spectral density at 1 kHz		
75	sqrtsfw	V/√Hz	$\sqrt{S_{ m id}}/{ m gm}$	Input-referred RMS white noise voltage spectral density		
76	sid	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m id}$	Channel thermal noise current spectral density		
77	sig	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m ig}(1~{ m kHz})$	Induced gate noise current spectral density at 1 kHz		
78	cigid	_	$\frac{m_{\rm igid}}{\sqrt{m_{\rm ig} \cdot m_{\rm id}}}$	Imaginary part of correlation coefficient between $S_{\rm ig}$ and $S_{\rm id}$		
79	fknee	Hz	$1  ext{Hz} \cdot S_{ ext{fl}}(1  ext{Hz})/S_{ ext{id}}$	Cross-over frequency above which white noise is dominant		
80	sigs	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m igs}$	Gate-source current noise spectral density		
81	sigd	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m igd}$	Gate-drain current noise spectral density		
82	siavl	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m avl}$	Impact ionization current noise spectral density		
83	ssi	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m S,I}$	Total source junction current noise spectral density		
84	sdi	$\mathrm{A}^2/\mathrm{Hz}$	$S_{ m D,I}$	Total drain junction current noise spectral density		

From PSP 102.4 onwards, the values of local parameters are provided in the operating point output. They are listed in the table below.

No.	Name	Unit	Description	
			Process Parameters	
0	lp_vfb	V	Local parameter VFB after T-scaling and clipping	
1	lp_stvfb	V/K	Local parameter STVFB after clipping	
2	lp_tox	m	Local parameter TOX after clipping	
3	lp_epsrox	_	Local parameter <b>EPSROX</b> after clipping	
4	lp_neff	$\mathrm{m}^{-3}$	Local parameter NEFF after clipping	
5	lp_vnsub	V	Local parameter VNSUB after clipping	
6	lp_nslp	V	Local parameter NSLP after clipping	
7	lp_dnsub	$V^{-1}$	Local parameter <b>DNSUB</b> after clipping	
8	lp_dphib	V	Local parameter <b>DPHIB</b> after clipping	
9	lp_np	$m^{-3}$	Local parameter NP after clipping	
10	lp_ct	-	Local parameter CT after clipping	
11	lp_toxov	m	Local parameter TOXOV after clipping	
12	lp_toxovd	m	Local parameter TOXOVD after clipping	
13	lp_nov	${\rm m}^{-3}$	Local parameter NOV after clipping	
14	lp_novd	${\rm m}^{-3}$	Local parameter NOVD after clipping	
			DIBL Parameters	
15	lp_cf	_	Local parameter CF after clipping	
16	lp_cfb	$V^{-1}$	Local parameter CFB after clipping	
			Mobility Parameters	
17	lp_betn	m <sup>2</sup> /V/s	Local parameter <b>BETN</b> after T-scaling and clipping	
18	lp_stbet	-	Local parameter STBET after clipping	
19	lp_mue	m/V	Local parameter MUE after T-scaling and clipping	
20	lp_stmue	_	Local parameter STMUE after clipping	
21	lp_themu	_	Local parameter THEMU after T-scaling and clipping	
22	lp_stthemu	_	Local parameter STTHEMU after clipping	
23	lp_cs	_	Local parameter CS after T-scaling and clipping	
24	lp_stcs	_	Local parameter STCS after clipping	
25	lp_xcor	$V^{-1}$	Local parameter <b>XCOR</b> after T-scaling and clipping	
26	lp_stxcor	_	Local parameter STXCOR after clipping	
27	lp_feta	_	Local parameter FETA after clipping	
Series Resistance Parameters				
28	lp_rs	Ω	Local parameter <b>RS</b> after T-scaling and clipping	
29	lp_strs	-	Local parameter STRS after clipping	
30	lp_rsb	$V^{-1}$	Local parameter RSB after clipping	
31	lp_rsg	$V^{-1}$	Local parameter <b>RSG</b> after clipping	
Velocity Saturation Parameters				
32	lp_thesat	$V^{-1}$	Local parameter <b>THESAT</b> after T-scaling and clipping	

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No.	Name	Unit	Description			
33	lp_stthesat	ı	Local parameter STTHESAT after clipping			
34	lp_thesatb	$V^{-1}$	Local parameter THESATB after clipping			
35	lp_thesatg	$V^{-1}$	Local parameter THESATG after clipping			
			Saturation Voltage Parameters			
36	lp_ax	_	Local parameter AX after clipping			
		Ch	nannel Length Modulation (CLM) Parameters			
37	lp_alp	_	Local parameter ALP after clipping			
38	lp_alp1	V	Local parameter ALP1 after clipping			
39	lp_alp2	$V^{-1}$	Local parameter ALP2 after clipping			
40	lp_vp	V	Local parameter VP after clipping			
Impact Ionization (II) Parameters						
41	lp_a1	_	Local parameter A1 after clipping			
42	lp_a2	V	Local parameter A2 after T-scaling and clipping			
43	lp_sta2	-	Local parameter STA2 after clipping			
44	lp_a3	ı	Local parameter A3 after clipping			
45	lp_a4	$1/\sqrt{V}$	Local parameter A4 after clipping			
			Gate Current Parameters			
46	lp_gco	-	Local parameter GCO after clipping			
47	lp_iginv	A	Local parameter IGINV after T-scaling and clipping			
48	lp_igov	A	Local parameter IGOV after T-scaling and clipping			
49	lp_igovd	A	Local parameter IGOVD after T-scaling and clipping			
50	lp_stig	ı	Local parameter STIG after clipping			
51	lp_gc2	-	Local parameter GC2 after clipping			
52	lp_gc3	_	Local parameter GC3 after clipping			
53	lp_chib	V	Local parameter CHIB after clipping			
			Gate-Induced Drain Leakage Parameters			
54	lp_agidl	$A/V^3$	Local parameter AGIDL after clipping			
55	lp_agidld	A/V <sup>3</sup>	Local parameter AGIDLD after clipping			
56	lp_bgidl	V	Local parameter <b>BGIDL</b> after T-scaling and clipping			
57	lp_bgidld	V	Local parameter <b>BGIDLD</b> after T-scaling and clipping			
58	lp_stbgidl	V/K	Local parameter STBGIDL after clipping			
59	lp_stbgidld	V/K	Local parameter STBGIDLD after clipping			
60	lp_cgidl	_	Local parameter CGIDL after clipping			
61	lp_cgidld	_	Local parameter CGIDLD after clipping			
Charge Model Parameters						
62	lp_cox	F	Local parameter COX after clipping			
63	lp_cgov	F	Local parameter CGOV after clipping			
64	lp_cgovd	F	Local parameter CGOVD after clipping			
65	lp_cgbov	F	Local parameter CGBOV after clipping			

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No.	Name	Unit	Description
66	lp_cfr	F	Local parameter CFR after clipping
67	lp_cfrd	F	Local parameter CFRD after clipping
			Noise Model Parameters
68	lp_fnt	_	Local parameter FNT after clipping
69	lp_ntexc	_	Local parameter NTEXC after clipping
70	lp_nfa	1/V/m <sup>4</sup>	Local parameter NFA after clipping
71	lp_nfb	1/V/m <sup>2</sup>	Local parameter NFB after clipping
72	lp_nfc	$V^{-1}$	Local parameter NFC after clipping
73	lp_ef	_	Local parameter EF after clipping
			Parasitic Resistance Parameters
74	lp_rg	Ω	Local parameter RG after clipping
75	lp_rbulk	Ω	Local parameter RBULK after clipping
76	lp_rwell	Ω	Local parameter RWELL after clipping
77	lp_rjuns	Ω	Local parameter <b>RJUNS</b> after clipping
78	lp_rjund	Ω	Local parameter <b>RJUND</b> after clipping
			Junction Parameters
79	cjosbot	F	Bottom component of total zero-bias source junction capacitance at device temperature
80	cjossti	F	STI-edge component of total zero-bias source junction capacitance at device temperature
81	cjosgat	F	Gate-edge component of total zero-bias source junction capacitance at device temperature
82	vbisbot	V	Built-in voltage of source-side bottom junction at device temperature
83	vbissti	V	Built-in voltage of source-side STI-edge junction at device temperature
84	vbisgat	V	Built-in voltage of source-side gate-edge junction at device temperature
85	idsatsbot	A	Total source-side bottom junction saturation current
86	idsatssti	A	Total source-side STI-edge junction saturation current
87	idsatsgat	A	Total source-side gate-edge junction saturation current
88	cjosbotd	F	Bottom component of total zero-bias drain junction capacitance at device temperature
89	cjosstid	F	STI-edge component of total zero-bias drain junction capacitance at device temperature
90	cjosgatd	F	Gate-edge component of total zero-bias drain junction capacitance at device temperature
91	vbisbotd	V	Built-in voltage of drain-side bottom junction at device temperature
92	vbisstid	V	Built-in voltage of drain-side STI-edge junction at device temperature
93	vbisgatd	V	Built-in voltage of drain-side gate-edge junction at device temperature
94	idsatsbotd	A	Total drain-side bottom junction saturation current
95	idsatsstid	A	Total drain-side STI-edge junction saturation current
96	idsatsgatd	A	Total drain-side gate-edge junction saturation current

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# Appendix A

# **Auxiliary Equations**

In this Appendix, some auxiliary functions which are used in the model equations are defined.

The MINA-smoothing function:

MINA 
$$(x, y, a) = \frac{1}{2} \cdot \left[ x + y - \sqrt{(x - y)^2 + a} \right]$$
 (A.1)

The MAXA-smoothing function:

MAXA 
$$(x, y, a) = \frac{1}{2} \cdot \left[ x + y + \sqrt{(x - y)^2 + a} \right]$$
 (A.2)

The functions  $\chi(y)$ , its derivatives,  $\sigma_1$ , and  $\sigma_2$ , which are used in the explicit approximation of surface potential:

$$\chi(y) = \frac{y^2}{2 + y^2} \tag{A.3}$$

$$\chi'(y) = \frac{4y}{(2+y^2)^2} \tag{A.4}$$

$$\chi''(y) = \frac{8 - 12y^2}{(2 + y^2)^3} \tag{A.5}$$

$$\nu = a + c \tag{A.6}$$

$$\mu_1 = \frac{v^2}{\tau} + \frac{c^2}{2} - a \tag{A.7}$$

$$\sigma_1(a, c, \tau, \eta) = \frac{a \cdot \nu}{\mu_1 + (c^2/3 - a) \cdot c \cdot \nu/\mu_1} + \eta$$
(A.8)

$$\mu_2 = \frac{v^2}{\tau} + \frac{c^2}{2} - a \cdot b \tag{A.9}$$

$$\sigma_2(a, b, c, \tau, \eta) = \frac{a \cdot \nu}{\mu_2 + (c^2/3 - a \cdot b) \cdot c \cdot \nu/\mu_2} + \eta$$
(A.10)

# Appendix B

# Layout parameter calculation

In post-layout simulations, various PSP instance parameters should be supplied either manually or by a layout extraction tool. In this appendix, it is shown how these parameters should be calculated.

Note: These equations are *not* part of the PSP model.

### **B.1** Stress parameters

### **B.1.1** Layout effects for irregular shapes

For irregular shapes the following effective values for SA and SB are to be used (see Fig B.1).

$$\frac{1}{\mathbf{S}\mathbf{A}_{\text{eff}} + 0.5 \cdot L} = \sum_{i=1}^{n} \frac{\mathbf{S}\mathbf{W}_{i}}{W} \cdot \frac{1}{\mathbf{S}\mathbf{A}_{i} + 0.5 \cdot L}$$
(B.1)

$$\frac{1}{\mathbf{SB}_{\text{eff}} + 0.5 \cdot L} = \sum_{i=1}^{n} \frac{\mathbf{SW}_i}{W} \cdot \frac{1}{\mathbf{SB}_i + 0.5 \cdot L}$$
(B.2)

## **B.2** Well proximity effect parameters

The values of the instance parameters **SCA**, **SCB** and **SCC** can be calculated from layout parameters using the equations below.

$$f_{\mathcal{A}}(u) = \frac{\mathbf{SCREF}^2}{u^2} \tag{B.3}$$

$$f_{\rm B}(u) = \frac{u}{\text{SCREF}} \cdot \exp\left(-10 \cdot \frac{u}{\text{SCREF}}\right)$$
 (B.4)

$$f_{\rm C}(u) = \frac{u}{\text{SCREF}} \cdot \exp\left(-20 \cdot \frac{u}{\text{SCREF}}\right)$$
 (B.5)

$$A_{\text{corner}} = \sum_{i=m+1}^{m+k} \left( \frac{L}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + W} f_{\mathbf{A}}(u) \, \mathrm{d}u \right)$$

$$+ \sum_{i=n+1}^{n+k} \left( \frac{W}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + L} f_{\text{A}}(u) \, du \right) \quad (B.6)$$

$$B_{\text{corner}} = \sum_{i=m+1}^{m+k} \left( \frac{L}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + W} f_{\text{B}}(u) \, du \right) + \sum_{i=n+1}^{n+k} \left( \frac{W}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i + L}^{\text{SCX}_i + \text{SCY}_i + L} f_{\text{B}}(u) \, du \right)$$
(B.7)

$$C_{\text{corner}} = \sum_{i=m+1}^{m+k} \left( \frac{L}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i}^{\text{SCX}_i + \text{SCY}_i + W} f_{\text{C}}(u) \, du \right) + \sum_{i=n+1}^{n+k} \left( \frac{W}{2} \cdot \int_{\text{SCX}_i + \text{SCY}_i + L}^{\text{SCX}_i + \text{SCY}_i + L} f_{\text{C}}(u) \, du \right)$$
(B.8)

$$\mathbf{SCA} = \frac{1}{W \cdot L} \cdot \left[ \sum_{i=1}^{n} \left( W_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + L} f_{\mathrm{A}}(u) \, \mathrm{d}u \right) + \sum_{i=n+1}^{n+m} \left( L_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + W} f_{\mathrm{A}}(u) \, \mathrm{d}u \right) + A_{\mathrm{corner}} \right]$$
(B.9)

$$\mathbf{SCB} = \frac{1}{W \cdot L} \cdot \left[ \sum_{i=1}^{n} \left( W_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + L} f_{\mathrm{B}}(u) \, \mathrm{d}u \right) + \sum_{i=n+1}^{n+m} \left( L_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + W} f_{\mathrm{B}}(u) \, \mathrm{d}u \right) + B_{\mathrm{corner}} \right]$$
(B.10)

$$\mathbf{SCC} = \frac{1}{W \cdot L} \cdot \left[ \sum_{i=1}^{n} \left( W_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + L} f_{\mathrm{C}}(u) \, \mathrm{d}u \right) + \sum_{i=n+1}^{n+m} \left( L_i \cdot \int_{\mathrm{SC}_i}^{\mathrm{SC}_i + W} f_{\mathrm{C}}(u) \, \mathrm{d}u \right) + C_{\text{corner}} \right]$$
(B.11)

Here, m and n are the number of projections of the well edge along the length and width of the devices, respectively. Moreover, k is the number of corners selected to account for the 'corner' effects.

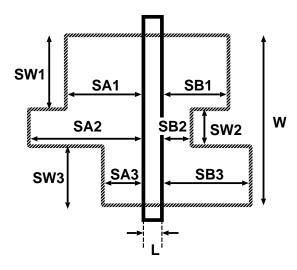


Figure B.1: A typical layout of MOS devices with more instance parameters  $(\mathbf{SW}_i, \mathbf{SA}_i \text{ and } \mathbf{SB}_i)$  in addition to the traditional L and W.

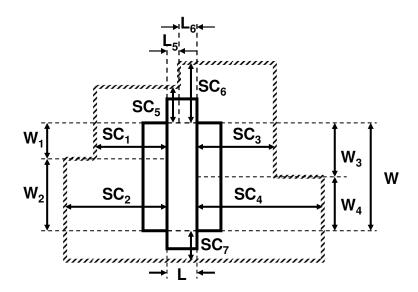


Figure B.2: A typical layout of MOS devices with WPE instance parameters

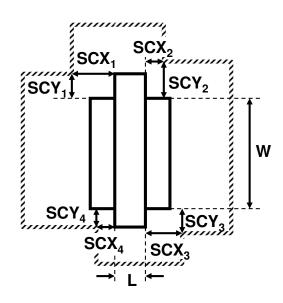


Figure B.3: A layout of MOS devices for corner terms calculation